

**FABRICATION AND RELIABILITY ASSESSMENT OF  
EMBEDDED PASSIVES IN ORGANIC SUBSTRATE**

A Thesis

Presented to

The Academic Faculty

By

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In Partial Fulfillment

of the Requirements for the Degree

Master of Science in Mechanical Engineering in the

George W. Woodruff School of Mechanical Engineering

Georgia Institute of Technology

December 2005

**FABRICATION AND RELIABILITY ASSESSMENT OF  
EMBEDDED PASSIVES IN ORGANIC SUBSTRATE**

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## ACKNOWLEDGEMENTS

First and foremost, I would like to thank my advisor Dr. Suresh Sitaraman for giving me the opportunity to study under his supervision. His genuine care and encouragement throughout the course of my graduate studies have helped me to achieve this great accomplishment. I would also like to thank Dr. Swapan Bhattachaya and Dr. Mahesh Varadarajan for their guidance and support. This thesis would not have been possible without them.

I would like to thank Dr. Rao Tummala and Dr. Daniel Baldwin for their valuable comments and serving on the thesis reading committee. I would also like to thank Dr. Robin Abothu, Dr. Raghuram Pucha, Dr. Lixi Wan, Dr. Jack Moon, Dr. Baik-Woo Lee, Reinhard Powell, and Ajanta Bhattacharjee for their help in design, fabrication, material characterization, and modeling part of my research. My sincere thanks are due to Prof. Charles Ume for letting me use his facility for shadow moiré measurements and to Prof. C. P. Wong for letting me use his facility for DSC measurements.

I would like to thank my friends in the Computer-Aided Simulation and Packaging Research (CASPaR) lab, Jamie Ahmad, Manoj Damani, Shashi Hedge, Karan Kacker, Injoong Kim, Kevin Klein, George Lo, Saketh Mahalingam, Andy Perkins, Krishna Tunga, and Jiantao Zheng for their friendship and professional help. I have enjoyed every bit of my time spent in the lab, and I will cherish the moment throughout my career.

I would like to thank Endicott Interconnect Technologies, Inc. for providing the test samples and material characterizations. I would also like to thank Packaging

Research Center (PRC) and Georgia Institute of Technology for providing a friendly environment and endless resources to pursue my graduate studies. I would like to acknowledge National Science Foundation (NSF) through the Georgia Tech/NSF Engineering Research Center in Electronic Packaging for funding this project.

Finally, I would like to thank my family for their love and inspiration. I would like to dedicate my thesis to my family.

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# NOMENCLATURE

## List of Abbreviations

AC – Alternating Current

BCB – Benzocyclobutene

CCVD – Combustion Chemical Vapor Deposition

CTE – Coefficient of Thermal Expansion

CVD –Chemical Vapor Deposition

DSC – Differential Scanning Calorimetry

EIA – Electronic Industries Alliance

EI Technology – Endicott Interconnect Technology, Inc.

ESL – Equivalent Series Inductance

ESR – Equivalent Series Resistance

FEA – Finite Element Analysis

FR-4 – NEMA designation Flame Resistant 4

HAST – Highly Accelerated Stress Test

IC – Integrated Circuits

iNEMI – National Electronic Manufacturing Initiative

IPC – International Printed Circuit Association

JEDEC – Joint Electron Device Engineering Council

Mil Spec; Mil Std – Military Specification; Military Standard

MOCVD – Metallo-Organic Chemical Vapor Deposition

NiCrAlSi – Nickel Chromium Aluminum Silica

ppm – Parts per Million

PTF – Polymer Thick Film

PTH – Plated-Through-Hole

PTZ – Lead zirconate titanate

PWB – Printed Wiring Board

Q-Factor – Quality Factor

RF – Radio Frequency

RH – Relative Humidity

SBU – Sequential Build Up

SMT – Surface Mount Technology

SOP – System on Package

TCC – Temperature Coefficient of Capacitance

TCR – Temperature Coefficient of Resistance

TSR – Total Strain Range

TV1 – Test Vehicle 1

TV2 – Test Vehicle 2

UV – Ultraviolet

VCR – Voltage Coefficient of Resistance

VNA – Vector Network Analyzer

## List of Symbols

$\text{\AA}$  – Angstrom

$A$  – Area

$^{\circ}\text{C}$  – Degree Celsius

$d$  – Height or thickness

$D_f$  – Dissipation Factor

$E$  – Elastic modulus

$\epsilon_0$  – Vacuum permittivity

$\epsilon_r$  – Dielectric constant

$F$  – Farad

$\text{GPa}$  – Gigapascal

$k$  – Dielectric constant

$K$  – Kelvin

$L$  – Length

mils – milli-inches

$\text{MPa}$  – Megapascal

$N_s$  – Number of squares

$N_p$  – Number of fringes

$Q$  – Coulomb

$R$  – Resistance

$R_s$  – Sheet resistance

$t$  – Time

$T$  – Temperature

$T_g$  – Glass transition temperature

$V$  – Voltage

$W$  – Width

$z$  – Out-of-plane displacement

### **List of Greek Symbols**

$\alpha$  – Coefficient of Thermal Expansion or illumination angle

$\beta$  – Observation angle

$\varepsilon$  – Axial strain

$\Omega$  – Resistance

$\rho$  – Resistivity

$\tau$  – Shear stress

$\gamma$  – Shear strain

$\sigma$  – Stress

$\nu$  – Poisson's ratio



## SUMMARY

In a typical printed circuit board assembly, over 70 percent of the electronic components are passives such as resistors, inductors, and capacitors, and these passives could take up to 50 percent of the entire printed circuit board area. By embedding the passive components within the substrate instead of being mounted on the surface, the embedded passives could reduce the system real estate, eliminate the need for surface-mounted discrete components, eliminate lead based interconnects, enhance electrical performance and reliability, and potentially reduce the overall cost. Even with these advantages, embedded passive technology, especially for organic substrates, is at an early stage of development, and thus a comprehensive experimental and theoretical modeling study is needed to understand the fabrication and reliability of embedded passives before they can be widely used.

This thesis aims to fabricate embedded passives in a multilayered organic substrate, perform extensive electrical and mechanical reliability tests, and develop physics-based models to predict the thermo-mechanical reliability of embedded capacitors. Embedded capacitors and resistors with different geometric shapes, planar dimensions, and thus different electrical characteristics have been fabricated on two different test vehicles. Capacitors are made with polymer/ceramic nanocomposite materials and have a capacitance in the range of 50 pF to 1.5 nF. Resistors are carbon ink based Polymer Thick Film (PTF) and NiCrAlSi and have a resistance in the range of 25  $\Omega$  to 400 k $\Omega$ . High frequency measurements have been done using Vector Network Analyzer (VNA) with 2 port signal-ground (S-G) probes. Accelerated thermal cycling (-

55 to 125°C) and constant temperature and humidity tests (85°C/85RH) based on JEDEC and MIL standards have been performed. Furthermore, physics-based numerical models have been developed and validated using the experimental data. By focusing on the design and fabrication as well as the experimental and theoretical reliability assessments, this thesis aims to contribute to the overall development of embedded passive technology for Digital and Radio Frequency (RF) applications.

# CHAPTER I

## INTRODUCTION

Passives are the key functional elements that play critical role in all electronic systems. It is a crucial part of modern electronic technology with a world wide market of \$20 billion per year as shown in Figure 1.1. Usually, passives refer to resistors, capacitors, and inductors; however, it can also include transformers, filters, mechanical switches, thermistors, temperature sensors, and almost any non-switching analog devices. These components perform vital functions such as bias, decoupling, filtering, and terminations to ensure proper operation of all electronic systems [Tummala, 2001].

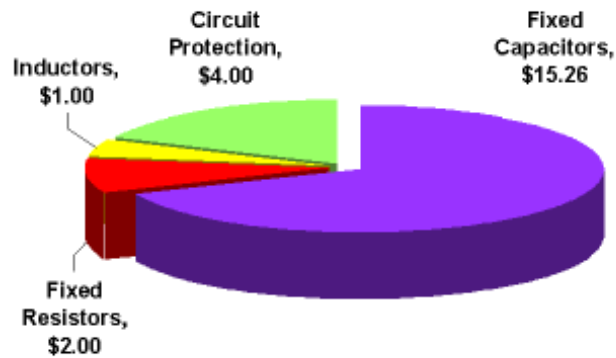


Figure 1.1. World passive market (\$billions) [iNEMI 2004]

The number of passives on any modern electronics is substantial compared to Integrated Circuits (ICs) as shown in Table 1.1. In a typical circuit, 80% of the components are passives, and they can take up to 50% of the printed wiring board area. As the functionality of electronic devices increase, the number of passive component will

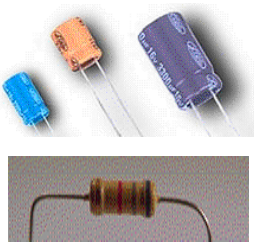
only grow higher. Therefore, passive components are significant factor in the overall cost, size, and reliability of electronic systems.

Table 1.1. Comparison of number of passives to actives components  
[Ladew and Makl, 1995]

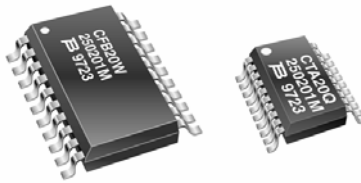
System	Total passives	Total ICs	Ratio
Ericsson DH338 Digital cellular phone	359	25	14:1
Nokia 2110 Digital cellular phone	432	21	20:1
Motorola StarTAC cellular phone	993	45	22:1
Apple G4 computer	457	42	11:1
Motorola Tango pager	437	15	29:1
Casio QV10 Digital Camera	489	17	29:1
1990 Sony Camcorder	1226	14	33:1

## 1.1 Types of Passives Devices

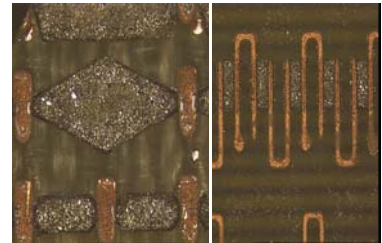
The three main types of passives are discrete, integrated, and embedded as shown in Figure 1.2 [Tummala, 2001].



a) Discrete



b) Integrated



c) Embedded

Figure 1.2. Configurations of passives

Discrete are the simplest and most commonly used form of passives. It consists of a single passive element with its own leaded or Surface Mount Technology (SMT)

package. Usually they are denoted in the numerical format such as 0402, which indicates a size of 40 x 20 mils (1.0 x 0.5 mm). Currently, 0201 is being used in certain high end products such as cell phones, and 01005 components are under research. As these components get smaller, manufacturers and board assemblers are presented with numerous challenges in attachment, inspection, handling, and cost of these devices. For an instance, the defect rate of 0201 from 0402 has increased dramatically in the order of a magnitude. This trend was observed during the transition from 0603 to 0402 and expected to continue for 01005 components.

Integrated passive is a general term for multiple discrete components combined into a single SMT package. They are either in an array or network format, where arrays contain multiple of same type of passives and networks contain combination of different types of passives. One of the main advantages of integrated over discrete is increased efficiency during assembly. Although using integrated components do not necessarily reduce the number of leads, more connections can be made with one alignment and mounting.

Embedded passive components, also known as integral passives, are buried within the substrate layers instead of being on the surface. Although it only accounts for 3% of current 900 billion passive components being used in the world, many expect the overall acceptance and market penetration to continue to grow in the future. The roadmap of National Electronic Manufacturing Initiative (iNEMI) 2004 suggests that embedded passives are needed for portable electronic products by 2005.

## **1.2 Advantages of Embedded Passives**

The potential advantages of embedded passives include:

- Significant reduction in overall system mass, volume, and footprint by eliminating surface mounts
- Improved electrical performance by eliminating leads and reducing parasitic
- Increased design flexibility
- Eliminate lead base interconnects
- Improved thermo-mechanical reliability by eliminating solder joints
- Potentially reduce the overall cost

One of the main advantages of embedded passives is significant reduction in the overall system mass and surface footprint. Surface mounts require excessive leads on the surface to connect to the substrate, while embedded passives contain only the functionally required portion. Also, embedded passives use the substrate as mechanical support and protection that additional packaging is not required. For certain applications such as wireless and mixed-signal system where almost half of the board surface is populated with passives, significant surface footprint can be reduced.

In terms of electrical performance, embedded passives have drastically lower parasitic than the surface mounts due to lack of surface leads and simplified passive structures. They can also be placed much closer to the interacting active components for faster response. These are particularly beneficial to high frequency capacitor applications such as decoupling, since parasitic reduces the useable frequency range. Other electrical advantage is increased design flexibility. Discrete components are made in advance that sometimes exact value is not available and multiple passives linked in series or parallel might be necessary. Embedded passives could eliminate these unnecessary steps by assigning exact dimensions during the design process. Although it

is difficult to modify the design once fabricated, the overall design process is much more flexible.

Embedded passives are more reliable by eliminating the two solder joints, which is the major failure location for discrete. However, it is difficult to confirm that the overall reliability is improved. Use of new materials and process could bring other concerns such as crack propagation, interface delamination, and component instability. To embed passives, more layers could be necessary to accommodate the embedded passives. This could mean integration of various new materials and processes that can cause significant thermo-mechanical stress due to Coefficient of Thermal Expansion (CTE) mismatch. Furthermore, unlike discrete components where defective parts can be replaced, rework is not a viable option for embedded passives. A single bad component can potentially lead to scrapping the entire board.

It is difficult to tell when embedded passives are more cost effective [Borland et al., 2003]. There are numerous contributing parameters that it is too complex to derive an accurate cost model. Embedded passives are attractive in a sense that all passive components on the same layer could be fabricated simultaneously. It would be particularly beneficial to electronic products with high passive counts, since incremental cost of adding one more passive is nearly zero. As number of passives per unit area increases, embedded passives are more cost effective as shown in Figure 1.3 [Tummala 2001]. A major concern is whether all passive devices can be embedded. If only certain values of passives can be embedded, then manufacturers will be more hesitant to support both discrete and embedded technologies.

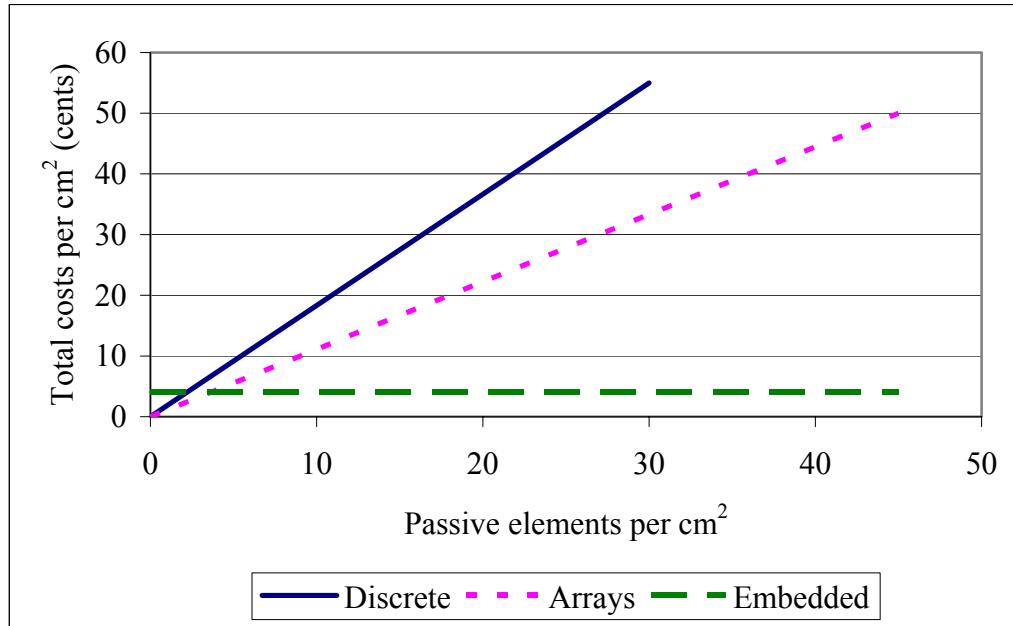


Figure 1.3. Cost effectiveness of passives

### 1.3 Challenges of Embedded Passives

There are many challenges associated with embedded passives, but none seem to be a showstopper. Most are the ones that can be expected with any other new technologies. Some of the challenges that hinder the implementation of embedded passives include [Ulrich and Schaper 2003]:

- Lack of optimal materials and processes
- Lack of design tools and standardization
- Requires vertical integration
- Yield and tolerance issues
- Lack of cost model

One of the major challenges of embedded passive is lack of optimal materials and process conditions. Although numerous materials and process conditions can achieve full



range of required electrical characteristics, optimal materials and processes have not been identified. This is even more problematic, since it needs to be resolved before other areas including development of design tools and standardization can be tackled. Design tool that combines both component sizing and system layout is not readily available partially due to lack of optimal materials.

Vertical integration is required for embedded passives. Since the passives are manufactured together with the substrate, board manufacturers are now required to fabricate the passives instead of simply purchasing them from passive manufacturers. Therefore, lack of expertise by the board manufacturers could cause initial hesitations or resistance towards the implementation.

Yield and tolerance is a major challenge for embedded passives. Surface mounts are usually tested before they are assembled, and even after assembly, bad components can be replaced. Also, they are usually assembled as the last step, which avoids harsh processing conditions of other components. However, embedded passives are quite different. They are assembled during the substrate fabrication that they and also the substrate must be able to withstand each others harsh processing conditions. Various chemical and mechanical exposures and thermo-mechanical stresses could cause permanent damage.

The ultimate decision of adapting embedded passive technology will be dependent on the overall costs and benefits. It is, however, difficult to weight how much benefit can be achieved by reducing the overall size, adding product values, increasing consumer appeal, and being able to make products that are otherwise not feasible. To gain more acceptances and increase market share, the above challenges must be resolved.

This thesis aims to contribute to the successful implementation of embedded passive technology by focusing on the fabrication and reliability assessments. The entire process from design and fabrication to characterization and reliability assessment has been conducted. This thesis is organized in the following manner:

Chapter 2 – Background Information and Literature Review of Embedded Passives

Chapter 3 – Objectives of the Research

Chapter 4 – Test Vehicle Designs

Chapter 5 – Fabrication of Embedded Passives

Chapter 6 – Characterization of Resistors and Capacitors

Chapter 7 – Experimental Reliability Assessment

Chapter 8 – Finite Element Modeling

Chapter 9 – Conclusion and Future Work

# CHAPTER II

## BACKGROUND INFORMATION AND LITERATURE

### REVIEW OF EMBEDDED PASSIVES

This chapter gives an overview of embedded passives with focus on resistors and capacitors. It presents fundamentals and performance parameters, a literature review on promising material candidates, processing methodologies, and reliability assessment of embedded passives.

#### 2.1 Fundamentals of Resistors

A resistor controls electric current by resisting the flow of charge through itself [Halliday et al., 1997]. Usually, it contains a strip of the resisting material with two conducting pads at the ends as shown in Figure 2.1.

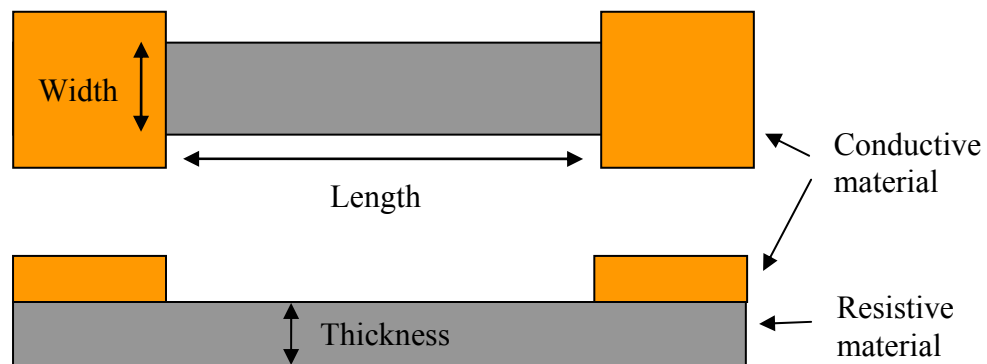


Figure 2.1. Typical resistor geometry

The unit of resistance is ohm ( $\Omega$ ), and it measures how well it resists or opposes the flow of current. It is calculated by using Equation 2.1.

$$R = \frac{\rho L}{Wd} \quad (\text{Eq. 2.1})$$

$R$  is the resistance ( $\Omega$ ),  $\rho$  is the resistivity of material ( $\Omega\text{-cm}$ ),  $L$  is the length of the strip (cm),  $W$  is the width of the strip (cm), and  $d$  is the thickness of the strip (cm). As shown in Equation 2.1, resistance is dependent on the resistivity of the material and the dimensions of the strip. Higher resistance can be achieved by using higher resistivity materials, increasing the length, and using smaller cross-sections. The resistivity is an intrinsic material property that is dependent on the composition and microstructure of the material. Another important property is the maximum amount of power that a resistor can handle. As power is applied and current flows through, most of the energy is dissipated as heat. If too much heat is generated, then resistors can be permanently damaged.

Sheet resistance is the resistance of a square strip. It is another common way of expressing the resistance as shown in Equation 2.2.

$$R = \left( \frac{\rho}{d} \right) \left( \frac{L}{W} \right) = R_s N_s \quad (\text{Eq. 2.2})$$

$R_s$  is the sheet resistance ( $\Omega/\text{sq}$ ) and  $N_s$  is the number of squares. As long as the ratio of  $L$  and  $W$  or the number of squares remains same, the resistance value does not change. A single value of resistance can be obtained by various sizes of resistor material as long as

the number of squares remains same. The decision of how big each square should be is based on several parameters:

- Available real estate
- Heat dissipation
- Tolerance
- Parasitic capacitance
- Standing waves and internal reflections
- Reflections at the resistor and interconnect interface

Usually, heat dissipation and tolerance are the most significant parameters. If resistors can not dissipate enough heat, it could potentially damage the resistors or accelerate other failure mechanisms. Therefore, large area if available should be utilized to improve heat dissipation and also tolerance. Other parameters such as parasitic capacitance can be a problem for high frequency applications. Long serpentine resistors should be avoided to minimize the parasitic. In most cases, resistor footprint should utilize large area with minimum number of squares to achieve the optimal performance and reliability.

## **2.2 Fundamentals of Capacitors**

A capacitor is a device that stores electrical charge [Halliday et al., 1997]. In a simple form, it contains two conducting metal plates separated by an insulator or dielectric material. When a voltage is applied, electric field shifts negative charges to one electrode and positive charges to the other electrode as shown in Figure 2.2.

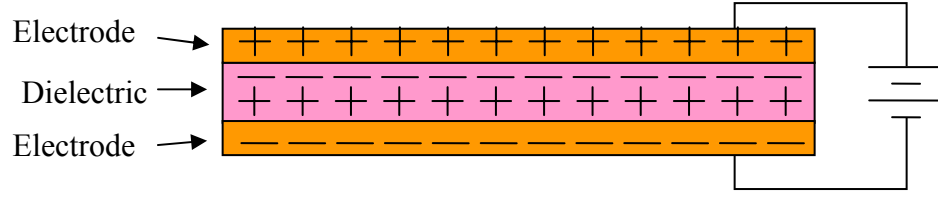


Figure 2.2. Capacitor charge configuration

This reconfiguration of electrical charge continues until the potential difference equals the applied voltage. Then the charge remains or is stored in the dielectric layer even after the voltage source is removed.

Capacitance measures how well the charge is stored. It is the ratio of stored charge versus applied voltage. A capacitor of one farad (F) capacitance equals 1 coulomb (Q) of charge stored when 1 volt (V) of voltage is applied. In a typical electrical circuit, capacitances in the range of picofarad ( $10^{-12}$ ) to microfarad ( $10^{-6}$ ) are used. Equation 2.3 shows how capacitance with a vacuum dielectric layer,  $C_o$ , is related to stored charge and applied voltage.

$$C_o = \frac{Q}{V} = \frac{qA}{V} = \frac{\epsilon_o EA}{V} = \frac{\epsilon_o (V/d)A}{V} = \frac{\epsilon_o A}{d} \quad (\text{Eq. 2.3})$$

$Q$  is the charge applied,  $V$  is the voltage applied,  $E$  is the electric field,  $\epsilon_o$  is the vacuum permittivity ( $8.854 \times 10^{-12} \text{ C}^2/\text{m}^2$ ),  $A$  is the area, and  $d$  is the distance between the conductors. Higher capacitance can be achieved by increase in area and decrease in the distance between the conductors.

Dielectric constant ( $k$  or  $\epsilon_r$ ) is an intrinsic material property that represents how well a capacitor stores charge when a voltage is applied. Although it is called the dielectric constant, the value changes based on many parameters such as temperature,

frequency, voltage, and time. Equation 2.4 shows a simple relationship between capacitance and dielectric constant.

$$C = \frac{\epsilon_o \epsilon_r A}{d} \quad (\text{Eq. 2.4})$$

As shown in Equation 2.4, higher dielectric constant results in higher capacitance at a given space. For this reason, high dielectric constant materials are desired in certain applications where space is limited.

Another important characteristic of a capacitor is the dissipation factor. This is the ratio of power loss in a dielectric material to the total power transmitted at a specific frequency. It represents how much energy is lost in the dielectric material during the AC operation. Generally, under 0.1% is consider low and anything above 5% is consider high. Although certain applications such as decoupling can tolerate a high percentage loss, this parameter is very critical especially in the high frequency applications where low loss is desired. The inverse of the dissipation factor is the quality factor (Q-Factor).

### **2.3 Polarization**

The ability of capacitor to store energy is dependent on the polarization mechanism of dielectric material. Under electric field, separation and alignment of the electric charge create three major types of polarization mechanisms as shown in Figure 2.3.

- electronic polarization
- atomic polarization
- ionic polarization

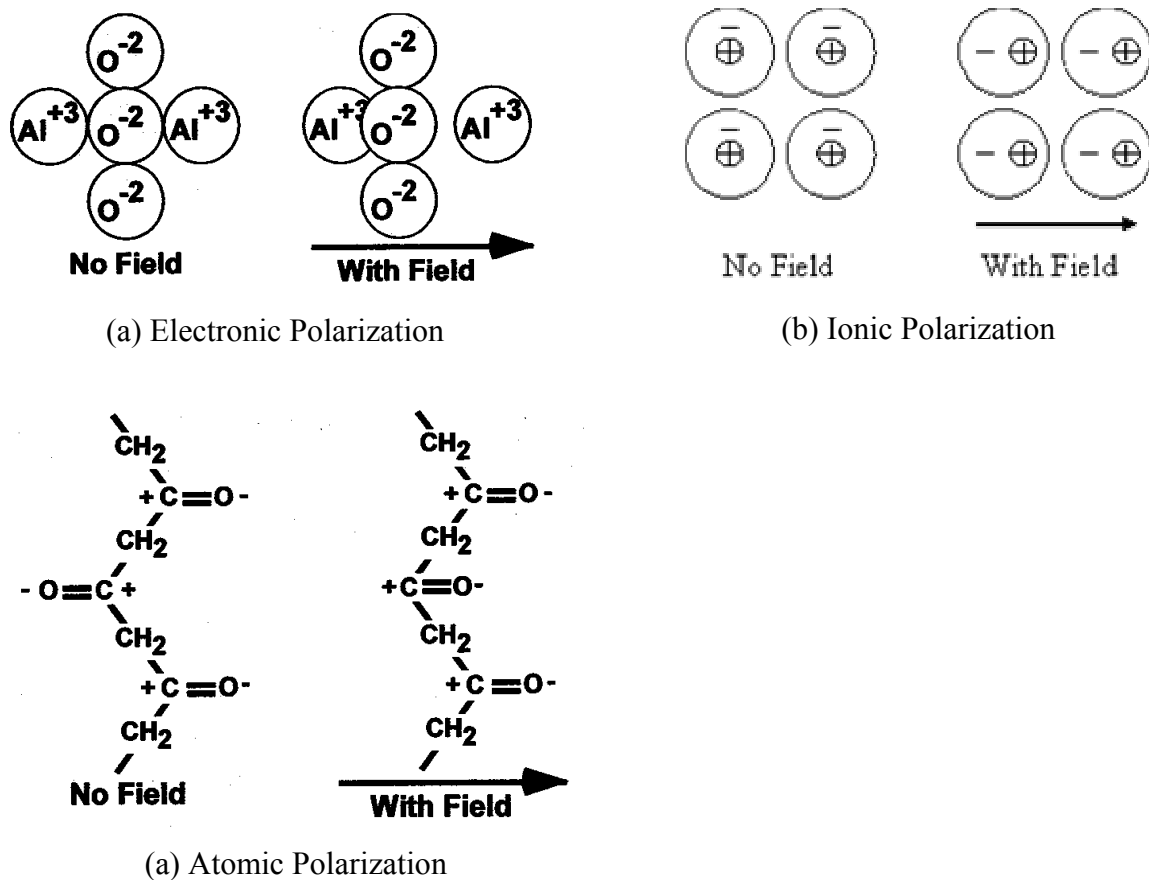


Figure 2.3. Major types of polarization mechanisms  
[Ulrich and Schaper, 2003; Rao, 2001]

Electronic polarization occurs due to electric field induced dipole moments within each atom. When an electric field is applied, positively charged nucleus and negatively charged electrons move to opposite direction. These shifts create small dipole moments and thus store energy. All materials exhibit electronic polarization, but the magnitude of polarization is much smaller than other polarization mechanisms due to the short dipole moment arm within each atom.

Atomic polarization refers to aligning of dipoles in nonionic atoms that share electrons asymmetrically. The permanent dipoles that are formed due to asymmetrically shared electrons do not contribute to the polarization, and only the movement or



alignment with the field creates capacitance. Ionic polarization is similar to atomic polarization except that it is produced by ionic species. Under electric field, positive and negative charge carriers rearrange themselves in the direction of the field. This shift can lead to a very high dielectric constant.

The two major types of dielectric materials are paraelectric and ferroelectric. They both exhibit all three types of polarizations, but ferroelectric materials maintain ionic polarization even after the electric field is removed. Ferroelectric reconfigures the ions that they can not revert back to their original state even after the electric field is removed. Therefore, ferroelectrics have as much as three orders of magnitude higher dielectric constants than paraelectrics, but they tend to be more sensitive to various operating conditions such as temperature, frequency, voltage, and time.

## 2.4 Stability of Embedded Resistors and Capacitors

As mentioned previously, material properties of embedded passives could change with respect to temperature, frequency, voltage, and time. It is important to understand how these variables affect the resistivity or capacitance to minimize any undesirable changes.

The Temperature Coefficient of Resistance (TCR) and Voltage Coefficient of Resistance (VCR) measure change in resistance with respect to change in temperature and voltage respectively as shown in Equations 2.5 and 2.6.

$$TCR = \frac{1}{R_{T1}} \frac{R_{T2} - R_{T1}}{T_2 - T_1} \quad (\text{Eq. 2.5})$$

$$VCR = \frac{1}{R_{V1}} \frac{R_{V2} - R_{V1}}{V_2 - V_1} \quad (\text{Eq. 2.6})$$

These are dimensionless quantities expressed in ppm/ °C. For most applications, it is desirable to have zero TCR and VCR, and thus stable resistance throughout the operating condition. Some applications including thermistors, however, exploit the changes in resistance to due temperature that high TCR is desired. Also, TCR is sometimes purposely made to a certain value to offset an existing material or component that is temperature dependent. For instance, capacitance in RC network usually increase with temperature, so negative TCR can be implemented to maintain a steady RC time constant. TCR is usually measured between -55 to 125°C, and VCR is usually measured between 5 V and 50 V [Sergent et al., 1995].

Similarly to TCR, the temperature coefficient of capacitance (TCC) measures change in capacitance with respect to change in temperature as shown in Equation 2.7.

$$TCC = \frac{1}{C_{T1}} \frac{C_{T2} - C_{T1}}{T_2 - T_1} \quad (\text{Eq. 2.7})$$

It is also a dimensionless quantity expressed in ppm/°C. Usually, TCC is positive due to greater inter-atomic spacing and thus higher dipole moment at higher temperatures. For most applications, TCC of less than 200 ppm/°C is considered low. A typical TCC of paraelectric is in the range of 100 – 300 ppm/°C, and it is fairly stable. However, the polarization mechanism of ferroelectric is dependent on the crystal structure and phase transition that value of TCC fluctuates dramatically with temperature. Figure 2.4 shows temperature effect on ferroelectric and paraelectric materials.

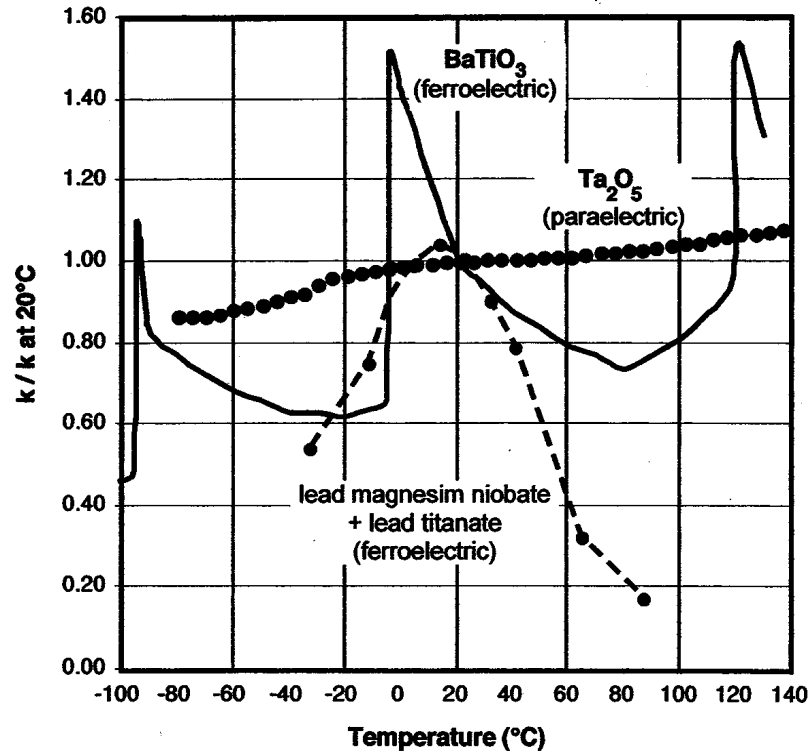


Figure 2.4. TCC of capacitor dielectric materials [Ulrich and Schaper 2003]

Frequency and voltage could have a dramatic effect on the dielectric constant and thus capacitor performance. As frequency increases, dipoles must be able to keep up in reversing directions to stay synchronized with the electric field to maintain a constant capacitance. When frequency starts to outpace the ability of the dipoles to reverse their directions, the effective dipole moment arms are shortened, and capacitance is decreased. Eventually when the frequency increases and reaches resonance frequency, the capacitors can no longer store energy and act as an inductor. Once again, dielectric constants of paraelectric tend to be fairly stable with respect to frequency, but ferroelectrics are significantly dependent on the frequency as shown in Figure 2.5.

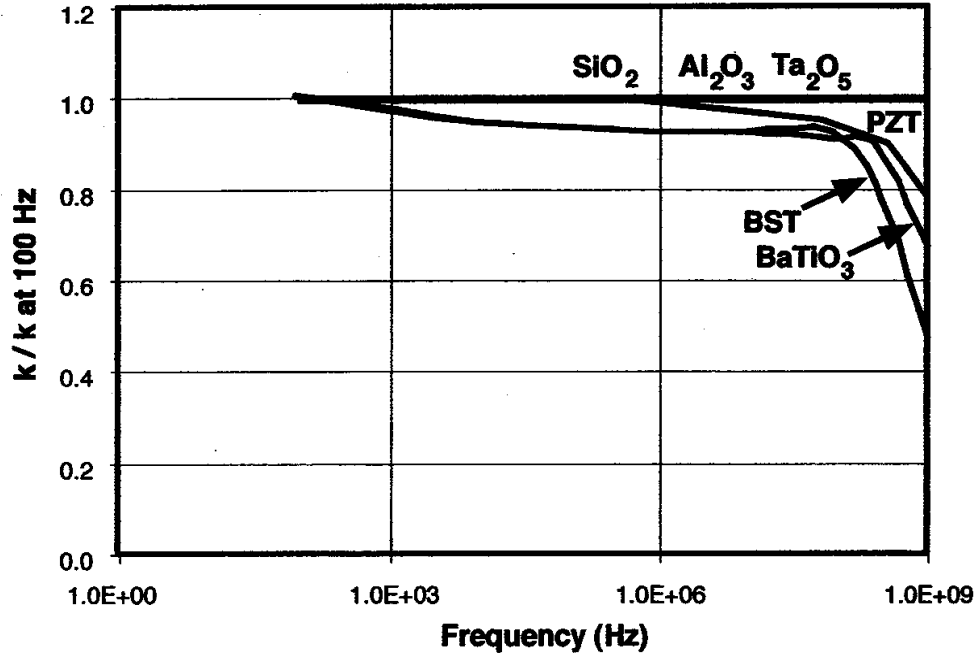


Figure 2.5. Frequency effect on capacitance [Ulrich and Schaper 2003]

## 2.5 Embedded Passive Materials and Fabrication Processes

There are many reports of suitable materials and processes for embedded passives; however, optimal materials and processes have not been identified. In order to develop the optimal material and process, various aspects of electrical and mechanical performances and compatibility with other existing processing steps must be considered. This section describes potential embedded passive materials that are compatible with the organic substrate process. Additionally, various commercially available fabrication process technologies are presented.

### 2.5.1 Resistors

A wide range of resistance is needed for various electronic systems. For most applications, resistance range from approximately 10  $\Omega$  to 1 M $\Omega$  is required [Ulrich and

Schaper 2003]. In terms of sheet resistance, number of squares that are outside the range of 0.1 to 100 could mean excessive footprints, yield and tolerance problems, and significant parasitic capacitance for high frequency applications. Consequently, at least two sheet resistances such as 100  $\Omega/\text{sq}$  and 10  $\text{k}\Omega/\text{sq}$  are needed to cover the desired range of resistance. Materials with 100  $\Omega/\text{sq}$  can cover the resistances from 10  $\Omega$  to 10  $\text{k}\Omega$ , and materials with 10  $\text{k}\Omega/\text{sq}$  can cover the resistance from 10  $\text{k}\Omega$  to 1  $\text{M}\Omega$ . In order to narrow down the choices of materials, if thickness can be between 100  $\text{\AA}$  to 1  $\mu\text{m}$ , then the material should have resistivity in the range of  $10^{-4}$  to 1  $\Omega\text{-cm}$ . Figure 2.6 shows various materials that are capable of meeting resistivity requirements.

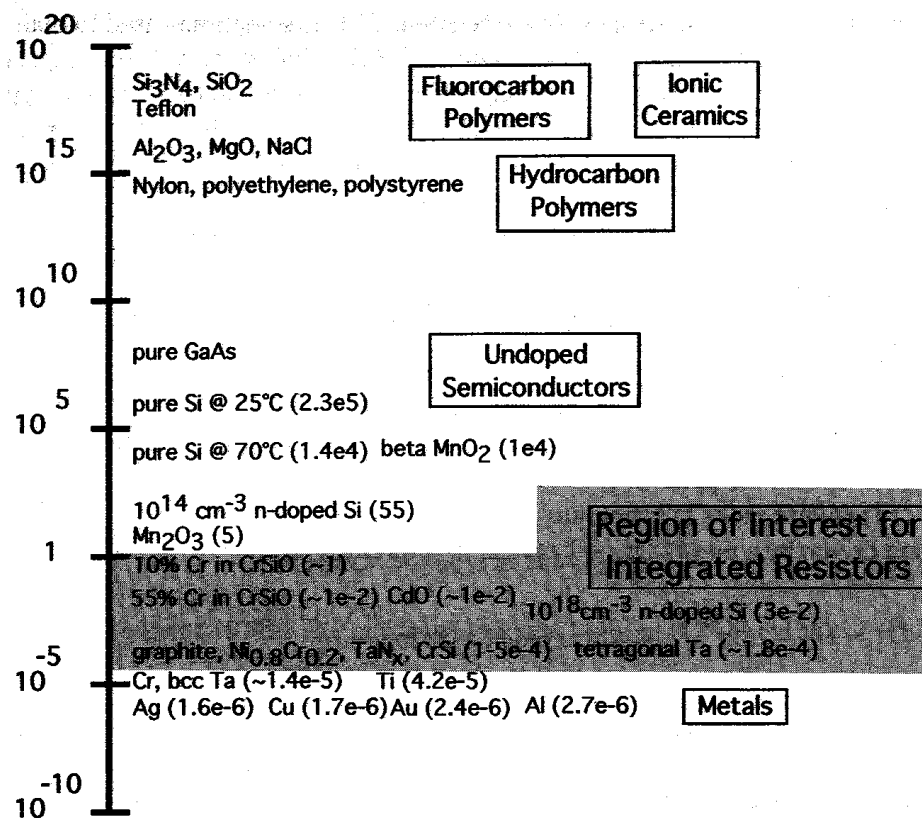


Figure 2.6. Electrical resistivities of materials [Ulrich and Schaper, 2003]

Although there are many materials that are capable of achieving these requirements, some of them are difficult to process or insufficiently stable with respect to temperature or time. Some of the leading types of materials that have shown success are resistive alloys, ceramic-metal nanocomposites, and carbon filled polymers.

Most of the resistive alloys are useful for low end resistances. These are usually sputtered, but they can be also electrolytically or electrolessly plated. Among resistive alloys, NiCr, NiCrAlSi, CrSi,  $TiN_xO_y$ , and  $TaN_x$  are the potential candidates. NiCr and NiCrAlSi foils are commercially available from Gould Electronics Inc. They can provide sheet resistance between 25 and 250  $\Omega/sq$  with relatively low TCR [Gould website].  $TaN_x$  is another very attractive resistive alloy for embedded resistor applications. They are usually form by reactive sputtering of Ta in a nitrogen atmosphere, and a wide processing condition can achieve stable resistivities up to 250  $\mu\Omega\text{-cm}$  with TCR of around  $-75 \text{ ppm}/^\circ\text{C}$  [Coates et al., 1998]. Sputtered  $TiN_xO_y$  offers relatively higher resistivities up to 5  $k\Omega/sq$  with TCR of  $\pm 100 \text{ ppm}/^\circ\text{C}$  [Shibuya et al., 2001]. Unlike most of these thin film resistor materials that are sputtered, some materials such as NiP and NiWP can be electroplated [Chahal et al., 1998]. Ohmega-Ply® and MacDermid's M-Pass™ are some of the mature commercialized Ni alloy based resistor technologies that can provide up to 250  $\Omega/sq$  and 100  $\Omega/sq$  respectively.

High end resistances above 100  $k\Omega$  can be achieved by ceramic-metal nanocomposites also known as a cermet [Ulrich and Schaper 2003]. These are commonly used in ceramic packages, but they can be sputtered at a relatively low temperature for organic packages. The most commonly used is Cr-SiO. Depending on the ratio, Cr-SiO can achieve up to 10  $m\Omega\text{-cm}$  with near zero TCR and good stability.

Polymer thick films (PTF) are also very promising embedded resistor material. They provide wide range of resistances from 1  $\Omega/\text{sq}$  to  $10^7 \Omega/\text{sq}$  at a relatively low cost. They are commonly available in viscous liquid form that can be easily screen printed or stenciled, and they have relatively low curing temperature. Some of drawbacks are, however, tolerance, stability, and reliability. Material tolerance is usually above 5 - 10%, and laser trim is most likely necessary. The oxidation between polymer and copper interface can cause drift in resistance values, and they are vulnerable to delamination or cracking due to CTE mismatch.

### ***2.5.2 Commercialized Resistor Material and Processes***

#### **Gould TCR<sup>®</sup> and TCR+<sup>™</sup>** [Gould website]

Gould TCR<sup>®</sup> and TCR+<sup>™</sup> are based on NiCr and NiCrAlSi alloys. NiCr foils are available in 25  $\Omega/\text{sq}$ , 50  $\Omega/\text{sq}$ , and 100  $\Omega/\text{sq}$  with TCR of less than 100 ppm/ $^{\circ}\text{C}$ . NiCrAlSi foils are available in 50  $\Omega/\text{sq}$ , 100  $\Omega/\text{sq}$ , and 250  $\Omega/\text{sq}$  with TCR of -20 ppm/ $^{\circ}\text{C}$ . These foils utilize two or three step etching process using cupric chloride, acidic permanganate, and ammoniacal solutions. NiCrAlSi foils are utilized in one of the test vehicles developed for this thesis, and detailed process conditions and test results are discussed in later chapters.

#### **Ohmega-Ply<sup>®</sup>** [Ohmega website]

Ohmega-Ply<sup>®</sup> resistors are based on electroplating of NiP on one side of Cu foil. Currently available sheet resistances are from 25 to 250  $\Omega/\text{sq}$  with TCR of  $\pm 100$  ppm/ $^{\circ}\text{C}$ , and 1000  $\Omega/\text{sq}$  is under development. Once plated, various print and etch steps are used to define the resistor dimensions. Extensive mechanical and electrical tests by Ohmega

and many others have shown reliable results. Material tolerance varies 5 – 10%, and thermal shock and humidity tests show less than 2% change.

**DuPont Interra™ EP20X** [DuPont website]

This ceramic thick film resistor is based on lanthanum boride (LaB6) material that can achieve up to 10 kΩ/sq with TCR of +200 ppm/°C. This material has been used for many years in ceramic packages, and it is known to be highly stable and reliable. The fabrication of the resist foil starts with conditioning the copper foil with thin layer of copper/glass paste to increase the adhesion between the Cu and LaB6. Then, LaB6 paste is screen printed and fired onto the Cu foil at 900°C to activate the resist material. The resulting fired film thickness is 14-18 μm, and it could exhibit material tolerance of 15% before trimming.

**MacDermid M-Pass™** [MacDermid website]

M-Pass™ resistors are based on electroless plating of NiP. The additive process can selectively plate an area by using palladium catalyst and photoresist. Also, sheet resistance of 25 – 100 Ω/sq can be controlled by plating time. Various thermal cycling and humidity test have shown reliable results of less than 2% change. Material tolerance is reported to be 10% before trimming.

**Shipley Insite™** [Rohm and Hass website]

Shipley Insite™ is also known as Rohm and Hass Insite™, and it is processed by doping titanium on to Cu using combustion chemical vapor deposition (CCVD). The resulting foil can provide sheet resistances of 500 and 1,000 Ω/sq with material tolerance of 10% and TCR of 200 ppm/°C. The processing involves simple print and etch steps.



### 2.5.3 Capacitors

In the past several years, numerous dielectric materials have been evaluated in an attempt to identify and develop the ideal dielectric material. Generally, an ideal dielectric material should have no leakage or parasitic, and it should also be stable with respect to temperature, frequency, voltage, and time. It should be easily fabricated with minimum variations, and compatibility with other processes is desired. Moreover, thermo-mechanical reliability and economic viability are also important parameters. Table 2.1 summarizes the capacitor requirements based on the potential applications.

Table 2.1. Potential embedded capacitor applications and their requirements  
[Ulrich and Schaper 2003]

Applications	Value Range	Tolerance Req.	Acceptable Leakage	Stability Req.	Acceptable Parasitic
Filtering	1 pF–100 pF	High	Low	Moderate	Low
Timing	1 pF – 100 pF	High	Low	Moderate	Higher
A/D conversion	1 pF – 10 nF	High	Low	Very high	Higher
Termination	50 pF – 200 nF	Lower	Higher	Lower	Higher
Decoupling	1 nF – 100 nF	Lower	Higher	Lower	Very low
Energy Storage	1 uF and up	Lower	Higher	Lower	Lower

As shown above, a wide range of capacitance from 1 pF to many uF is needed for various applications. For some such as filtering and termination require relatively low capacitance of 1 pF – 200 pF, while others such as decoupling and energy storage require much higher capacitance in the range of nF and uF. Also, some attributes are more critical to certain applications than others. For instance, filtering application considers

high tolerance, stability, and low parasitic as main priority, while the decoupling application can scarifies tolerance and stability for higher capacitance and low parasitic.

The two main types of dielectric materials are paraelectrics and ferroelectrics. Paraelectrics tend to have much lower dielectric constant than ferroelectrics, but they are more stable with respect to temperature, frequency, voltage, and time. These two can be further divided into four classes [Rao, 2001; iNEMI 2004]:

- Thin film oxides
- Unfilled polymers
- Ferroelectrics
- Ferroelectric filled polymers

Thin film oxides and unfilled polymers are both paraelectric materials. The main differences are their dielectric constants and specific capacitances. Thin film oxides such as  $\text{Ta}_2\text{O}_5$ ,  $\text{TiO}_2$ ,  $\text{Al}_2\text{O}_3$  have higher dielectric constants in the range of 40, while unfilled polymers are in the range of 3 – 5. Moreover, thin film oxides can be made very thin as low as a tenth of a micron that the specific capacitance can be quite high up to 200  $\text{nF}/\text{cm}^2$ , while unfilled polymers have 0.3  $\text{nF}/\text{cm}^2$  at the most. The main advantages of unfilled polymers over thin film oxides are their simple processing conditions and considerably lower processing cost per area.

Ferroelectrics such as barium titanate can have very high dielectric constants of around 2000. With thickness of one micron, specific capacitance can be potentially up to 1800  $\text{nF}/\text{cm}^2$ . This material class offers by far the highest energy density, which can be especially useful in the energy storage applications. Some of the disadvantages are, however, its strong dependence toward environment and operating condition such as

temperature, frequency, voltage, and time. Also to process ferroelectrics, firing at temperature of at least 500°C in oxygen is required that it can not be directly implemented on the organic substrates. The material must be annealed onto a separate copper foil first before it can be laminated onto an organic substrate.

Ferroelectric filled polymers are mixtures of both paraelectric and ferroelectric. The purpose of mixing both types is to obtain relatively high specific capacitance and compatible processing conditions to organic substrates. By adding ferroelectric material into paraelectrics such as epoxy or polyimide, relatively high dielectric constant of 70 with specific capacitances of 12 nF/cm<sup>2</sup> can be obtained at low temperature process. Table 2.2 lists various dielectric materials and their properties.

#### ***2.5.4 Fabrication Techniques of Capacitors***

There are numerous fabrication techniques for embedded capacitors including sputtering, anodization, Chemical Vapor Deposition (CVD), Metallo-Organic Chemical Vapor Deposition (MOCVD), spin-coating, sol-gel, pulse-laser deposition, dry calcinations, hydrothermal, and more [Ulrich and Schaper 2003]. Since these processes can directly affect the electrical and mechanical properties of materials, it is important to realize the pros and cons of various process methodologies. This section focuses on organic substrate compatible processes. Some ferroelectric materials that require high processing temperature are also discussed, since they can be annealed and then laminated onto the substrate.

Table 2.2. Various dielectric materials  
[Maissel and Glang, 1970; Garrou, 1992; Sergent and Harper, 1995]

Material	Dielectric constant	Dissipation factor (%)	TCC (ppm/°C)
Teflon	2.0	0.02	-100
BCB	2.7	0.1	N/A
Polycarbonate	3.1	0.1	N/A
SiO <sub>2</sub>	3.7	0.03	<100
Epoxyes	3 – 6	0.4 – 0.7	N/A
SiO	5.1	0.01	~200
Al <sub>2</sub> O <sub>3</sub>	9	0.4 – 1	390
Ta <sub>2</sub> O <sub>5</sub> (amorphous)	24	0.2 – 1	200
BaTiO <sub>3</sub> (tetragonal)	~1000	5	Highly variable

Sputtering processes involve removing of atoms from a source by energetic positive ion bombardment. Up on hitting the source, positive ions become neutral again by receiving electrons from the source. This procedure releases energy, and particles from the source are deposited onto the substrate. The typical deposition rates are 100 - 1000 Å per minute, and it is depended on many factors including RF power density, gas pressure, gas composition, gas flow rate, and temperature. Usually, it is used for depositing a few hundred angstroms to a few microns thick film. The entire process is performed in a vacuum environment to promote uniform deposition and minimize the contaminants. Although a vacuum is required and the deposition is not always uniform, this process has the advantage over others that it is processed at a relatively low temperature. This process can be used for almost all paraelectrics without any further

processing, but ferroelectric needs to be annealed at a high temperature after sputtering to achieve the high dielectric constant.

Generally, CVD based processes refer to depositing gaseous form of material in a low pressure reaction chamber. When enough energy is applied, this vapor phase material reacts to form a solid film on the substrate. There are many variations of CVD. Thermally activated CVD refers to a method that heats the substrate to generate the energy required to start the activation. Similarly, plasma-assisted CVD refers to a method that uses electron energy of plasma as the energy source. Plasma-assisted CVD is sometime preferred due to its lower temperature processing condition. MOCVD is one way to deposit a thin film of metal. Although MOCVD is considered one of the most expensive methods, it has low processing temperature and a very thin film of less than 100 Å can be deposited without any defects on a smooth surface substrate [Hendrix et al., 2000; Nielsen et al., 2000]. Combustion chemical vapor deposition (CCVD) is another variation of CVD. The dielectric material is first dissolved into a combustible solvent to create a flame. Then the substrate is passed through the flame to deposit the ferroelectric material directly. This process does not require a vacuum chamber, and it has been used to deposit variety of materials including cerium oxide, tantalum, and strontium titanate. In terms of processing cost, CCVD can deposit at a lower cost than sputtering.

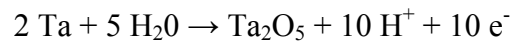
Anodization is a process of electrochemical oxidation on a metal surface by exposing to either oxygen or moisture [Ulrich and Schaper 2003; Berry and Sloan, 1959]. During the process, a thin film of mechanically stable and defect free oxides can be uniformly grown. Although almost all metals react to this process, not all metals can grow oxides. Some metals including cadmium, zinc, and magnesium will dissolve in the

electrolyte bath, and loose or porous oxides are formed. Some of the well known metals that can be anodized are Al and Ta. Also, ferroelectric such as barium titanate has been anodized at a low temperature even though dielectric properties were poor. The metals that can be anodized are known as “valve metals,” and some of the widely used metals and their properties are listed in Table 2.3 [Berry et al., 1968].

Table 2.3. Anodizable valve metals

Metal	Oxide	Dielectric Constant of Oxide	Maximum attainable film thickness (μm)
Aluminum	Al <sub>2</sub> O <sub>3</sub>	9	1.5
Tantalum	Ta <sub>2</sub> O <sub>5</sub>	23	1.1
Titanium	TiO <sub>2</sub>	40	N/A

The actual electrochemical oxidation process is similar to corrosion. The metal acts as an anode, and it is submerged into a conductive solution along with a cathode of a noble metal such as gold or platinum coated mesh. When the voltage is applied, the metal reacts with water molecules, and oxides and hydrogen are form. This simple electrochemical reaction is:



The advantages of anodization are uniform deposition, ease of processing, and precise thickness control [Nelms, 1998]. During anodization, thinner areas of oxide have lower resistance than the thicker areas. Therefore, thinner areas get deposited faster, and the entire board results in a uniform defect free deposition. Also, the processing condition is fairly lenient. The final thickness is a strong function of final applied voltage, and it not

easily affected by processing time, composition of the bath, temperature, or current. When a voltage is set, a certain thickness of film can be expected. There is, however, a limit on the maximum attainable film thickness. The film will continue to grow until the applied electric field is equal to the breakdown field of the oxide. For Ta, the ratio of final thickness to final voltage is  $16 \text{ \AA/V}$ , and the maximum attainable film thickness is approximately  $1.1 \text{ }\mu\text{m}$ . Therefore, if the final voltage is set as  $70 \text{ V}$ , then the final thickness will be  $1120 \text{ \AA}$ .

Sol-gel deposition and hydrothermal deposition are solution based chemical processes. Although these are not as widely used as other processes, relatively low temperature and low cost make them quite attractive. Sol-gel process involves thermally removing the organic part of a liquid phase metal-organic solution to create a thin film of metal oxides. It starts by transforming metal-organic compounds such as metal alkoxides into liquid phase by dissolving in alcohol. Then, the solution is gelated by a hydrolysis reaction to form a polymeric network or a colloidal network. The gelated solution can then be spin coated or dip coated onto a substrate. Final cure is needed to complete the process. Some of the advantages of sol-gel deposition include high degree of chemical homogeneity, low cost, and possible high dielectric constant. Although at least  $500^\circ\text{C}$  curing temperature is required, high dielectric constant of above 1000 can be achieved. Lead zirconate titanate (PTZ) sol-gel technology can create specific capacitance of  $2000 \text{ nF/cm}^2$ . This curing condition is well over organic substrate limit, but the curing can be done separately on a copper foil and then laminated onto an organic substrate.

### 2.5.5 Commercialized Capacitor Technologies

Dupont is one of the leading developers of embedded passive technologies. Interra™ ceramic thick film capacitors are based on a doped barium titanate and a glass, and they have high dielectric constant of 1800 – 2000 with dissipation factor of less than 2.5% [DuPont website]. Moreover, Interra™ HK™ planar capacitor series offer low dielectric constant of 3 – 11 with dissipation factor of less than 1%. These are very stable with respect to temperature and frequency, and they are compatible with existing PWB processes. 3M™'s Embedded Capacitor Material consists of barium titanate filled epoxy sandwiched between two copper foils [3M website; Diaz-Alvarez and Krusius, 2000]. It has dielectric constant of 15 – 23 with dissipation factor of less than 1%. Table 2.4 lists some of the commercialized capacitor technologies.

Table 2.4. Summary of commercialized capacitor technologies

	Dupont Interra™ ceramic thick film	Dupont Interra™ HK™ planar laminate	3M Embedded Capacitor Material	Sanmina Buried Capacitance™ ZBC-2000® [Sanmina website]
Dielectric material	Fired ferroelectric paste on Cu foil	Cu-clad polyimide	BaTiO <sub>3</sub> in epoxy	Cu-clad FR4
Dielectric constant	1800 – 2000	3.5 – 11	16	4.2
Specific capacitance (nF/cm <sup>2</sup> )	~40	0.14 – 0.8	1	0.07
Dissipation factor (%)	< 2.5	0.3 – 1	0.6	1.5



## **2.6 Reliability Qualification Tests and Numerical Modeling of Embedded Passives**

Significant progresses have been made over the last several years on embedded passive material and process development. However, the reliability and physics of failure have received little attention. By embedding, thermal and mechanical behaviors of these new materials and processes bring increased complexities, and they must be evaluated to successfully control the tolerance and drift in electrical properties.

Some of the common reliability qualification tests include:

**Air to air accelerated reliability test** – This test is a commonly used methodology in the electronic packaging industry to assess the thermo-mechanical reliability of the components. It is also known as MIL-STD-883 Method 1011 condition B, IPC-SM-785, or JESD22-A104-B. Components are cycled between two extreme temperatures such as -55 and 125°C. Each cycle is 20 minutes long with 10 minute dwell time. The components must survive 1000 cycles to qualify.

**Standard Steady State Humidity Life Test** – This test is a standard methodology to evaluate the moisture resistance of electronic packages. It is also known as EIA/JESD22-A101-B. Components must survive 1000 hours at constant temperature of 85°C and 85% relative humidity (RH) to qualify.

**Highly Accelerated Stress Test (HAST)** – This test is also known as pressure cooker test or the JESD22-A102-B. It activates similar failure mechanism as steady state humidity life test but at a much higher stress. The components must survive 96 hours at 121°C and 100% RH to qualify.

There is very limited literature exists on study of thermo-mechanical reliability of embedded passives. Some have performed various qualification tests, but they are limited to certain materials or processes. Moreover, even less literature exist on numerical analyses or analytical studies that provide design guidelines. Several who have investigated the reliability of embedded passives are Fairchild [1997], Zhou [2002], Yang [2001], and Damani [2004].

Fairchild [Fairchild et al., 1997] fabricated embedded resistors on a flexible thin-film test vehicle. It contained 50  $\mu\text{m}$  thick polyimide film with chromium silicate (CrSi) resistive material. The sheet resistance of 100  $\Omega/\text{sq}$  was used develop resistance in the range of 50  $\Omega$  - 200 k $\Omega$ . Several qualification tests were performed based on temperature, voltage, and moisture effects. Thermal shock between -55 and 160°C are performed for 300 cycles with 20 minute cycle period, and less than 2% change was observed. Steady state temperature humidity test at 85°C/85RH for 500 hours show increase in resistance of 1.2%. Power dissipation test was conducted by applying 200 mW of power. It was observed that larger resistors survived, but smaller ones failed. Although variety of reliability tests was performed, test vehicle had fabrication problems that the validity of these reliability evaluations is questionable. The copper metallization on some devices were reported to be extremely over-etched, while some were under etched. The resulting resistors values were larger than designed values, and most devices above 50k $\Omega$  were never functional.

Zhou [Zhou et al., 2002] has performed variety of qualification tests to investigate the reliability of embedded resistors and capacitors. Commercially available DuPont Interra<sup>TM</sup> ceramic thick film resistors and 3M C-Ply capacitors were fabricated on organic

substrates. Thermal cycling was performed between -40 to 125°C for 1000 cycles. Each cycle was 1 hour long with ramp and dwell time of 15 minutes. Among 205 resistors and 30 capacitors tested, none failed and no significant change in electrical properties was observed. Others who have conducted qualifications tests are Borland [Borland et al., 2003] and Schatzel [Schatzel, 2003]. Borland also investigated Dupont Interra<sup>TM</sup> ceramic resistors and capacitors by thermal cycling and temperature humidity tests.

One of the earlier numerical models of embedded capacitors was developed by Yang [Yang, 2001]. He has developed simple electrostatic models using isotropic temperature independent materials to evaluate the edge effect and electrical interference of neighboring capacitors. Generally, one of the electrodes on a parallel plate capacitor is larger than the other due to fabrication issues, and sometimes this can cause slight change in the capacitance due to the fringing effect. Although the change is usually negligible, Yang reported that it is almost nonexistent if the ratio of diameter and thickness of dielectric material is larger than 200.

Damani [Damani et al., 2004] has fabricated test boards and conducted various qualification tests including thermal cycling, HAST, and constant temperature and humidity tests. Furthermore, he developed physics-based numerical models to investigate the thermo-mechanical loading experienced during the fabrication process and the effect of capacitor location relative to the neutral point of PCB. He has found that various qualification tests and fabrication process conditions have significant effect on the electrical parameters. Although he has performed extensive studies on embedded passives, his results are based on several assumptions. The number and types of embedded passives on the tests boards are very limited, and they are not fully embedded.

The top capacitor electrode and entire resistor structures are not covered. Also, his models do not account for pads, vias, traces, and other essential components that can impact the reliability assessments.

It is clear that there are very limited amount of work done in embedded passive reliability assessments.

This thesis aims to fabricate embedded passives in a multilayered organic substrate, perform extensive electrical and mechanical reliability tests, and develop physics-based models to predict the thermo-mechanical reliability of embedded passives. Embedded capacitors and resistors with different geometric shapes, planar dimensions, and thus different electrical characteristics have been fabricated on two different test vehicles. Capacitors are made with polymer/ceramic nanocomposite materials and have a capacitance in the range of 50 pF to 1.5 nF. Resistors are carbon ink based Polymer Thick Film (PTF) and NiCrAlSi and have a resistance in the range of 25  $\Omega$  to 400 k $\Omega$ . High frequency measurements have been done using Vector Network Analyzer (VNA) with 2 port signal-ground (S-G) probes. Accelerated thermal cycling (-55 to 125°C) and constant temperature and humidity tests (85°C/85RH) based on JEDEC and MIL standards have been performed. Furthermore, physics-based numerical models are being developed, and the results from the numerical models will be validated using the experimental data. By focusing on the design and fabrication as well as the experimental and theoretical reliability assessments, this thesis aims to contribute to the overall development of embedded passive technology for Digital and Radio Frequency (RF) applications.

## **CHAPTER III**

### **OBJECTIVES OF THE RESEARCH**

The potential advantages of embedded passives are very promising. By embedding the passive components within the substrate, the embedded passives could reduce the system real estate, eliminate the need for surface-mounted discrete components, eliminate lead-based interconnects, enhance electrical performance and reliability, and potentially reduce the overall cost. Even with these advantages, embedded passive technology, especially for organic substrates, is at an early stage of development, and thus a comprehensive experimental and theoretical modeling study is needed to understand the fabrication and reliability of embedded passives before they can be widely used.

Based on the literature review, some of the topics that need to be addressed are:

- Numerous researches have been focused on the material and process developments in terms of cost and compatibility with existing systems; however, very little attention has been given to thermo-mechanical reliability of embedded passives.
- Although tolerance and yield are very important concerns, there are very limited studies on the effect of process conditions.
- There are very limited numerical analyses that can give upfront design guidelines to improve the reliability.

This research aims to address all of the above topics. In particular, the primary objectives of this research are to fabricate embedded resistors and capacitors in a multilayered organic substrate, perform extensive electrical and mechanical reliability tests, and develop physics-based models to predict the thermo-mechanical reliability of embedded passives. Two test vehicles with different geometric shapes and planar dimensions of embedded resistors and capacitors have been fabricated, and extensive reliability tests based on temperature and humidity have been performed. The physics based numerical models have been developed and correlated with the experimental results.

To achieve the objectives of the research, this work aims to:

- Fabricate embedded resistors and capacitors in a multilayered organic substrate using sequential build-up (SBU) process.
- Subject the test vehicles to various reliability qualification tests such as air-to air thermal cycling and steady state temperature and humidity tests to investigate the thermo-mechanical reliability.
- Cross-section the test boards to visually investigate any damages or failures.
- Perform high frequency measurements of embedded capacitor to investigate the useful frequency range.
- Investigate test board warpage using shadow moiré interferometry.
- Develop 2-D and 3-D parametric models to study the effects of geometric features of embedded capacitors.
- Develop physics based process models to study the effect of SBU process condition.

- Perform thermo-mechanical electrostatic analysis to study the change in capacitance due to thermo-mechanical deformations and correlate the results with the experimental data.

## **CHAPTER IV**

### **TEST VEHICLE DESIGNS**

Two test vehicles are designed with different geometric shapes, planar dimensions, and thus different electrical characteristics. Test Vehicle 1 (TV1) is a 6" x 6" epoxy based board with 8 metal layers as shown in Figure 4.1. It includes both resistors and capacitors on metal layer 7, and they are connected to copper probing pads on metal layer 8 through microvias. The core is a 6 layer subcomposite made of EI Driclad<sup>®</sup> laminate. Driclad<sup>®</sup> is a high  $T_g$  FR4 with dielectric constant of  $\sim 4.0$  and dielectric loss of 0.014, and it is lead free assembly compatible. Capacitor dielectric is based on polymer-ceramic nanocomposite with dielectric constant of 22, and resistors are carbon ink based PTF with sheet resistances of  $10\ \Omega/\text{sq}$  or  $10\ \text{k}\Omega/\text{sq}$ . These components are divided into a grid of 4 rows and 5 columns. Inside of each block, there are either resistors or capacitors in different geometries and dimensions.



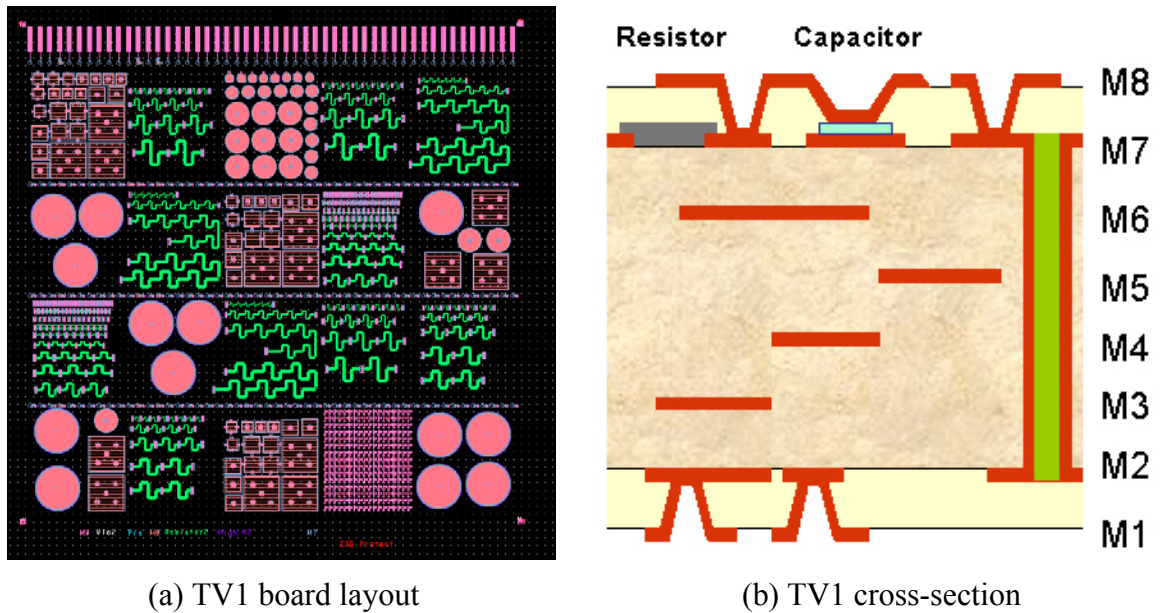
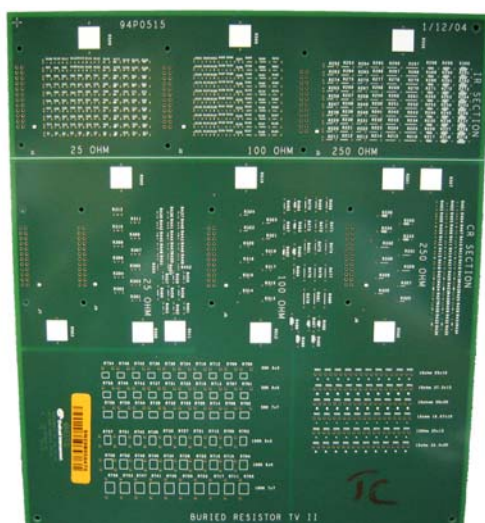
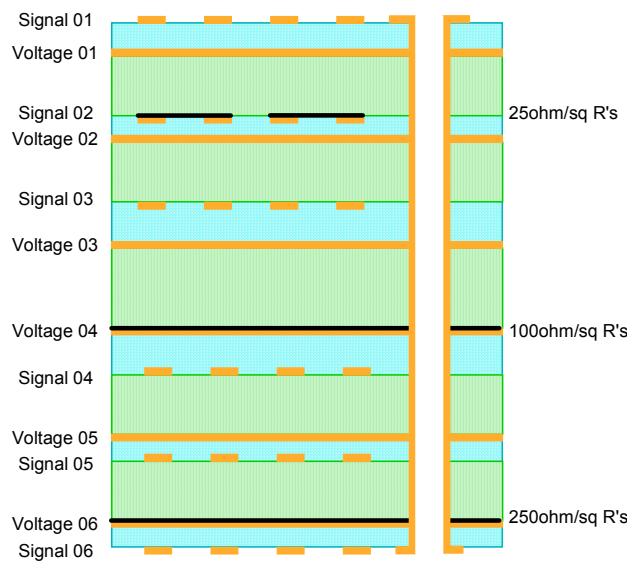


Figure 4.1. Test Vehicle 1 layout and cross-section

Test Vehicle 2 (TV2) is a 9" x 10.25" epoxy based board with 12 metal layers as shown in Figure 4.2a. It contains different planar dimensions of resistors only and no capacitors are included. The resistors are made of NiCrAlSi TCR foil from Gould Electronics Inc. Once again, all dielectric is EI DriClad<sup>®</sup> laminate. Resistors are divided into 3 sections. The top section is defined for insulation resistance testing of resistor elements to adjacent circuit features. Resistors in this section are stitched together, but can be probed individually through intermediate Plated Through Holes (PTH). The middle and bottom section of the boards are set up for contact resistance testing. Resistors in the middle section are all tied into the 2 x 12 headers in that section. Furthermore, there are 4 large (0.4" x 0.4") resistors per layer that can be used for evaluating sheet resistance tolerance of the raw material. Three different sheet resistances used are 25  $\Omega$ /sq, 100  $\Omega$ /sq, and 250  $\Omega$ /sq. They are embedded in three different layers as shown in Figure 4.2b.



(a) TV2 board layout



(b) TV2 cross-section

Figure 4.2. Test Vehicle 2 layout and cross-section

Following sections will describe the capacitors and resistors in detail.

#### 4.1 Capacitors

Table 4.1 lists the different shapes and sizes of parallel plate capacitors, and Figure 4.3 shows some of the capacitor layouts on TV1.

Table 4.1. Shape and sizes of various capacitors on TV1

Shape	Size (diameter or length in mils)	Probe Location (center or edge)	Typical Initial Capacitance (pF)
Circle 1	110	Edge	40 – 110
Circle 2	145	Center	50 – 130
Circle 3	240	Center	130 – 380
Circle 4	440	Center	500 – 1400
Square 1	110	Center and Edge	30 – 90
Square 2	160	Center and Edge	70 – 240
Square 3	360	Center	350 – 1050

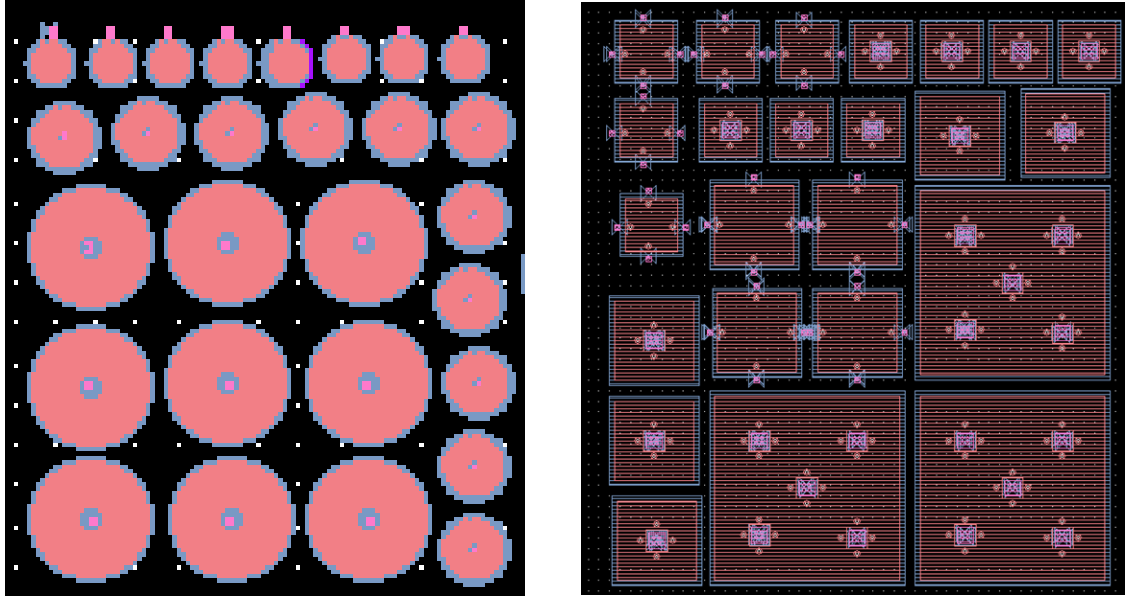


Figure 4.3. Circular and square capacitor designs on TV1

As listed in Table 4.1, wide variety of geometric shapes and planar dimensions of capacitors was designed to evaluate the process ability and reliability. There are four sizes of circular and three sizes of square capacitors that range from 100 mils to 440 mils. The capacitance ranges from 30 pF to 1.5 nF, and specific capacitance ranges from 1 to 1.5 nF/cm<sup>2</sup>. Although some capacitors have same size and geometric shape, there is a wide variation in the initial capacitance between the test boards. This is due to the different dielectric thicknesses obtained by using different processing conditions to fabricate the test boards. Electrical characterization of capacitors is presented in detail in the following chapter.

In order to properly measure the capacitance, microvias provide the electrical connections from the top and bottom electrodes to the probe pads on the surface. These are located either on the center or edge of the capacitor as shown in Figure 4.4.

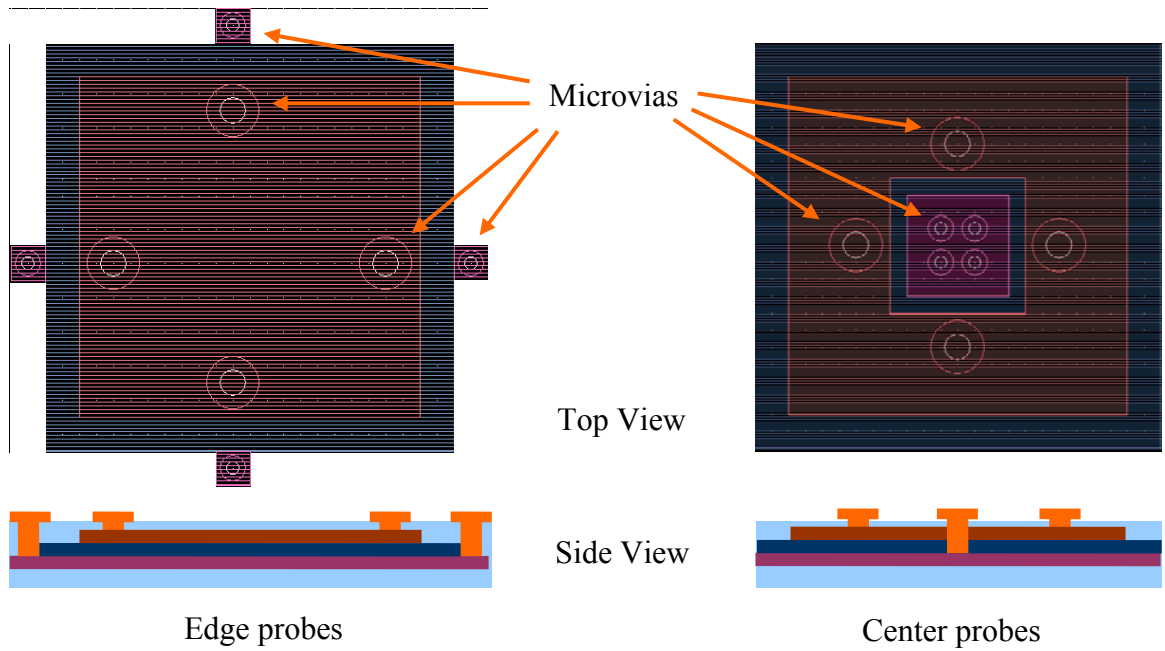


Figure 4.4. Edge probes and center probes design

For center probe connections, the top electrode has a square shape cutout in the center for the microvias to connect the bottom electrode. This square shape cutout is 40 mils in length to fit four microvias, while the other cutouts are 25 mils in diameter to fit a single microvia. For edge probe connections, the top electrode does not have a cutout in the center, but the bottom electrode has little tabs extending out on the side for the microvias to connect. Therefore, the edge probes provide a slightly larger area and thus higher capacitance than the same size center probe capacitors, but they also require a slightly larger clearance room to implement. In terms of electrical characteristics, center probe is preferred do to its lower parasitic inductance.

## 4.2 Resistors

Figure 4.5 shows some of the resistor layouts on TV1, and Table 4.2 lists the planar dimensions and number of squares of the resistors on TV1.

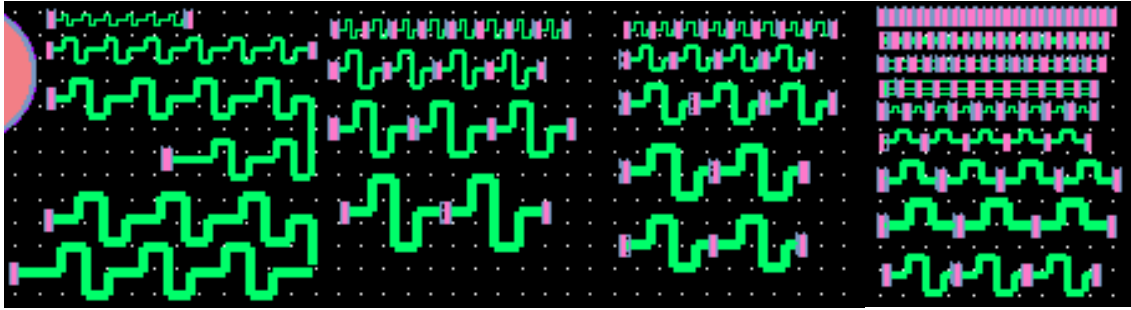


Figure 4.5. Various geometric shapes and sizes of resistors on TV1

Table 4.2. Dimensions of various embedded resistors on TV1

Width (mil)	Length (mil)	Number of Corners	Number of Squares
10	10	0	1
10	60	4	10
10	90	6	15
10	140	6	20
10	575	36	100
20	20	0	1
20	120	4	10
20	180	6	15
20	280	6	20
20	1130	36	100
30	30	0	1
30	180	4	10
30	270	6	15
30	425	6	20
30	1940	36	100
40	40	0	1
40	240	4	10
40	360	6	15
40	560	6	20
40	2470	38	100

As listed in Table 4.2, a wide variety of resistors are designed to evaluate the processability and reliability of the resistors. These resistors are made of carbon ink based PTF material from Asahi. Two sheet resistances of  $10\ \Omega/\text{sq}$  and  $10\ \text{k}\Omega/\text{sq}$  are used to cover the resistance range of  $10\ \Omega - 400\ \text{k}\Omega$ . Some resistors have same nominal resistance even though they have different width by maintaining the same number of squares. Usually, smaller resistors are desired to minimize the PWB footprint area, but these smaller resistors have less area to dissipate the heat that it generates. If more heat is generated than it can dissipate, resistors can be permanently damaged.

Similarly, wide variety of resistors is designed for TV2. These resistors are made of NiCrAlSi thin film foils from Gould Electronics Inc. Three sheet resistances of  $25\ \Omega/\text{sq}$ ,  $100\ \Omega/\text{sq}$ , and  $250\ \Omega/\text{sq}$  are used to cover the resistance range of  $10\ \Omega - 100\ \text{k}\Omega$ . Figure 4.6 shows some of the resistor layouts on TV2, and Table 4.3 lists the planar dimensions.

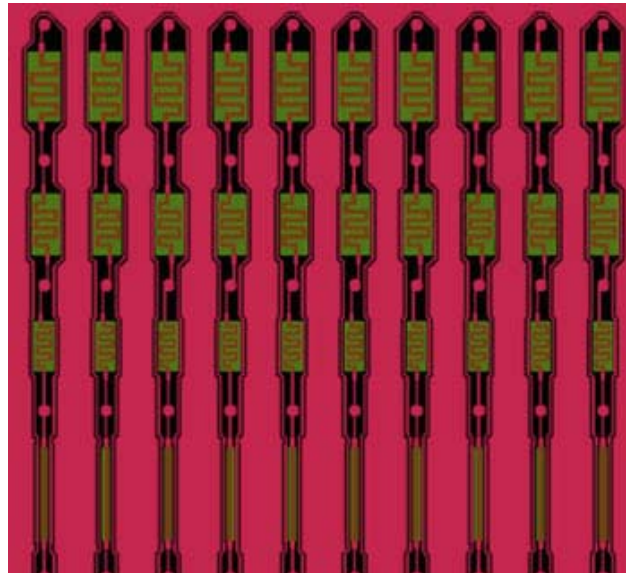


Figure 4.6. Various resistors on TV2

Table 4.3. Dimensions of various embedded resistors on TV2

25 $\Omega$ / square			100 $\Omega$ / square			250 $\Omega$ / square		
Length (mils)	Width (mils)	Nominal ( $\Omega$ )	Length (mils)	Width (mils)	Nominal ( $\Omega$ )	Length (mils)	Width (mils)	Nominal ( $\Omega$ )
40	10	100	10	10	100	1955	5	97.8K
50	12.5	100	15	15	100	2332	6	97.2K
60	15	100	20	20	100	2695	7	96.3K
10	25	10	100	10	1000	347	10	8.7K
15	37.5	10	120	12	1000	416	12	8.7K
20	50	10	80	8	1000	271	8	8.5K
10	16.7	15	10	13.33	75	120	10	3K
15	25	15	15	20	75	144	12	3K
20	33.3	15	20	26.67	75	96	8	3K
10	12.5	20				188	10	4.7K
15	18.75	20				150.4	8	4.7K
20	25	20				225.6	12	4.7K
15	15.1	24.9				997	5	49.9K
20	20.1	24.9				1193	6	49.7K
25	25.1	24.9				1386	7	49.5K
30	10	75						
45	15	75						
60	20	75						
400	400	25	400	400	100	400	400	250



## CHAPTER V

### FABRICATION OF EMBEDDED PASSIVES

The three main fabricated features for TV1 are capacitors, resistors, and microvias with probing pads. Figure 5.1 shows some of the clean room equipments that have been used. For additional details on the fabrication, please refer to Packaging Research Center at Georgia Institute of Technology [PRC website]. The following sections describe the sequential build up (SBU) process steps and processing conditions.



(a) Profilometer



(b) Spin Coater



(c) Vacuum Laminator



(d) Exposure Tool



(e) Electroplating Bath

Figure 5.1. Clean room equipments



## 5.1 Capacitor Fabrication Steps and Processing Conditions

Capacitor layer is the first processing step for TV1. This process starts with the bare core 6-metal layer board with bottom copper electrode already laminated as shown in Figure 5.2. Figure 5.3 shows the general overview of capacitor fabrication process.

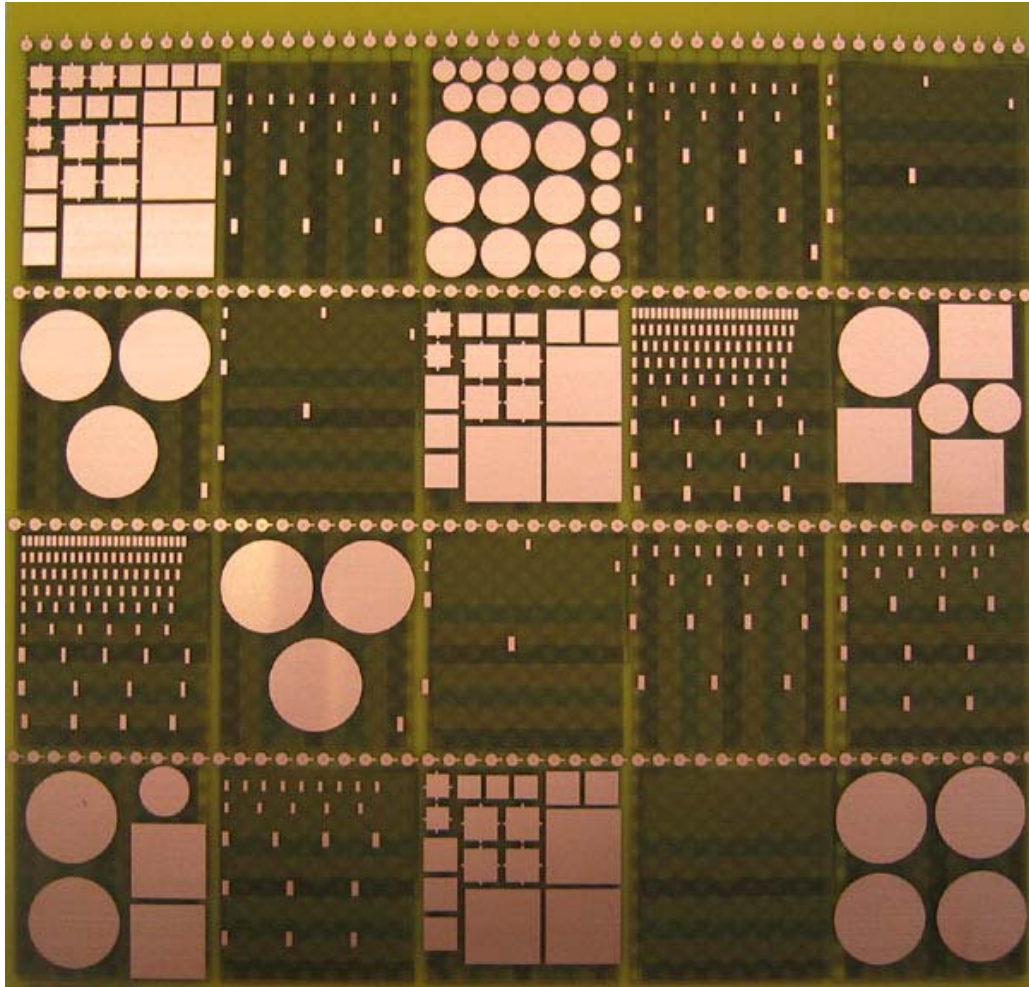


Figure 5.2. Bare board with bottom electrodes and resistor pads

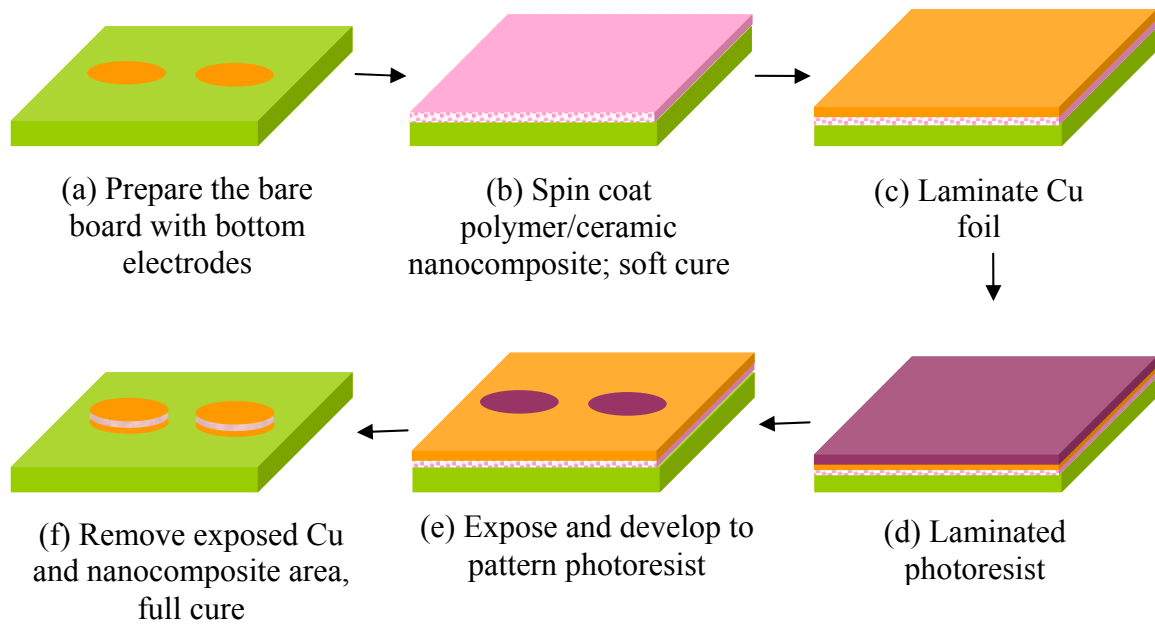


Figure 5.3. Overview of capacitor process

- To prepare for the lamination of polymer/ceramic dielectric, the bare board was first surface treated with acetone to remove any organic residues. Then, it was microetched to roughen up the surface of bottom copper electrodes, and bond film was applied to further enhance the adhesion (Figure 5.3a).
- The polymer/ceramic nanocomposite dielectric was prepared by thoroughly mixing barium titanate based polymeric resin with hardener and thinner. The mixture was spin coated onto the bare board to achieve a nominal thickness of 20  $\mu\text{m}$ . Then, the board was soft cured at 65°C for 45 minutes (Figure 5.3b).
- For top copper electrode, a 15  $\mu\text{m}$  copper foil was vacuum laminated, and heat press was performed to strengthen the lamination (Figure 5.3c).

- Positive acting liquid photoresist Shipley SP20-29 was spin coated onto the board (Figure 5.3d).
- The top electrode patterns are UV exposed with a positive mask and developed (Figure 5.3e).
- The resulting exposed copper and nanocomposite materials were removed. The board is fully cured at 150°C for 1 hour to complete the capacitor process. This simple and low temperature process exhibited high yield with specific capacitance of 1.5 nF/cm<sup>2</sup> (Figure 5.3f). Figure 5.4 shows the fabricated capacitors, and Appendix A lists the detailed processing conditions

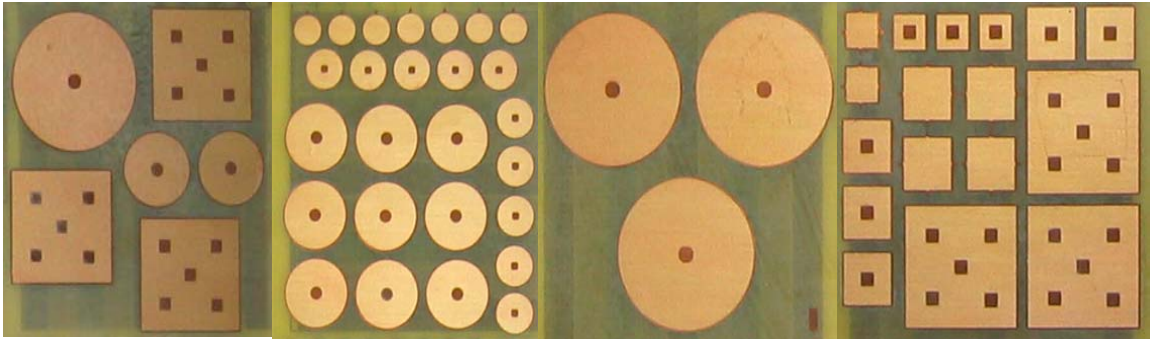


Figure 5.4. Pictures of fabricated capacitors

## 5.2 PTF Resistor Fabrication Steps and Processing Conditions for TV1

Once the capacitor layer is completed, resistor layer was fabricated using a screen print lift-off process. This process starts with the bare board with resistor copper pads already attached. Figure 5.5 shows the general overview of resistor fabrication process.

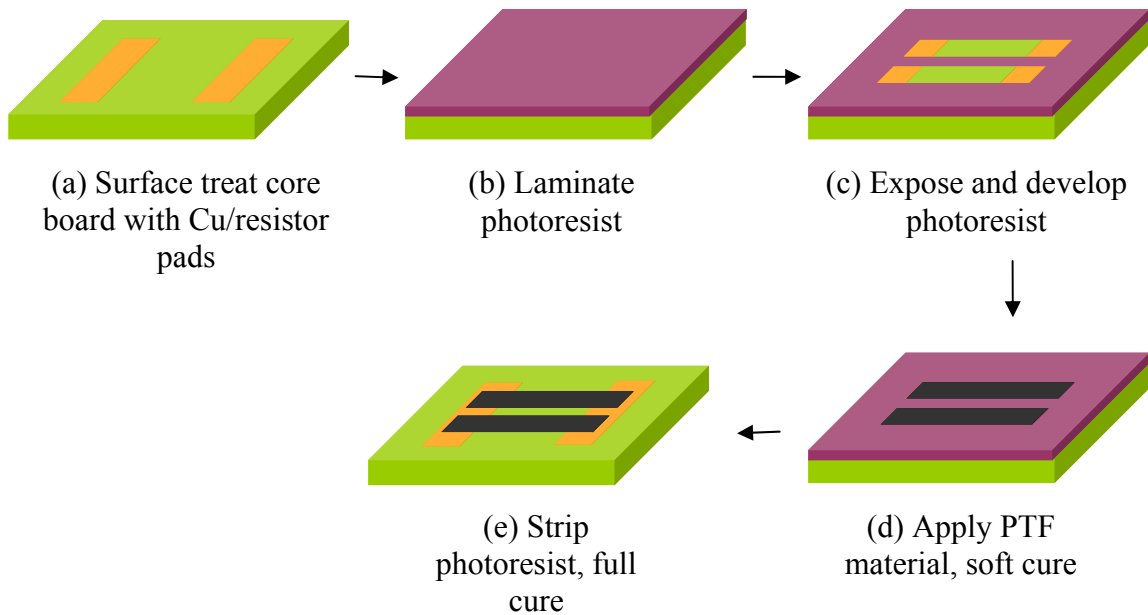


Figure 5.5. Overview of resistor process

- The bare board with capacitors already processed was treated with acetone and microetch solution to thoroughly remove any organic residues and roughen up the surface to improve the adhesion (Figure 5.5a).
- Negative acting dry film photoresist DuPont Riston™ 4615 was vacuum laminated. This 30  $\mu\text{m}$  thick photoresist was used to create a deep resist trace (Figure 5.5b).
- The resist traces are UV exposed with a negative mask and developed (Figure 5.5c).
- Carbon ink based PTF supplied by W.R. Grace was screen printed into the developed negative pattern of the resist trace. Both 10  $\Omega/\text{sq}$  and 10  $\text{k}\Omega/\text{sq}$  sheet resistances were used (Figure 5.5d).
- The resist materials are soft cured, and the photoresist was stripped.

- The board was fully cured at 150°C for 1 hour to complete the resistor process (Figure 5.5e). Figure 5.6 shows the fabricated resistors, and Appendix B lists the detailed processing conditions.

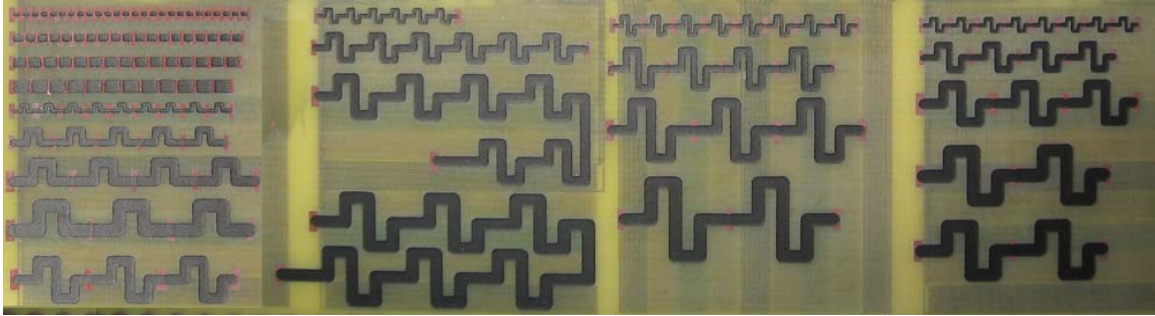


Figure 5.6. Pictures of fabricated resistors

### 5.3 Microvia Fabrication Steps and Processing Conditions for TV1

Once the capacitor and resistor layers are completed, microvia was added to complete the TV1 fabrication. Figure 5.6 shows the general overview of resistor fabrication process.

- The bare board with capacitors and resistors already processed was treated with acetone and microetched to thoroughly remove any organic residue and roughen up the surface to improve adhesion (Figure 5.7a).
- Photo-imageable negative liquid epoxy Vantico Probimer 7081 was spin coated to achieve a nominal thickness of 30  $\mu\text{m}$ . Once the board was exposed, it was baked at 100°C for 1 hour to fully crosslink the exposed photoresist area. GBL solvent at room temperature was used to develop the unexposed photoresist area, and the board was fully cured at 160°C for 1 hour (Figures 5.7b and 5.7c).

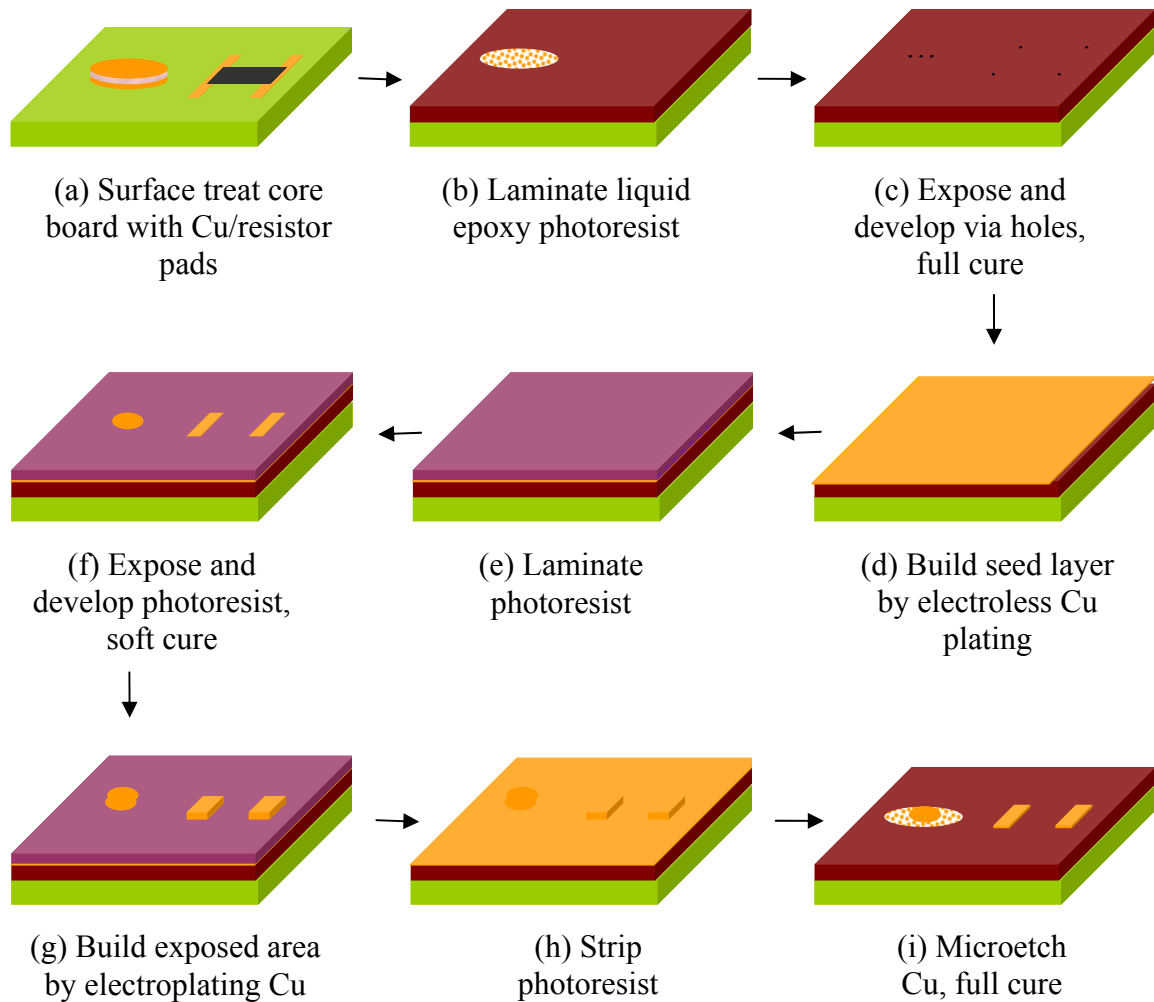


Figure 5.7. Overview of microvia and copper probing pad process

- Conventional electroless copper plating was performed to build a thin seed layer for microvias (Figure 5.7d).
- Conventional photolithography was performed with DuPont Riston 4615 dry film to pattern the probing pads. This photoresist is a 30  $\mu\text{m}$  thick negative photoresist (Figures 5.7e and 5.7f).
- Copper was electroplated to build the microvias and probing pads (Figure 5.7g). Finally, the photoresist was stripped, and the copper seed layer was



microetched to complete the process (Figures 5.7h and 5.7i). Figure 5.8 shows the completed TV1, and Appendix C lists the detailed processing conditions.

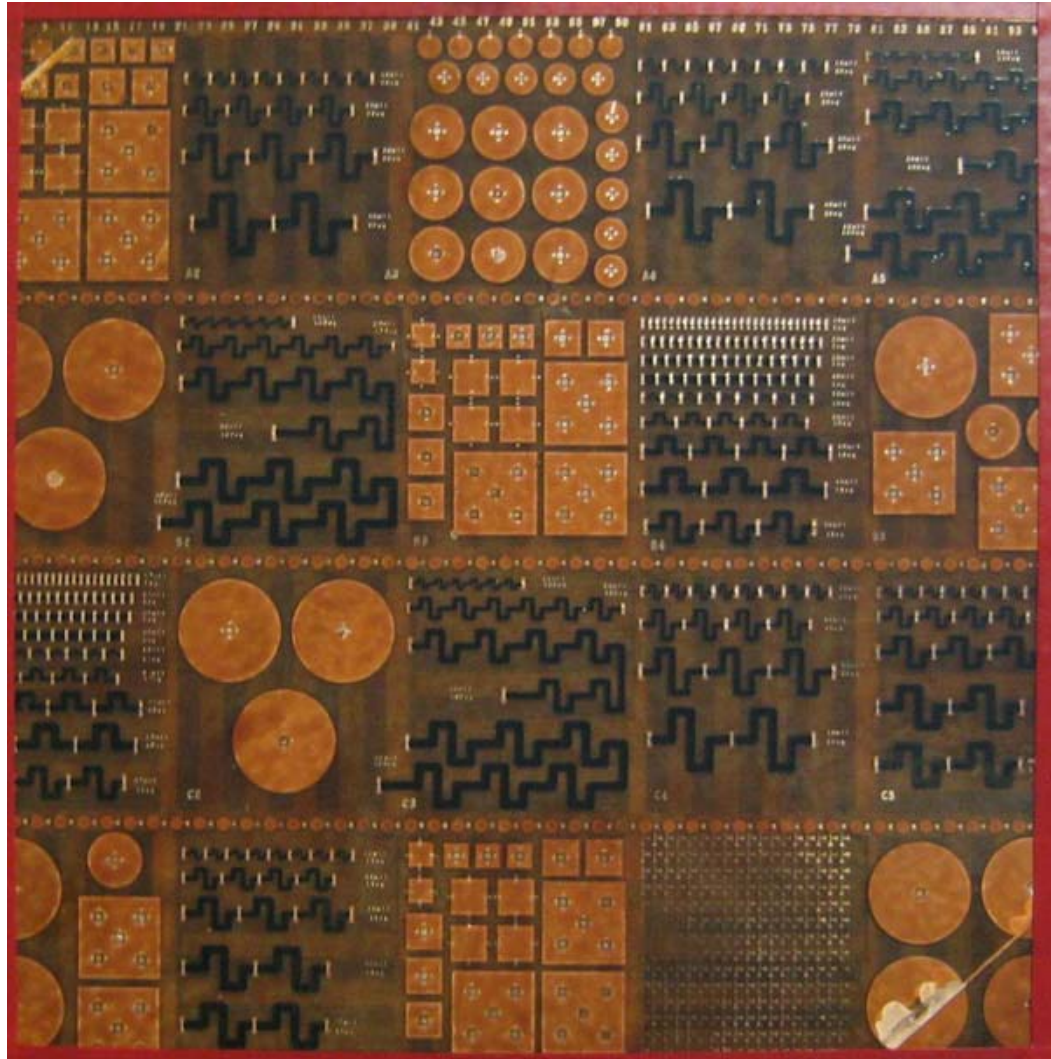


Figure 5.8. Picture of completed TV1

#### 5.4 NiCrAlSi Foil Resistor Fabrication Steps and Processing Conditions for TV2

The processing steps and conditions of Gould TCR NiCrAlSi foil resistors were obtained from Gould Electronics Inc. Figure 5.9 shows the general overview of

NiCrAlSi foil resistor fabrication process. The Gould resistor foils contain a sputtered NiCrAlSi thin film layer on the rough, matte surface of a copper foil. Therefore, the foil is laminated onto a bare board and two step etching processes are performed. The first etch solution removes both copper and NiCrAlSi to define the resistors dimensions. The second etching solution selectively removes the copper. All the fabrication of TV2 was done at EI Technologies, Inc. Table 5.1 lists the two step etching processes, and Figure 5.10 shows the picture of TV2.

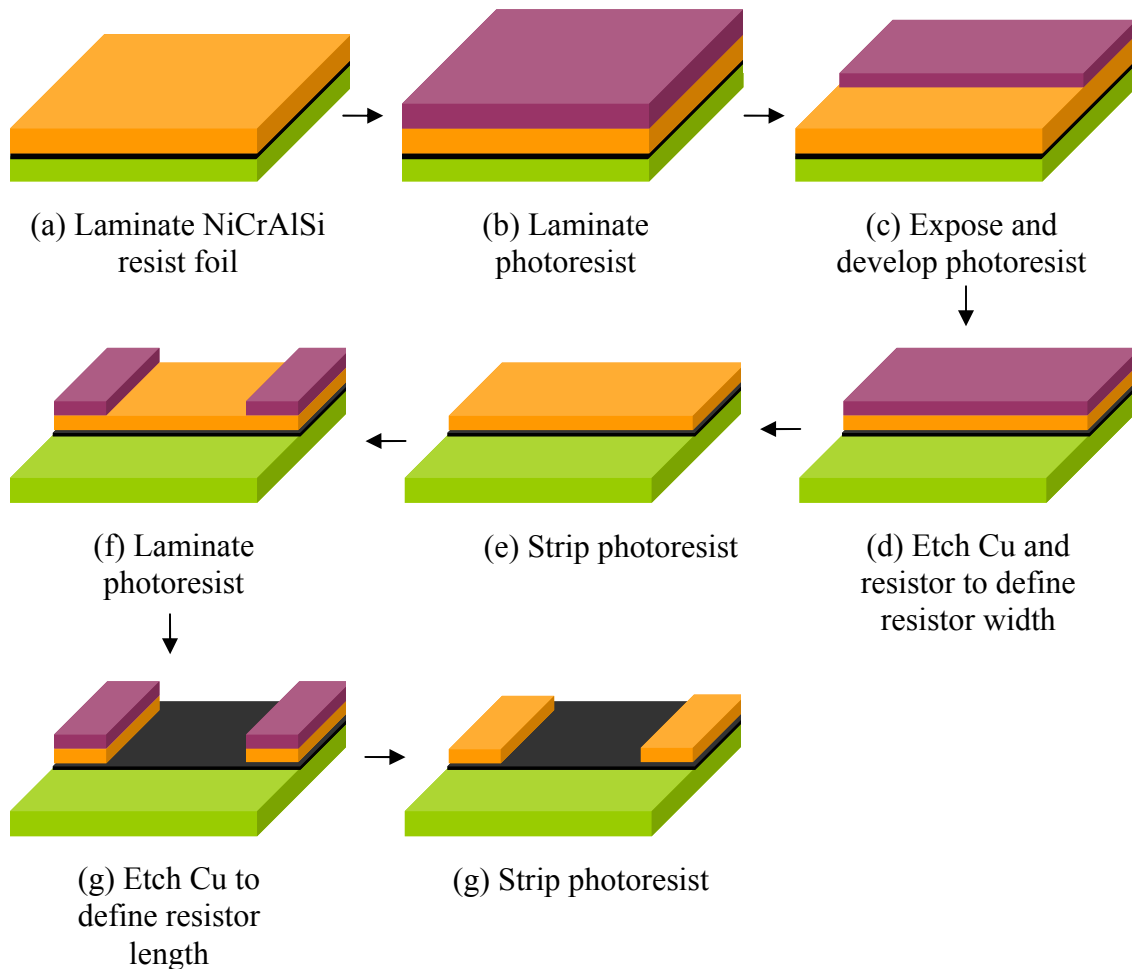


Figure 5.9. Gould resistor fabrication process [Gould website]



Table 5.1. NiCrAlSi Etching process

First etch process (removes both copper and resist, (Figure 5.9d)	Cupric Chloride solution: 200 g/l CuCl <sub>2</sub> 60 g/l HCl at 52°C
Second etch process (removes copper only, Figure 5.9g)	267 g/l NH <sub>4</sub> Cl 1 g/l ortho-phosphoric acid 392 ml NH <sub>4</sub> OH 10 g/l CuCl <sub>2</sub> at 54 – 60°C

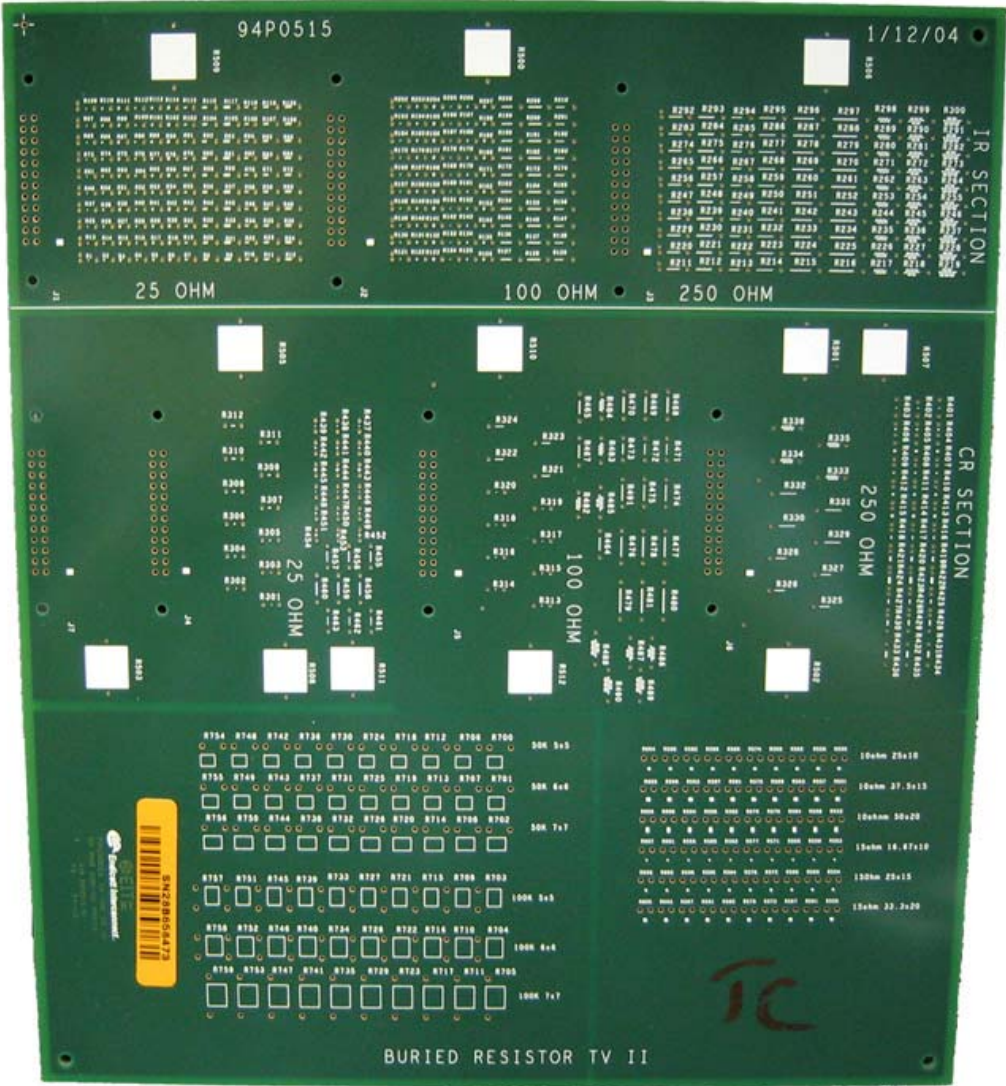


Figure 5.10. Picture of completed TV2

# CHAPTER VI

## CHARACTERIZATION OF RESISTORS AND CAPACITORS

### 6.1 Ideal Capacitor

Usually, the electrical characteristic of storing charge is dominated in a capacitor that it acts as a capacitor. However, a capacitor also has some resistance and inductance as parasitic known as Equivalent Series Resistance (ESR) and Equivalent Series Inductance (ESL). ESR exists due to intrinsic resistance present in the conducting plates and other leads, and ESL exists due to inductance associated with the parallel plates and leads. For most capacitor electrodes that are made of copper or aluminum, ESR is negligible. However, if the plates are very thin or if they are made of valve or refractory metals, then ESR should be considered more seriously. ESL is dependent on the frequency at which the capacitor operates. As shown in Figure 6.1, the capacitor impedance increases as frequency increases.

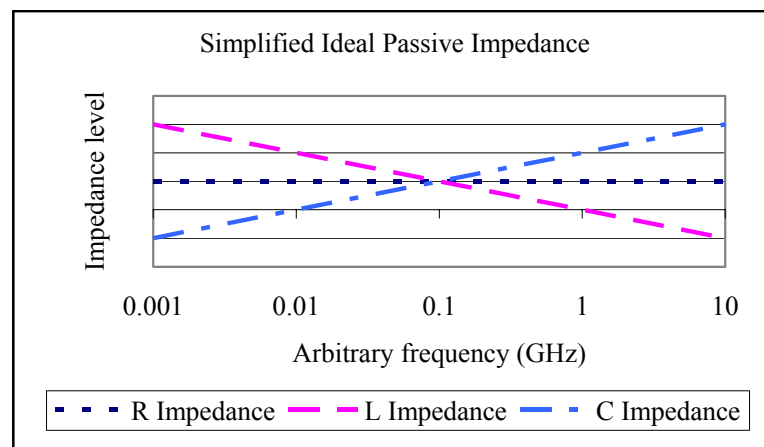


Figure 6.1. Frequency dependent ideal passive impedance

At a certain frequency known as resonant frequency, the inductive characteristic becomes more dominant, and the capacitor no longer acts as capacitor but as an inductor. This marks the upper limit of the useful frequency range of a capacitor.

In comparison to surface mount counterparts, embedded capacitor has typically two orders of magnitude smaller parasitic inductance. The two main reasons are: 1) smaller current loop and 2) reduction in self-inductance by mutual inductance. Surface mounts have much larger current loop, as the current has to travel above the surface through the leads. This advantage due to smaller current loop makes embedded capacitors more attractive in high frequency applications.

## 6.2 High Frequency Measurement

The high frequency performance of TV1 440 mils circular capacitor was measured with Vector Network Analyzer (VNA) and two Ground-Signal (G-S) probes as shown in Figure 6.2. This equipment is capable of measuring high frequency up to 3 GHz. The pitch of the probes is 500  $\mu\text{m}$ , and the locations of probes with respect to a capacitor are shown in Figure 6.3.



Figure 6.2. Vector Network Analyzer setup

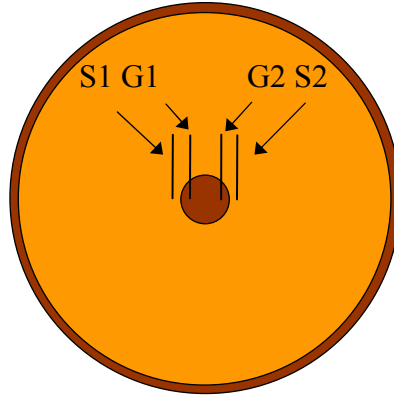


Figure 6.3. Ground and signal probe locations

As shown in Figure 6.3, the ground probes are connected to the bottom electrodes, and the two signal probes are connected to the top electrodes. The types and locations of probes can cause significant inductance in the measurements [Chen et al., 2000]. In order to minimize any parasitic from the connection, these probes are located closely together to minimize the loop inductance. Also, two-port measurement was performed to minimize the chance of loose connections. The calibration of the equipment was based on commonly used Short-Open-Load-Thru (SOLT) calibration technique [Cascade Microtech website]. Entire calibration and actual measurements were performed by the research engineers at PRC. The measurement results are shown in Figures 6.4 and 6.5.

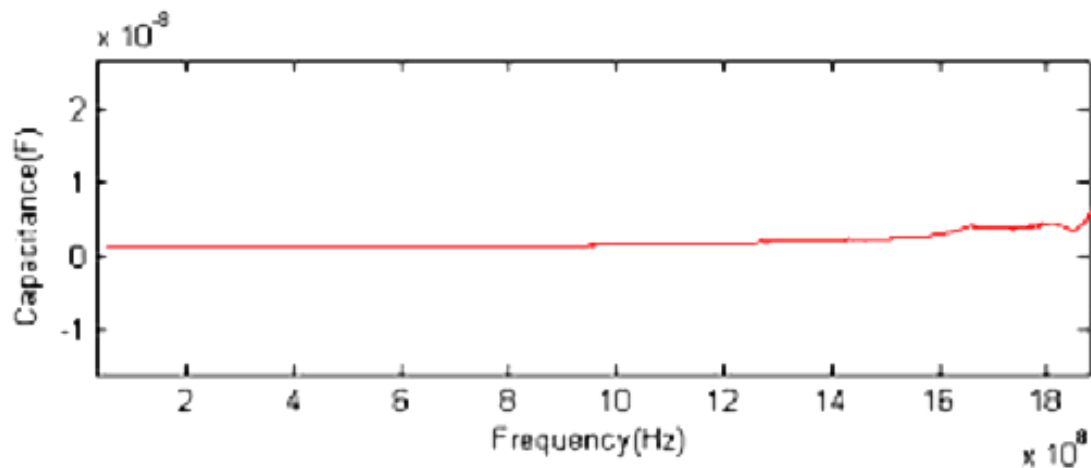


Figure 6.4. Extracted capacitance of the structure.

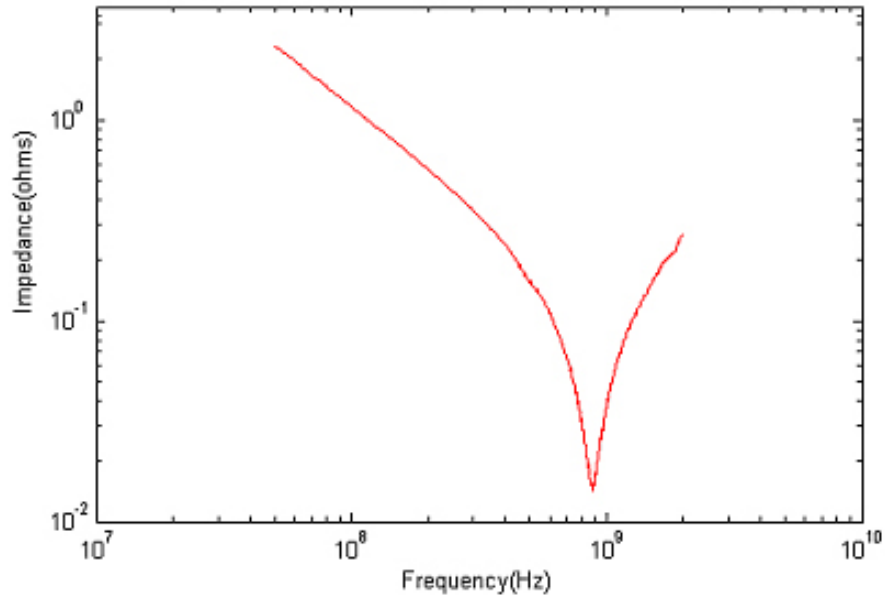


Figure 6.5. Impedance profile of the capacitor.

Figure 6.4 shows the impedance measurement with respect to frequency. Frequency range of 50 MHz – 2 GHz was scanned, and the capacitor resonates at around 900 MHz. Figure 6.5 shows the measurement of capacitance with respect to frequency. Capacitance essentially remains steady during the frequency range of 200 MHz to 1.8 GHz.

### 6.3 Temperature Coefficient of Resistance and Capacitance

The TCR and TCC measure change in resistance and capacitance with respect to change in temperature as previously discussed in section 2.4. It is important to understand how these parameters affect the resistivity or capacitance to minimize any undesirable changes.

The TCR of PTF material and TCC of nanocomposite dielectric were measured by using a hot plate and a thermocouple. The measurement was performed while the temperature was varied between approximately 25°C to 125°C. Figure 6.6 shows the measurement setup.

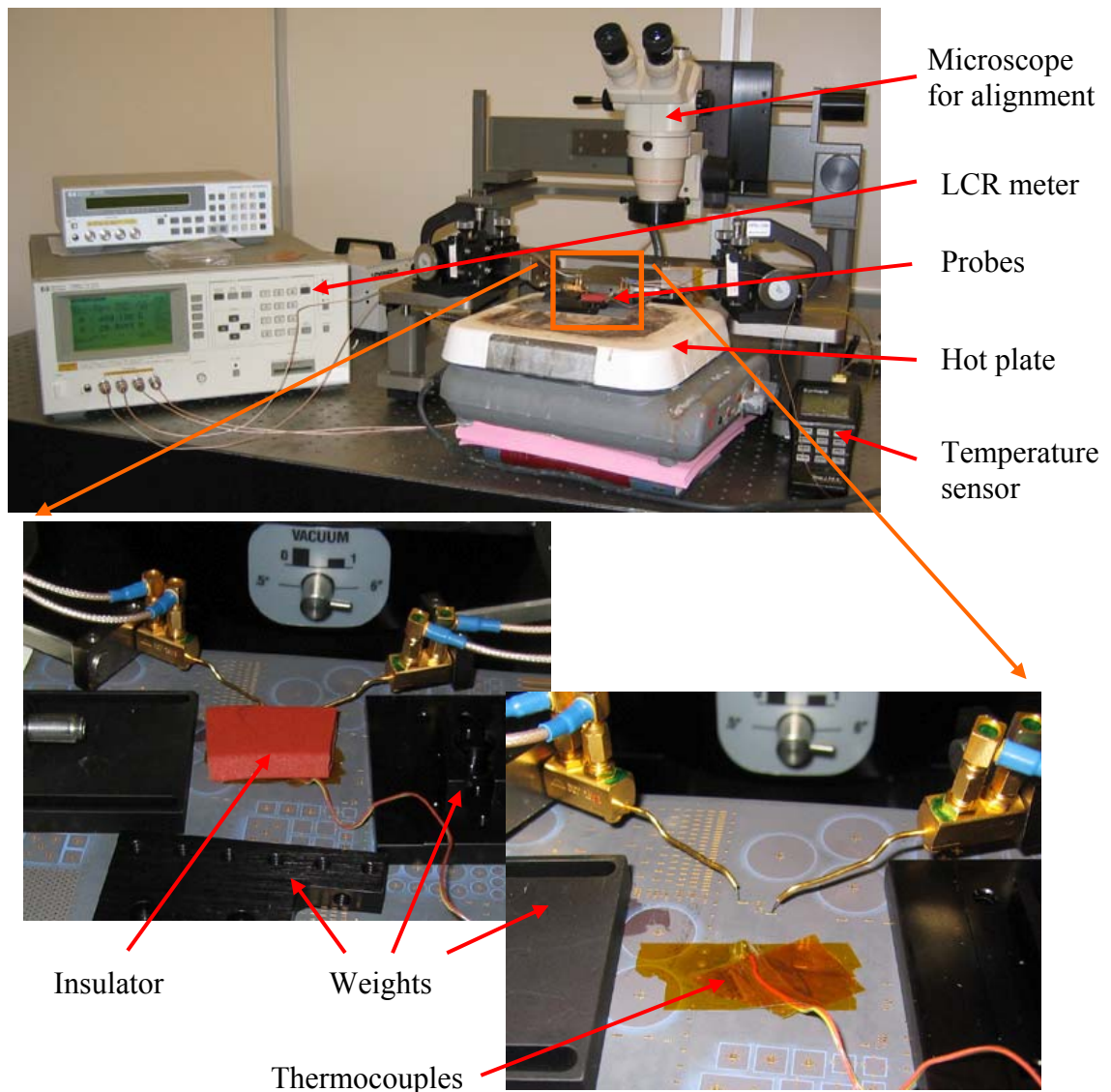


Figure 6.6. TCR and TCC measurement setup

As shown above in Figure 6.6, the measurement setup consists of various equipments including LCR meter, microscope, thermocouple, insulator, and weights. First, a thermocouple and insulation materials are mounted near the component on top of the board to accurately measure the component temperature. This board is then placed on top of the heat plate to heat up the board. Before the heat plate is activated, two LCR probes are aligned with the microvia pads using the microscope. Also, several weights



are placed around the board to prevent it from warpage and secure firm contact of probes with the pads.

Once the setup is completed, the board is heated to approximately 125°C and maintained at the high temperature. Then, the heat plate is turned off, and while the entire setup is cooling down by natural ambient air, resistance or capacitance is incrementally measured. The measurements are taken while it is cooling instead of heating since it is difficult to control the heating rate. Also since TCR and TCC are based on their intrinsic material properties, components with the highest respective material volume percentage such as resistors with 100 square and 40 mil width or capacitors with 440 mil diameter were measured. Several measurements were completed as shown in Figures 6.7 and 6.8, and Table 6.1 summarizes the results.

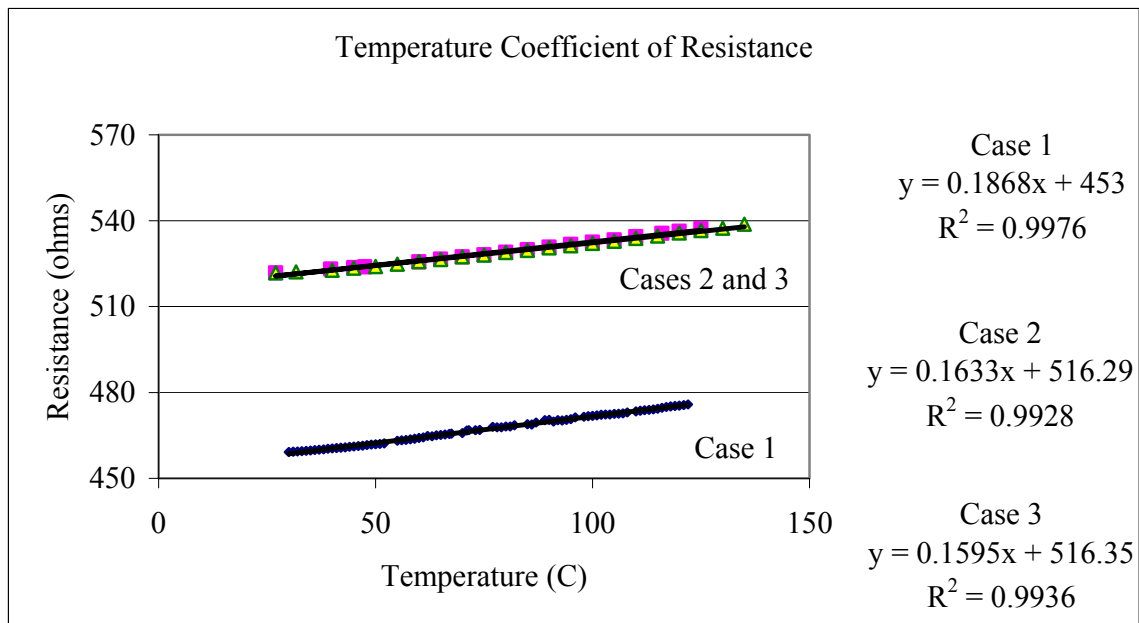


Figure 6.7. TCR measurements

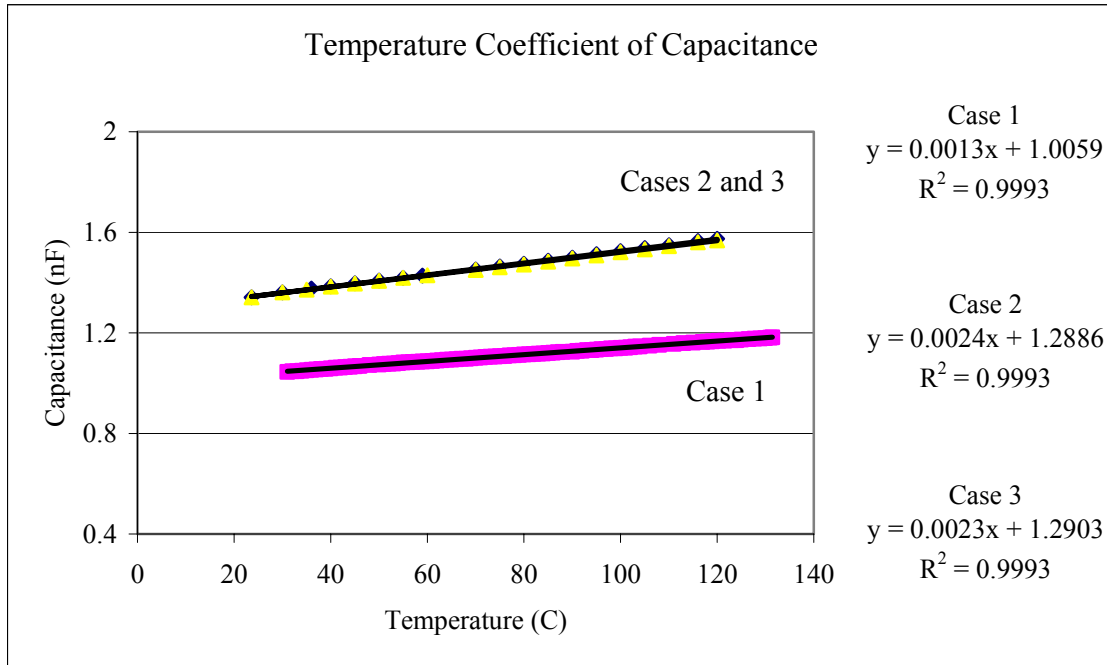


Figure 6.8. TCC measurements

Table 6.1 Summary of TCR and TCC measurement

TCR Test Cases	TCR (ppm/°C)	TCC Test Cases	TCC (ppm/°C)
Case 1 (100 sq/40 mil width PTF)	407	Case 1 (440 mil circular)	1244
Case 2 (100 sq/40 mil width PTF)	313	Case 2 (440 mil circular)	1790
Case 3 (100 sq/40 mil width PTF)	306	Case 3 (440 mil circular)	1715

Both Figures 6.7 and 6.8 show linear relationship between the resistance and capacitance with respect to temperature. Since TCR and TCC are based on the material property, all the measurements should have similar results. Although Cases 2 and 3 share similar results, Case 1 is slightly different from others possibly due to localized degradation of material or simple measurement errors. Measurements of Cases 2 and 3 are performed within few hours apart and they were based on a same component; however, Case 1 was



tested few days prior to other measurements and it was based on a different component. In terms of the magnitude of TCR and TCC, they are higher than desired, but they are expected. PTF material is known for its difficulty in achieving stability with respect to temperature. Also, capacitor nanocomposite, which is a mixture of barium titanate based ferroelectric ceramic particles in organic material, could lead to unstable electrical characteristics. High TCC is expected when barium titanate has high TCC of  $\sim 5000$  ppm/ $^{\circ}\text{C}$  and epoxy has TCC of  $\sim 300$  ppm/ $^{\circ}\text{C}$ .

#### 6.4 Warpage Measurement using Shadow Moiré

Shadow moiré interferometry is a well established technique that can accurately measure the out-of-plane displacement or warpage of a test sample [Hassell, 2001]. It analyzes the fringes that are created from the interference between the equally spaced reference grating and the shadows of grating reflected on the test sample. Figure 6.9 shows a simplified experimental setup.

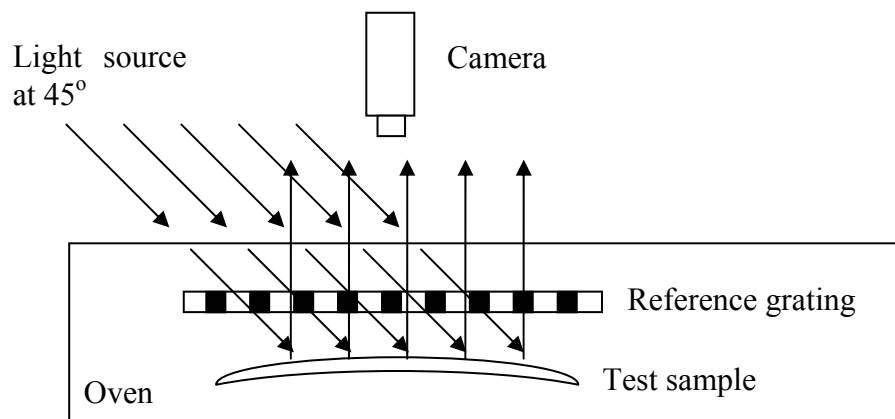


Figure 6.9. Simplified shadow moiré experiment setup

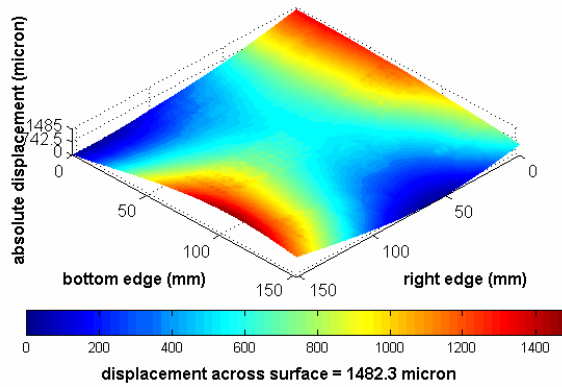
As shown above in Figure 6.9, light is projected onto the reference grating, which creates shadow of gratings. If the test sample is not flat, then the grating and its shadow create fringe patterns that can be analyzed by Equation 6.1.

$$z = \frac{Np}{\tan \alpha + \tan \beta} \quad (\text{Eq. 6.1})$$

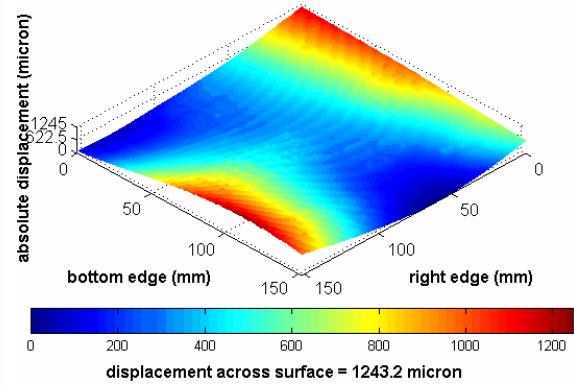
$z$  is the out-of-plane displacement,  $Np$  is the number of fringes,  $\alpha$  is the illumination angle, and  $\beta$  is the observation angle.

Shadow moiré interferometry was performed to measure the warpage of TV1. The fringe patterns were captured at various temperatures approximately from 30°C to 150°C. The measurements were based on grating resolution of 100 lines per inch. Figure 6.10 shows warpage measurement results.

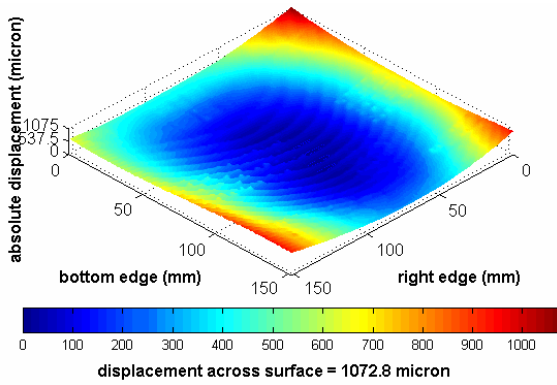
As shown in Figure 6.10, TV1 is initially warped in a saddle shape, and as the temperature rises from 25°C to 150°C, it gradually warps into a spherical shape. Highest warpage resulted at 150°C with 1.68 mm out-of-plane displacement. The direction of warpage is expected since there is higher volume of substrate dielectric, which has highest CTE, on the bottom of the test board. As the entire board heats up, bottom half of the board expands more than the top half.



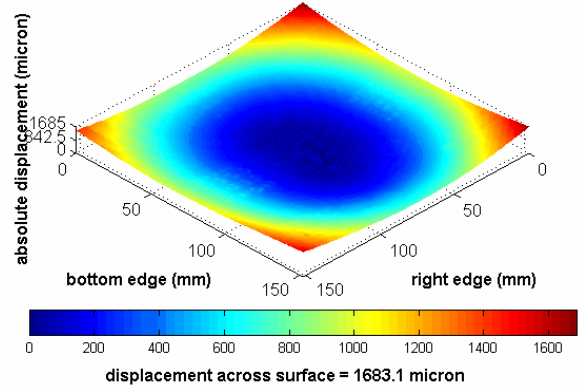
(a) Warpage at 25°C = 1.48 mm



(b) Warpage at 60°C = 1.24 mm



(c) Warpage at 90°C = 1.07 mm



(d) Warpage at 150°C = 1.68 mm

Figure 6.10. Warpage measurements at different temperatures

## **CHAPTER VII**

### **EXPERIMENTAL RELIABILITY ASSESSMENT**

Although embedded passives present better reliability with the elimination of solder joint interconnects, the embedded passives also introduce other concerns such as cracks, delamination and component instability. More substrate layers will be needed to accommodate the embedded passives, and various materials within the substrate may cause significant thermo-mechanical stress due to CTE mismatch. Unlike surface mounted components where defective parts can be reworked and replaced, a single bad component can obliterate the entire board. Consequently, reliability is a major issue in the acceptance and success of embedded passives technology.

EI Technologies, Inc. has fabricated both TV1 and TV2 in bulk, and these test boards are used for all the reliability tests. These test boards from EI Technologies, Inc. share the same board layers described in earlier chapters. However, some material discrepancies exist due to material availability. All the resistor materials are identical, but the dielectric material used in the microvia layer is Dynavia 2000<sup>TM</sup> instead of Vantico Probimer 7081<sup>TM</sup>. These materials have similar electrical properties and processing conditions.

#### **7.1 Reliability Qualification Test Conditions and Equipments**

Instead of a typical field use condition, reliability qualification tests are performed under a more demanding environment to accelerate the failure mechanisms, namely, temperature, humidity, voltage, and pressure. Four reliability qualification tests based on

JEDEC and MIL standards were used to evaluate the embedded passives as listed in Table 7.1.

Table 7.1. Reliability qualification test conditions

Test Cases	Test Conditions	Test Duration
Air to Air Thermal Cycling	-40 – 125°C	Each cycle consists of 10 minute dwell at each extreme temperature, 20 minutes per cycle, Total of 1000 cycles
Air to Air Thermal Cycling	-55 – 125°C	Each cycle consists of 10 minute dwell at each extreme temperature, 20 minutes per cycle, Total of 1000 cycles
Steady State Temperature Humidity Test	85°C / 85 RH	1000 hours
Highly Accelerated Stress Test (HAST)	121°C / 100 RH	96 hours

All thermal cycling tests were performed with Thermotron ATS-320-DD chamber. It consists of three chambers stacked together vertically as shown in Figure 7.1. The top and bottom chambers were maintained at constant temperature of 125°C, and the middle chamber was maintained at -40 or -55°C. Two large baskets inside these chambers hold the test samples, and as the baskets move up and down, the test samples are exposed to two extreme temperatures. The dwell time in each temperature extreme was 10 minutes; hence, each cycle was 20 minutes long. After every 100 or 200 cycles of continuous run, the test vehicles were removed from the chambers for electrical measurements. These tests were conducted for 1000 cycles.

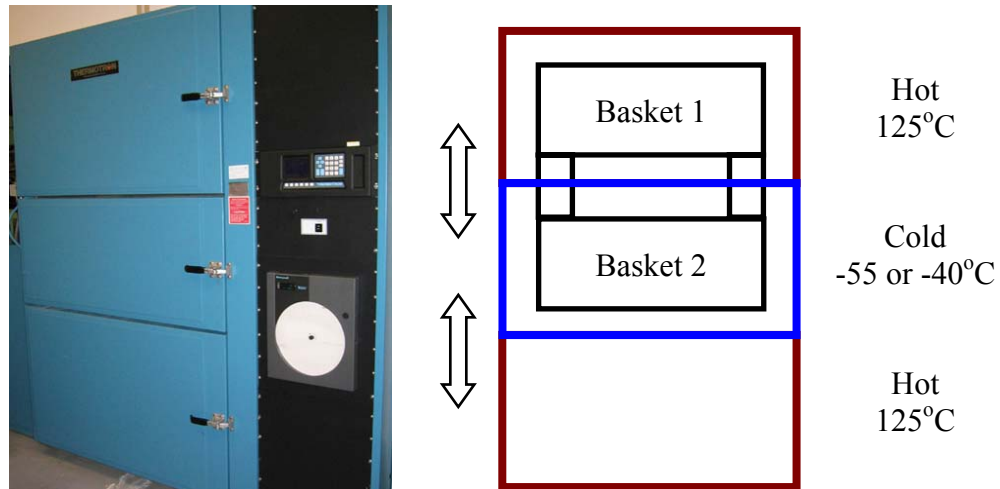


Figure 7.1. Schematics of thermal chamber

Steady state temperature and humidity tests and HAST were performed with Thermotron 2800 and ESPEC HAST System TPC-422M as shown in Figure 7.2 respectively. After every 100 hours of continuous run, the test vehicles were removed from the chamber for electrical measurements. Steady state test and HAST were conducted for 1000 hours and 96 hours respectively.



(a) Steady state temperature and humidity chamber



(b) HAST chamber

Figure 7.2. Humidity test chambers

## **7.2 Test Results of Test Vehicle 1**

For each test vehicles, different conditions of air-to-air thermal cycling and constant temperature and humidity tests were performed. The test results are divided into three sections:

1. TV1 PTF Resistors
2. TV1 Capacitors
3. TV2 NiCrAlSi Thin Film Foil Resistors

For TV1, three different configurations of TV1 designs were fabricated and tested: resistors only, capacitors only, and resistors and capacitors together. Although the original TV1 design included both resistors and capacitors, some test boards were fabricated with just one type of component and not the other. This separation removes possible interaction between the processing conditions. Other differences between these boards are sheet resistance of resistors.

Resistors are described by three design parameters: sheet resistances, number of squares, and width of squares. Sheet resistances represent the different material properties, and the number of squares and width of square represent the planar dimensions. The effects of these three categories on the resistor reliability are presented. For capacitors, effects of design parameters including planar dimensions, geometric shapes, and microvia locations on the reliability are presented. Also, changes in Q-Factors are compared against capacitor shapes and sizes.

### ***7.2.1 Reliability Test Results for Test Vehicle 1 PTF Resistors***

Four unique test cases for TV1 PTF resistors are depicted in Table 7.2.

Table 7.2. PTF reliability test cases

Cases	Test boards	Conditions
Case 1	TV1 Capacitors and Resistors (10 $\Omega$ /sq)	Thermal cycling (-40 – 125°C) 1000 cycles
Case 2	TV1 Capacitors and Resistors (10 k $\Omega$ /sq)	Thermal cycling (-40 – 125°C) 1000 cycles
Case 3	TV1 Resistor only (10 $\Omega$ /sq)	Thermal cycling (-55 – 125°C) 1000 cycles
Case 4	TV1 Resistor only (10 $\Omega$ /sq)	Steady state temperature and humidity (85°C/85%RH) 1000 hours

As listed in Table 7.2, Cases 1 and 2 include both resistors and capacitors, while Cases 3 and 4 only include resistors. Also, Case 2 has sheet resistance of 10 k $\Omega$ /sq, while others have 10  $\Omega$ /sq. Each board contains approximately 300 resistors, and 100 resistors at 6 different locations are examined during the tests. Figure 7.3 shows the locations of resistor groups examined, Figures 7.4 shows the overall resistance change for different cases, and Tables 7.3 to 7.6 list the results

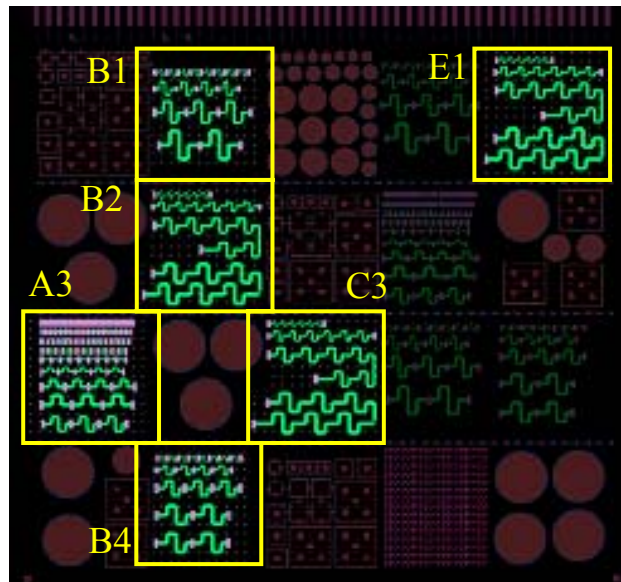


Figure 7.3. Examined PTF resistors



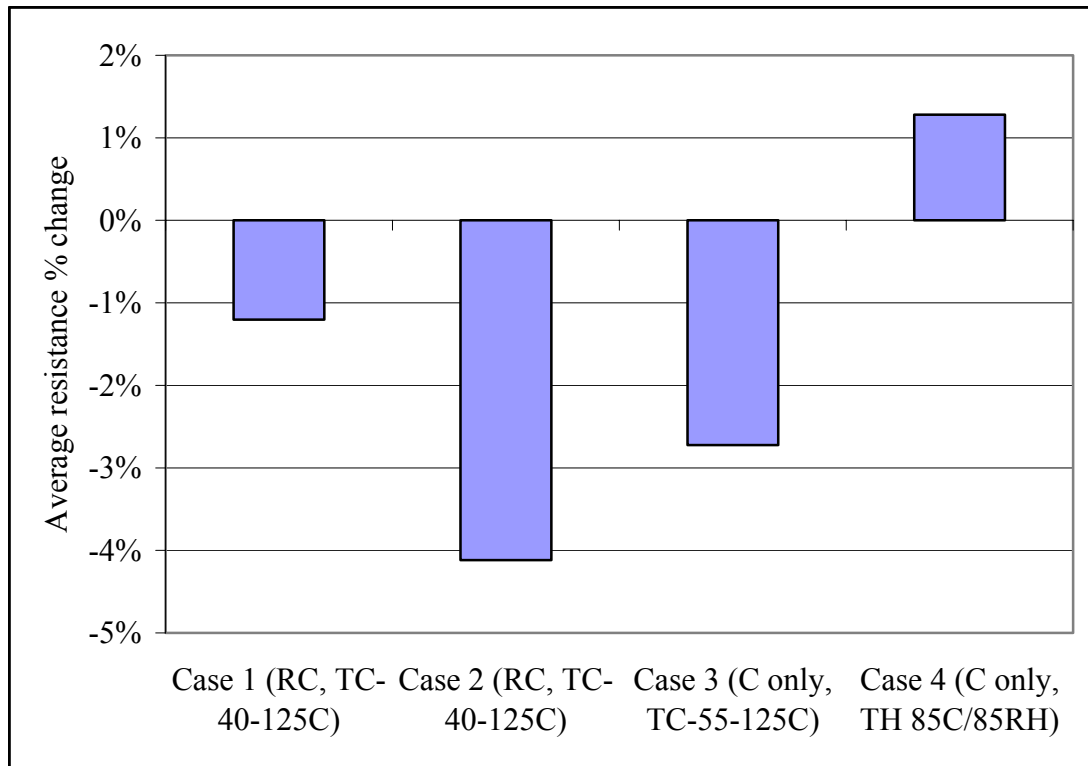


Figure 7.4. Comparison between the reliability tests

Table 7.3. Case 1 test results of TV1 resistors

Case 1: TV1 Resistor and Capacitors PTF 10 $\Omega$ /sq				
Number of Squares	Avg. Initial R ( $\Omega$ )	Number of Samples	Standard Deviation	R change after Thermal cycling (-40 – 125°C, 1000 cycles)
1 square	4.5	32	0.6	-1.40%
10 squares	47.1	17	2.6	-1.46%
15 squares	72.7	22	4.4	-1.16%
20 squares	91.4	17	12.3	-0.91%
100 squares	437.7	12	34.9	-1.10%

Table 7.4. Case 2 test results of TV1 resistors

Case 2: TV1 Resistor and Capacitors PTF 10 kΩ/sq				
Number of Squares	Avg. Initial R (kΩ)	Number of Samples	Standard Deviation	R change after Thermal cycling (-40 – 125°C, 1000 cycles)
1 square	4.8	32	0.1	-3.36%
10 squares	38.5	17	1.4	-4.32%
15 squares	57.9	22	2.5	-4.19%
20 squares	80.3	17	2.0	-4.29%
100 squares	374.2	12	27.7	-4.43%

Table 7.5. Case 3 test results of TV1 resistors

Case 3: TV1 Resistor only – PTF 10 Ω/sq				
Number of Squares	Avg. Initial R (kΩ)	Number of Samples	Standard Deviation	R change after Thermal cycling (-40 – 125°C, 1000 cycles)
1 square	7.8	25	1.0	-4.75%
10 squares	55.6	15	7.8	-2.63%
15 squares	86.1	22	19.5	-2.19%
20 squares	110.8	17	17.9	-2.07%
100 squares	503.3	12	71.8	-1.98%

Table 7.6. Case 4 test results of TV1 resistors

Case 4: TV1 Resistor only – PTF 10 Ω/sq				
Number of Squares	Avg. Initial R (kΩ)	Number of Samples	Standard Deviation	R change after Thermal cycling (-40 – 125°C, 1000 cycles)
1 square	6.3	32	0.4	1.70%
10 squares	51.6	17	5.4	1.30%
15 squares	76.2	22	11.5	1.35%
20 squares	100.8	17	13.5	1.04%
100 squares	445.4	12	26.7	1.00%

Before the changes in resistances are averaged, each resistor value is normalized to make each resistor count equally. After 1000 thermal cycles, all resistors experienced a slight decrease in the resistance, whereas after 1000 hours of constant temperature and humidity test, all the resistors experienced a slight increase in the resistance. Although Damani [Damani, 2004] has reported similar decrease in the resistance after thermal cycling, this result is unexpected. The degradation of resistor material due to thermo-mechanical loads should increase the resistance. The decrease in the resistance is most likely due to presence of partially cured resistors. As they are thermal cycled, the PTF materials continue to cure, which shrinks and compacts the resist materials to yield lower resistance. This explanation is supported by the plot of resistance change over cycles as shown in Figure 7.5.

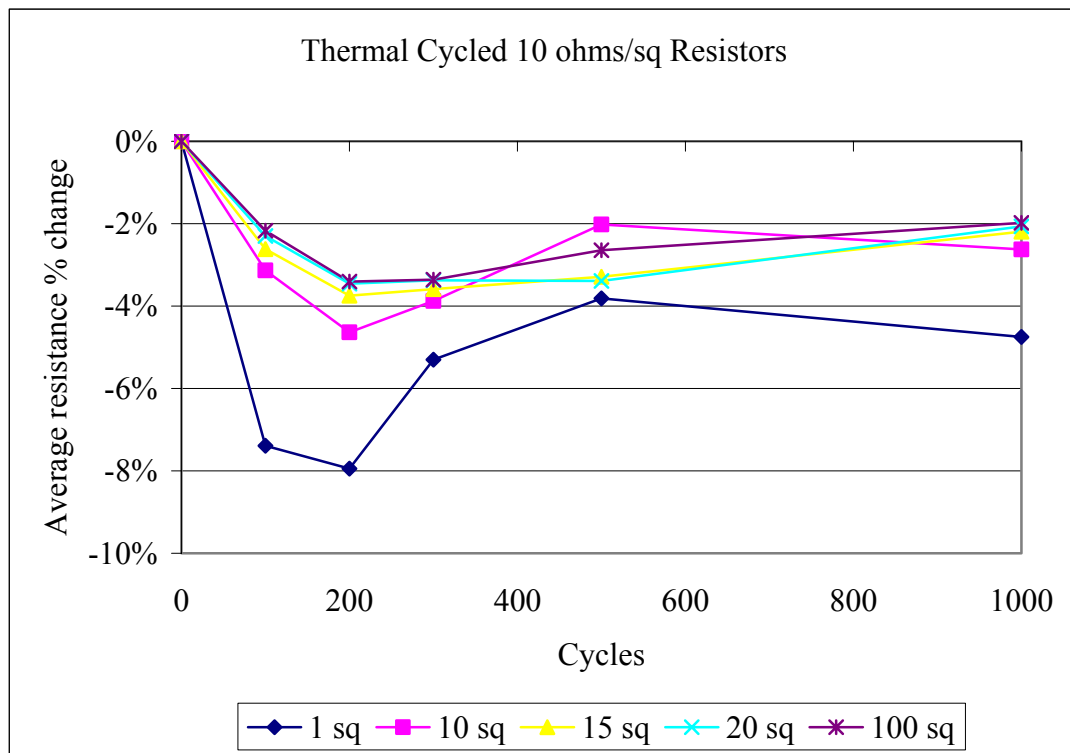


Figure 7.5. Resistance change during thermal cycling

As shown in Figure 7.5, there is a sharp decrease in the resistance during the first 200 cycles. Then, the resistances gradually increase and stabilize. This sequence indicates that the materials were still being cured during the first 200 cycles. After this curing, further thermal cycling results in degradation of the material properties; and therefore, the resistance increases by about 4% from the resistance of the fully cured material.

The increase of the resistance by about 2% during the humidity test is expected. The absorbed moisture expands the entire board, and the resistors are stressed and deformed.

### **Effect of Planar Dimensions and Resistor Location on Resistance Change**

In terms of number of squares or width of squares, there seem to be a no clear trend on which configuration performs better as shown in Figures 7.6 and 7.7. The percentage change in the resistance remains the same regardless of the planar dimensions. It should be pointed out that when only one square is used for measurements, there appears to be a deviation in the results. This is possibly due to the fact that the averaging effects of multiple squares are not considered when one square is used for the measurement.

Similar to planar dimensions, the percentage in the resistance remains same regardless of the location of resistors. Figure 7.8 compares three groups of identical resistors at different locations of B2, C3, and E1.

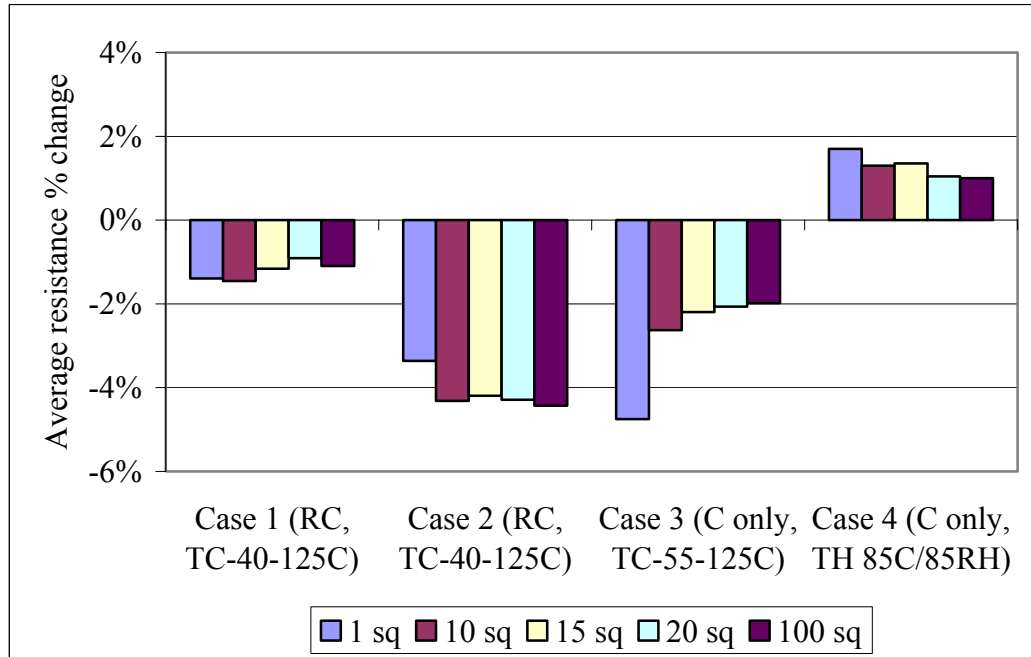


Figure 7.6. Comparison of resistors in terms of number of squares

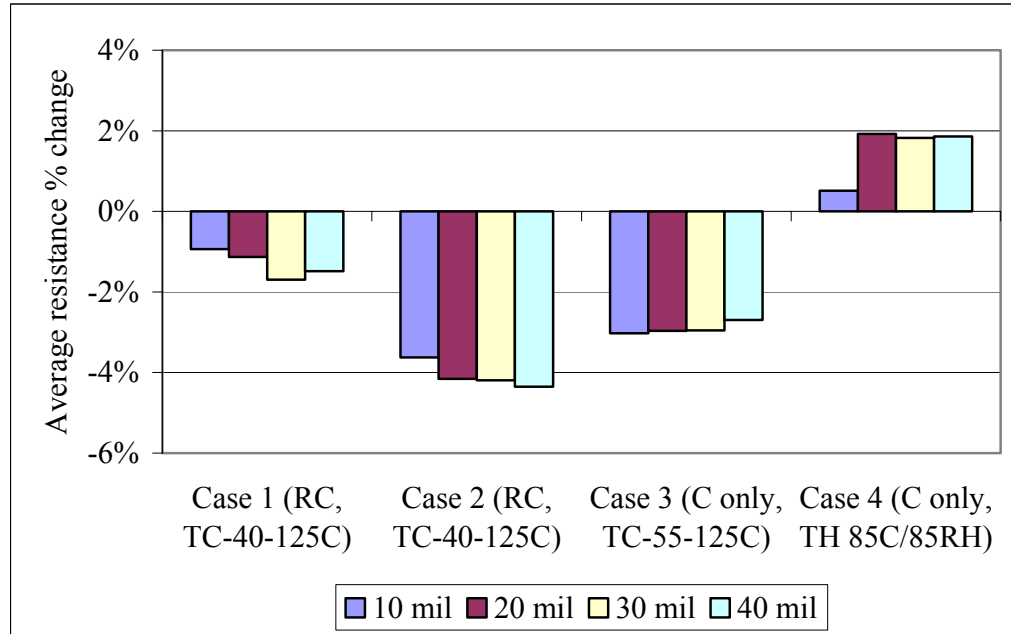


Figure 7.7. Comparison of resistors in terms of width of squares

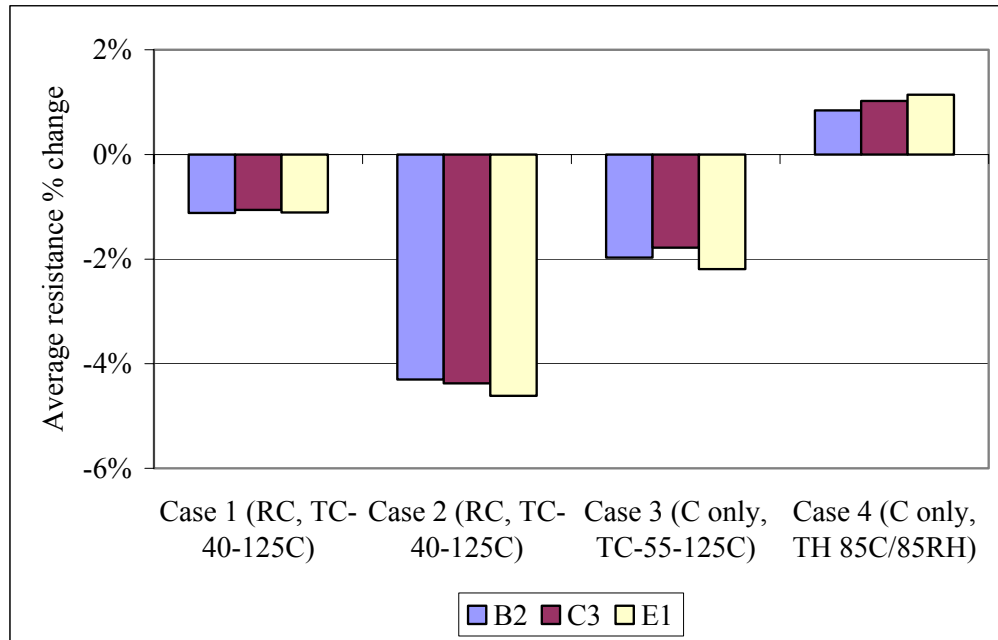


Figure 7.8. Comparison of resistor locations

All the reliability qualification tests showed that PTF resistors are quite reliable. None of the resistors failed during the tests, and the average resistance changes are within 5%. The sheet resistance had most effect on the resistance change compared to the planar dimensions or locations of resistors. This could be due to different thermo-mechanical properties between the materials. 10 k $\Omega$ /sq resistors could have higher CTE mismatch than 10  $\Omega$ /sq resistors that more severe thermo-mechanical deformation could have occurred.

### 7.2.2 Test Results of Test Vehicle 1 Capacitor

Four test cases for TV1 capacitors are depicted in Table 7.7.

Table 7.7. Capacitor reliability test cases

Cases	Test boards	Conditions
Case 1	TV1 Capacitors and Resistors (10 $\Omega$ /sq)	Thermal cycling (-40 – 125°C) 1000 cycles
Case 2	TV1 Capacitors and Resistors (10 k $\Omega$ /sq)	Thermal cycling (-40 – 125°C) 1000 cycles
Case 3	TV1 Capacitors only (10 $\Omega$ /sq)	Thermal cycling (-55 – 125°C) 1000 cycles
Case 4	TV1 Capacitors only (10 $\Omega$ /sq)	Steady state temperature and humidity (85°C/85%RH) 1000 hours

As listed in Table 7.7, Cases 1 and 2 include both resistors and capacitors, while Cases 3 and 4 only include capacitors. The difference between the Cases 1 and 2 is that they have different resistor material. This should not have any effect on the capacitors, and therefore, these boards should yield similar results. Within each board, 68 of 98 total capacitors are strategically selected to represent various geometric shapes and planar dimensions. For each capacitor, both capacitance and Q-Factor are measured at a low frequency of 100 kHz. Figure 7.9 shows the locations of capacitor group examined, Figure 7.10 plots the overall results, and Tables 7.8 to 7.15 summarize the results.

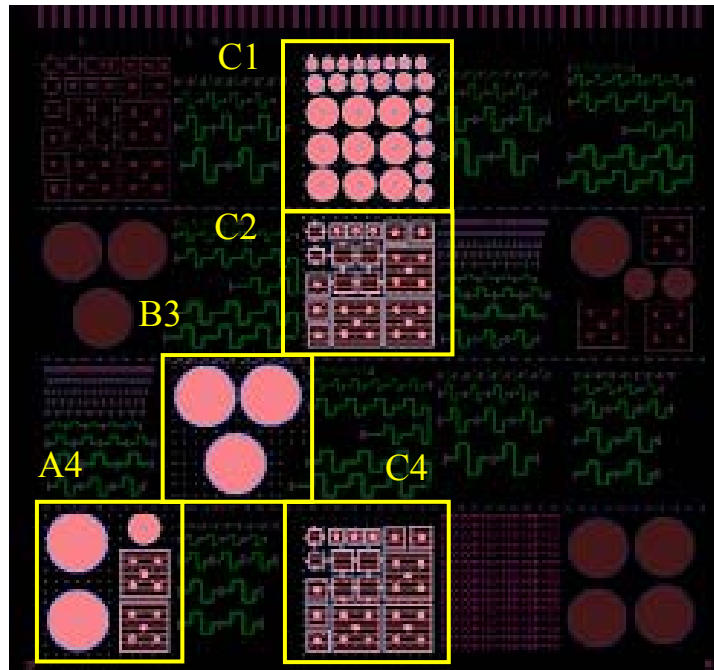


Figure 7.9. Examinated capacitors

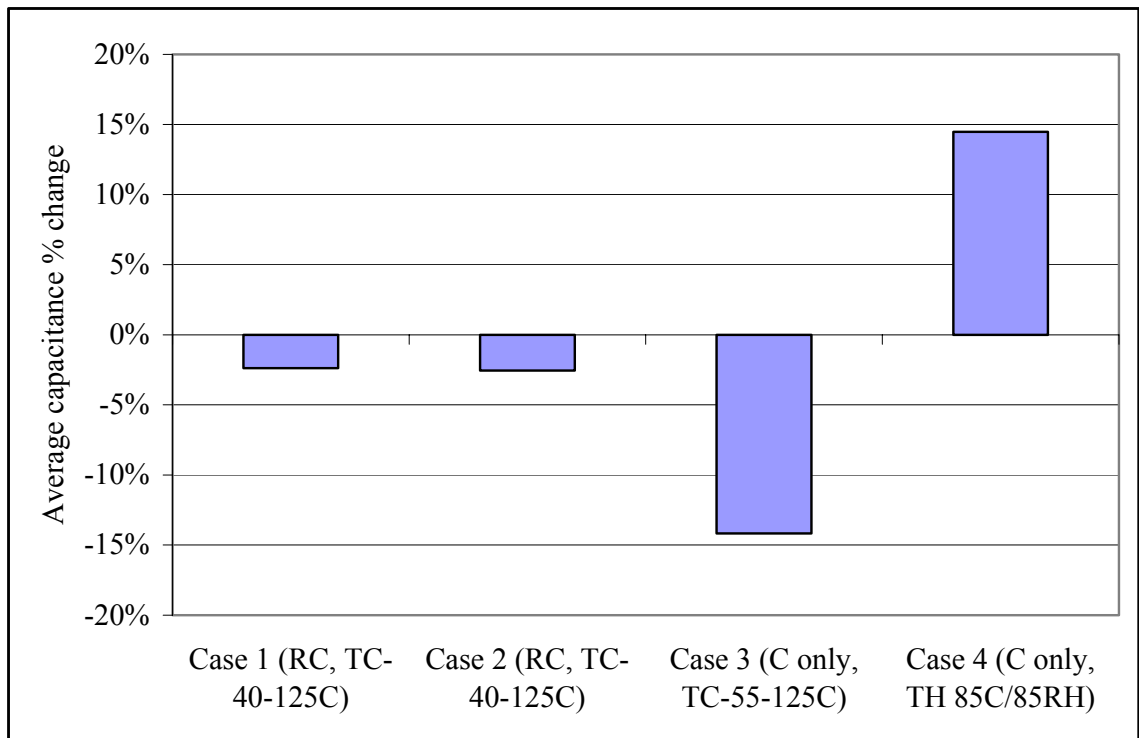


Figure 7.10. Reliability test results of capacitors



Table 7.8. Case 1: capacitance results of TV1 capacitors

Case 1: Thermal Shock (-40 to 125°C 1000 cycles)					
Capacitor Shape	Size (diameter or length in mil)	Average Initial Capacitance at 100 kHz (pF)	Number of Samples	Standard Deviation	Average % Change
Circular edge	110	63	5	7.5	-2.92%
Circular center	145	73	10	10.8	-2.67%
Circular center	240	269	10	40.2	-2.20%
Circular center	440	1050	5	177.8	-1.79%
Square edge	110	58	4	17.6	-3.08%
Square center	110	42	6	6.8	-3.20%
Square edge	160	217	7	51.1	-1.96%
Square center	160	164	9	26.7	-2.11%
Square center	360	997	5	141.2	-1.90%

Table 7.9. Case 2: capacitance results of TV1 capacitors

Case 2: Thermal Shock (-40 to 125°C 1000 cycles)					
Capacitor Shape	Size (diameter or length in mil)	Average Initial Capacitance at 100 kHz (pF)	Number of Samples	Standard Deviation	Average % Change
Circular edge	110	88	5	3.2	-2.71%
Circular center	145	127	7	14.6	-2.59%
Circular center	240	357	10	58	-2.62%
Circular center	440	1188	5	115.2	-1.92%
Square edge	110	83	3	18.3	-3.31%
Square center	110	65	5	3.9	-2.85%
Square edge	160	306	8	66.7	-2.86%
Square center	160	185	10	22.9	-2.83%
Square center	360	1043	3	85.5	-2.18%

Table 7.10. Case 3: capacitance results of TV1 capacitors

Case 3: Thermal Shock (-55 to 125°C 1000 cycles)					
Capacitor Group	Size (diameter or length in mil)	Average Initial Capacitance at 100 kHz (pF)	Number of Samples	Standard Deviation	Average % Change
Circular edge	110	45	7	1.6	-26.44%
Circular center	145	61	10	2.4	-20.22%
Circular center	240	149	10	18.7	-8.88%
Circular center	440	613	5	33.2	-2.09%
Square edge	110	52	4	2.9	-22.42%
Square center	110	46	6	2.9	-26.15%
Square edge	160	90	8	7.7	-11.79%
Square center	160	94	10	5.6	-14.63%
Square center	360	432	8	25.9	-3.50%

Table 7.11. Case 4: capacitance results of TV1 capacitors

Case 4: Constant Temperature Humidity (85°C/85%RH 1000 hours)					
Capacitor Group	Size (diameter or length in mil)	Average Initial Capacitance at 100 kHz (pF)	Number of Samples	Standard Deviation	Average % Change
Circular edge	110	30	7	2.2	19.68%
Circular center	145	46	10	2.7	13.89%
Circular center	240	131	10	20.4	12.52%
Circular center	440	534	5	36.6	9.87%
Square edge	110	37	1	NA	16.85%
Square center	110	28	6	2.0	16.72%
Square edge	160	NA	NA	NA	NA
Square center	160	74	10	8.6	12.39%
Square center	360	358	8	27.8	9.87%

Table 7.12. Case 1: Q-Factor results of TV1 capacitors

Case 1: Thermal Shock (-40 to 125°C 1000 cycles)					
Capacitor Shape	Size (diameter or length in mil)	Average Initial Q-Factor at 100 kHz	Number of Samples	Standard Deviation	Average % Change
Circular edge	110	44	5	2.6	27.98%
Circular center	145	44	10	0.9	26.89%
Circular center	240	46	10	7.3	49.83%
Circular center	440	52	5	1.3	52.49%
Square edge	110	43	4	0.8	29.65%
Square center	110	42	6	0	23.02%
Square edge	160	48	7	2.9	34.93%
Square center	160	45	9	1.4	27.48%
Square center	360	51	5	1.1	42.02%

Table 7.13. Case 2: Q-Factor results of TV1 capacitors

Case 2: Thermal Shock (-40 to 125°C 1000 cycles)					
Capacitor Shape	Size (diameter or length in mil)	Average Initial Q-Factor at 100 kHz	Number of Samples	Standard Deviation	Average % Change
Circular edge	110	41	5	0	22.57%
Circular center	145	40	7	0.7	22.04%
Circular center	240	46	10	1.0	34.94%
Circular center	440	50	5	2.5	43.78%
Square edge	110	40	3	0.6	24.79%
Square center	110	39	5	0	17.52%
Square edge	160	46	8	1.1	33.24%
Square center	160	41	10	1.7	23.79%
Square center	360	48	3	1.5	33.79%

Table 7.14. Case 3: Q-Factor results of TV1 capacitors

Case 3: Thermal Shock (-55 to 125°C 1000 cycles)					
Capacitor Group	Size (diameter or length in mil)	Average Initial Q-Factor at 100 kHz	Number of Samples	Standard Deviation	Average % Change
Circular edge	110	37	7	1.3	104.96%
Circular center	145	38	10	0.8	102.13%
Circular center	240	45	10	1.7	65.17%
Circular center	440	61	5	0.8	42.48%
Square edge	110	39	4	1.0	92.36%
Square center	110	36	6	2.0	103.21%
Square edge	160	44	8	2.0	72.86%
Square center	160	43	10	1.7	75.93%
Square center	360	55	8	0.8	49.77%

Table 7.15. Case 4: Q-Factor results of TV1 capacitors

Case 4: Constant Temperature Humidity (85°C/85%RH 1000 hours)					
Capacitor Group	Size (diameter or length in mil)	Average Initial Q-Factor at 100 kHz	Number of Samples	Standard Deviation	Average % Change
Circular edge	110	57	7	1.0	-47.24%
Circular center	145	54	10	0.6	-41.92%
Circular center	240	54	10	0.5	-40.93%
Circular center	440	66	5	0.8	-46.21%
Square edge	110	50	1	1.4	-39.22%
Square center	110	51	6	0.5	-41.25%
Square edge	160	53	NA	NA	NA
Square center	160	52	10	0.6	-39.11%
Square center	360	58	8	0.5	-41.42%

Once again, each capacitor is normalized and then averaged to make each capacitor count equally. After 1000 thermal cycle, all the capacitor groups experienced decrease in the capacitance. This trend is expected, since thermal loads degrade the dielectric material resulting in decrease in the dielectric constant. Also, thermo-mechanical deformation could cause the parallel plate electrodes to delaminate and thickness to increase. The test board that was cycled between -55 to 125°C shows much higher capacitance percent change than the boards that were cycled between -40 to 125°C. Although this trend is expected, the magnitude of differences is much higher than expected. Also, Cases 1 and 2 which had different resistor materials but shared same thermal cycling condition have similar results as expected. This suggests that the resistor materials do not affect or interact with the capacitor layer.

After 1000 hours of constant temperature and humidity test, capacitors experienced increase of 10% to 20% in capacitance. This increasing trend is expected, since absorbed moisture has higher dielectric constant.

### **Effect of Geometric Shapes and Planar Dimensions on Capacitance Change**

For each test conditions, capacitors are separated into seven different combinations of planar dimensions and geometric shapes as shown in Figure 7.11. Although size of capacitors in Cases 1 and 2 does not seem to affect the capacitance change, there is a clear trend of smaller capacitor having higher average percentage change in Cases 3 and 4.

This result suggests that the dimension of capacitor plays a critical role in the overall reliability. Especially in cases 3 and 4, noticeable difference in the capacitance change suggest that the change could be a stronger function of thermo-mechanical

deformation than the dielectric material degradation. In terms of geometric shape, there seem to be no significant difference between the circular and square shape electrodes.

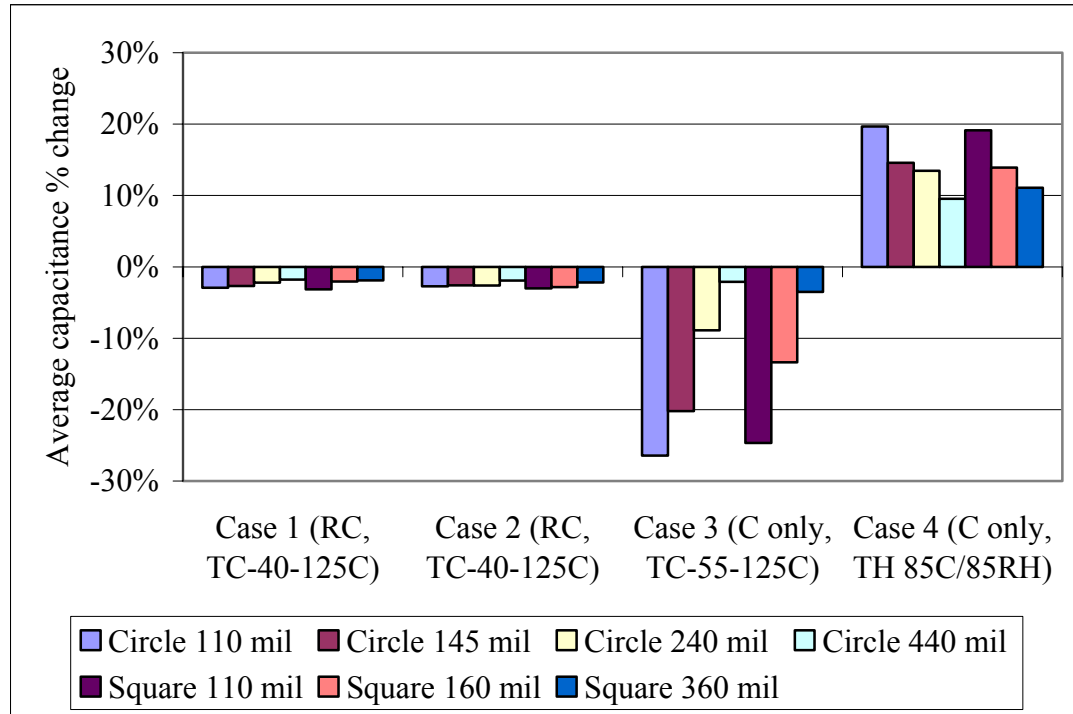


Figure 7.11. Change in capacitance in terms of geometric shape and dimension

## Q-Factors

Other important characteristic of capacitors is Q-Factors. This parameter measures how well the energy is stored in the dielectric during AC operation. It is sometimes displayed as dissipation factor, which is a reciprocal Q-factor. A value above 1000 is considered to be very good and lower than 20 is considered bad. As shown in Figure 7.12, the average initial Q-Factor varies approximately from 35 to 65 depending on the size of the capacitors. Larger capacitors seem to have higher Q-Factor than the smaller capacitors. Figure 7.13 shows the changes in Q-Factor after various reliability tests.

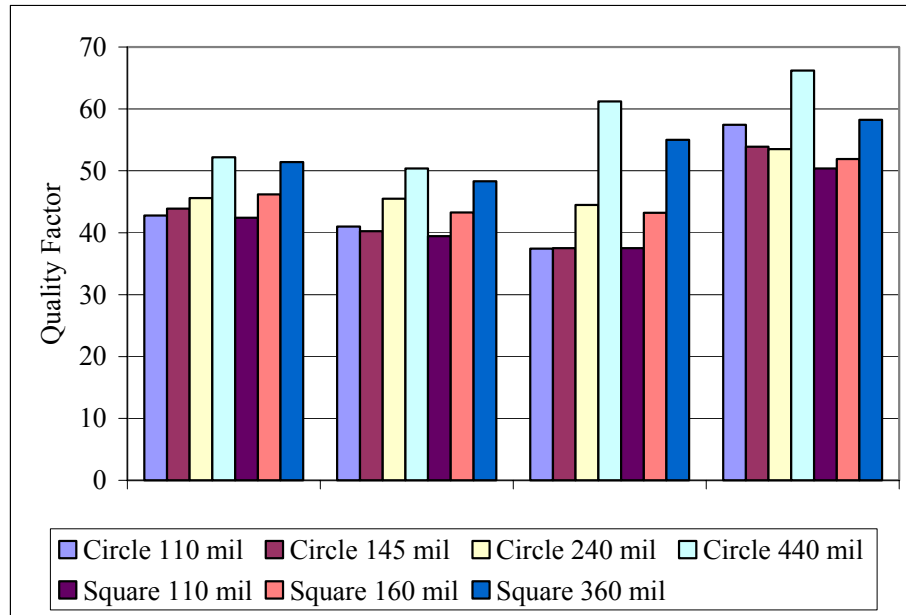


Figure 7.12. Averaged initial Q-Factor

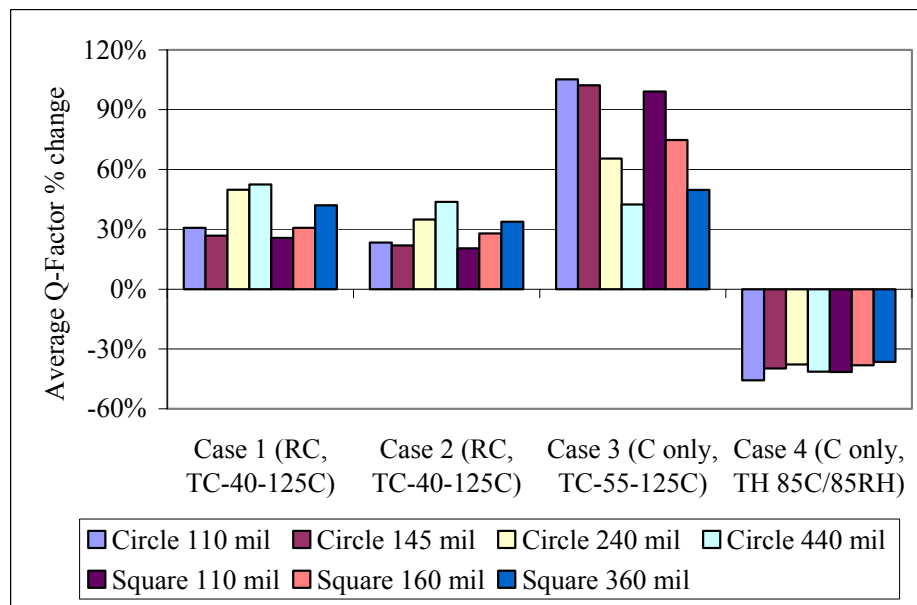


Figure 7.13. Change in Q-Factor of capacitors.

As shown in Figure 7.13, Q-Factors increased after thermal cycling. This increasing trend suggests that the dielectric material is storing energy better after the thermal cycling. One possible explanation for such unexpected results is that the dielectric was

not fully cured. As the thermal cycling gradually cures the dielectric, the performance of capacitor is improved. After steady state temperature and humidity test, all types of capacitors experienced increased in Q-Factor of about 40%. This is due to increased moisture absorption.

The reliability qualification tests show that there is room for currently used embedded capacitor process to improve. Although Cases 1 and 2 showed less than 5% change in capacitance, significant change of approximately 20% are observed in Cases 3 and 4. This drastic difference is difficult to explain. The main difference between these cases is that Cases 3 and 4 do not contain any resistors. Although absence of resistor layer should have simplified the process steps, the different processing condition must have affected the final test boards.

### **7.3 Test Results of Test Vehicle 2 NiCrAlSi Resistors**

Four identical TV2s with NiCrAlSi thin film foil resistors were tested at two different conditions.

- Air to air thermal cycling (-55 to 125°C) for 1000 cycles
- Highly Accelerated Stress Test (121°C/100RH) for 96 hours

Each TV2 contained approximately 550 resistors, and 100 resistors were monitored during the tests. Overall, NiCrAlSi resistors showed much more stable results than the PTF resistors. All four tests showed less than 1% increase in resistance. Among all the resistors examined, however, one resistor that was thermal cycled became open. Figure 7.14 shows the locations of resistor groups examined, Figure 7.15 shows the resistance change, and Table 7.16 summarizes the results.



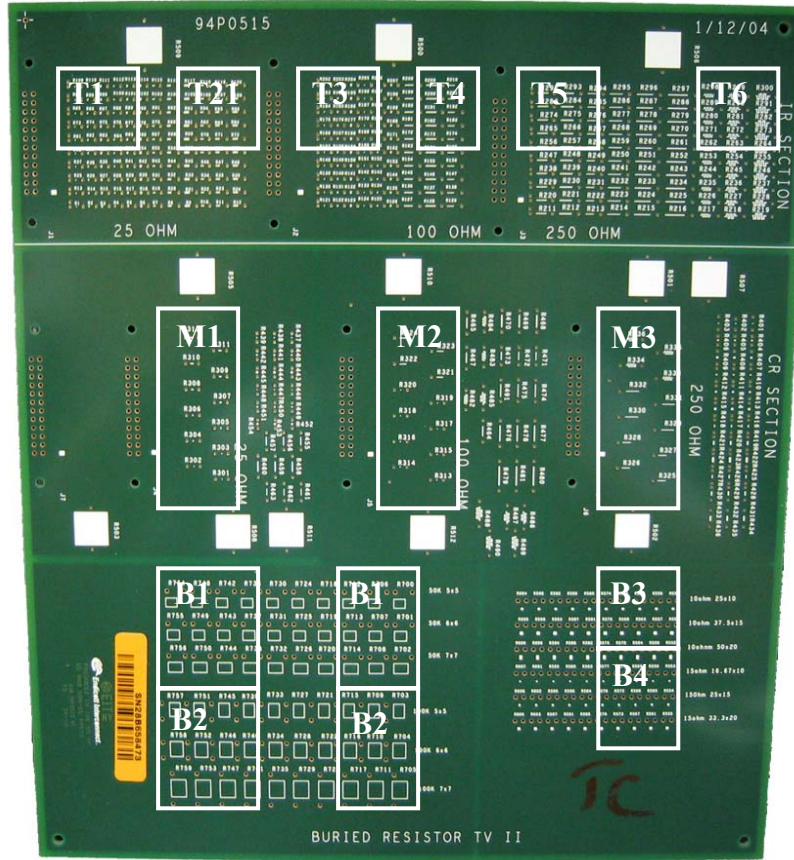


Figure 7.14. Examined NiCrAlSi resistors

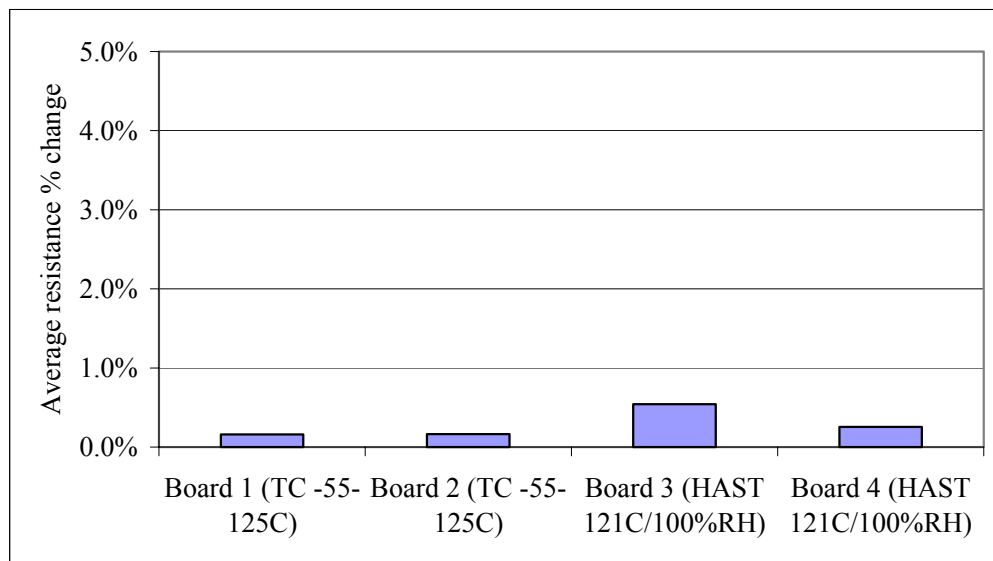


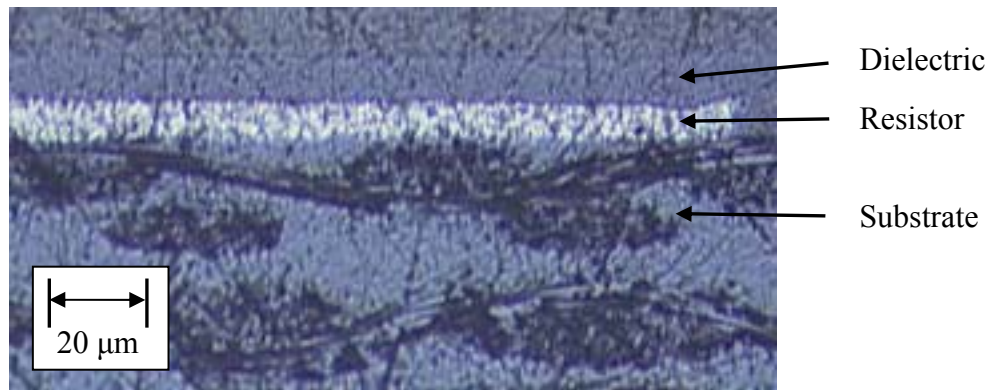
Figure 7.15. NiCrAlSi resistor test results

Table 7.16. Summary of NiCrAlSi resistance change

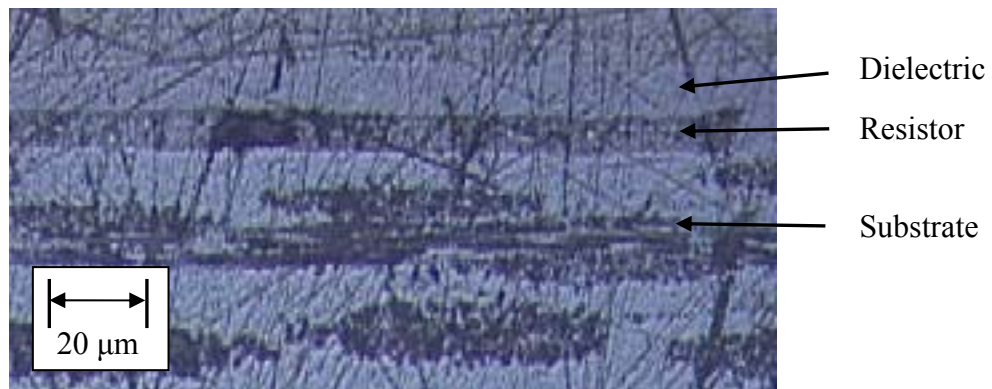
NiCrAlSi foil			
Resistor group	Resistance range ( $\Omega$ )	Thermal cycle (-55 to 125°C 1000 cycles)	HAST (121°C/ 100RH 100 hours)
T1	~ 20	0.43%	0.38%
T2	~ 100	0.07%	0.08%
T3	~ 75	0.06%	0.05%
T4	~ 1 k	0.04%	0.09%
T5	~ 3 k	0.38%	0.84%
T6	~ 9 k	0.41%	0.69%
M1	20 – 100	0.21%	0.07%
M2	70 – 100	0.06%	0.08%
M3	~9 k	0.30%	0.70%
B1	~ 60 k	0.31%	0.52%
B2	~ 100 k	0.30%	0.53%
B3	5 – 10	0.51%	0.68%
B4	~ 15	0.07%	0.72%

#### 7.4 Cross-Sectioning of Test Vehicles

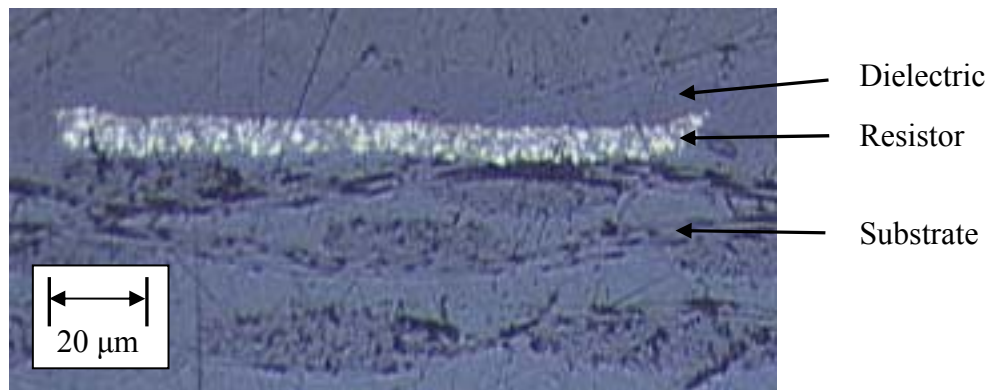
After completion of various qualification tests, test boards were cross-sectioned to visually investigate the causes of change in resistance and capacitance. Figures 7.16 and 7.17 show the cross-sections of resistors and capacitors.



(a) 10  $\Omega$  after thermal cycle (1000 cycles)

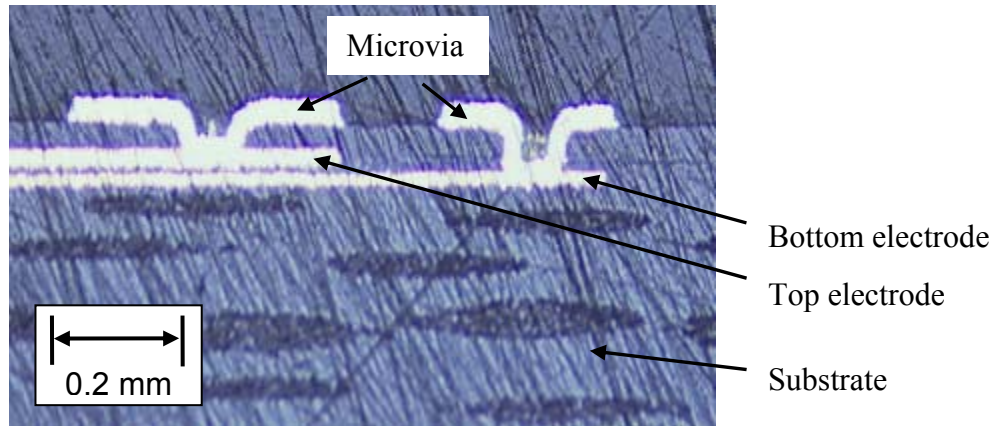


(b) 10 k $\Omega$  after thermal cycle (1000 cycles)

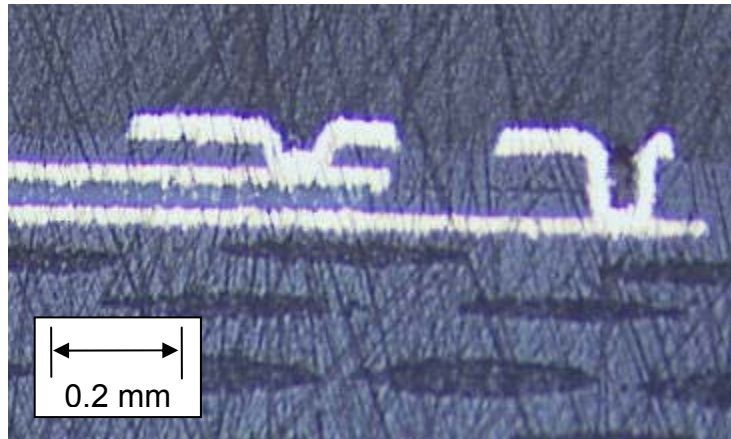


(c) 10  $\Omega$  after humidity test (1000 hours)

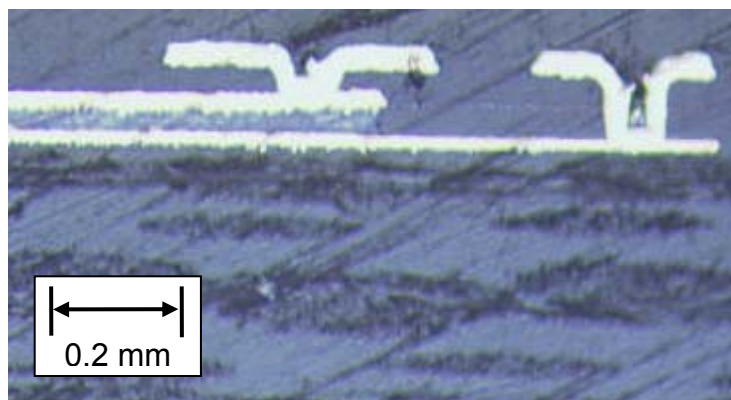
Figure 7.16. Cross-sections of resistors in TV1



(a) Capacitor and resistor test board after thermal cycling (1000 cycles)



(b) Capacitor only test board after thermal cycling (1000 cycles)



(c) Capacitor only test board after humidity test (1000 hours)

Figure 7.17. Cross-sections of capacitors in TV1

Figure 7.16 shows the cross-sections of three test cases of TV1 resistors. All cases show no visible sign of cracking or delamination within the resistor layers. Also, all cases show similar thickness of resistors, but 10 k $\Omega$  resistor in Figure 7.16b is noticeably darker than 10  $\Omega$  resistors. Figure 7.17 shows cross-sections of three test cases of TV1 capacitors. All figures shows edge probed capacitors with microvias. Although there is no visible sign of cracking or delamination, some microvias are severely deformed. Also, there is a dramatic difference in the capacitor dielectric thickness between the figures, which explains the wide range of capacitance between the test boards. Table 7.17 compares the thicknesses of capacitor dielectric and their averaged initial capacitance between the test cases.

Table 7.17 Wide range of initial capacitance due to different dielectric thicknesses

Test cases	Thickness ( $\mu\text{m}$ )	Initial Capacitance (pF)			
		Square Edge 2.8 mm	Square Center 2.8 mm	Square Edge 4 mm	Square Center 4 mm
Case 1 R and C board Thermal cycled	~15	58	42	217	164
Case 2 R and C board Thermal cycled	~10	83	65	306	185
Case 3 C only board Thermal cycled	~ 30 – 40	52	46	90	94
Case 4 C only board Humidity	~25 – 35	37	28	NA	74



As shown above in Table 7.17, thicknesses vary from approximately 10  $\mu\text{m}$  to 40  $\mu\text{m}$ . This high variation resulted in a wide range of average initial capacitance from 74 pF to 306 pF for 4 mm capacitors.

Among 400 NiCrAlSi resistors tested, one of the resistors that were thermal cycled became open. This resistor was cross-sectioned to investigate the failure as shown in Figure 7.18.

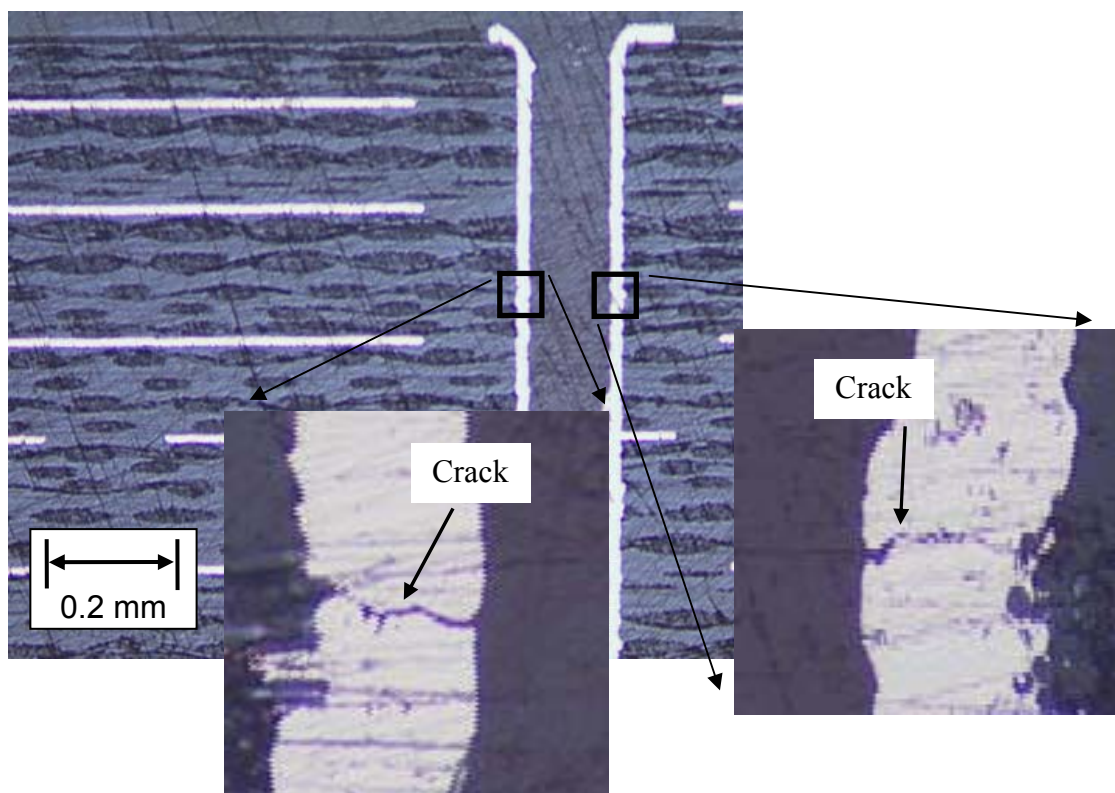


Figure 7.18. Cross-section of TV2 showing cracks on PTH

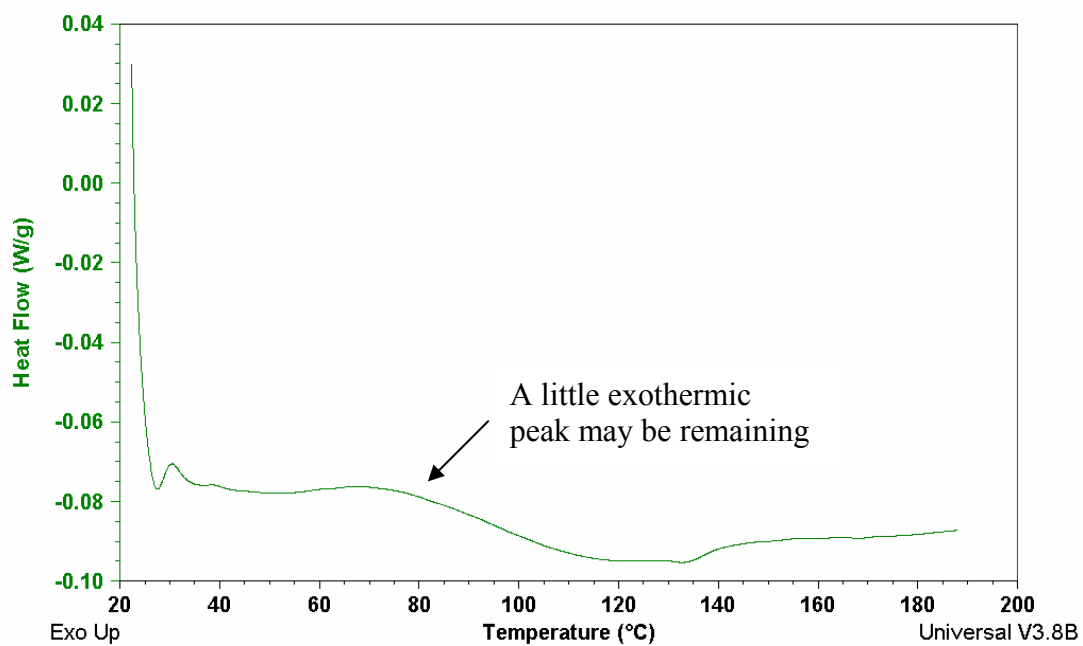
After careful observation, the actual NiCrAlSi resistor seemed operational; however, a crack was found on the PTH. This caused the resistor measurement to be electrically open.

## **7.5 PTF Resistor Degree of Cure Measurement**

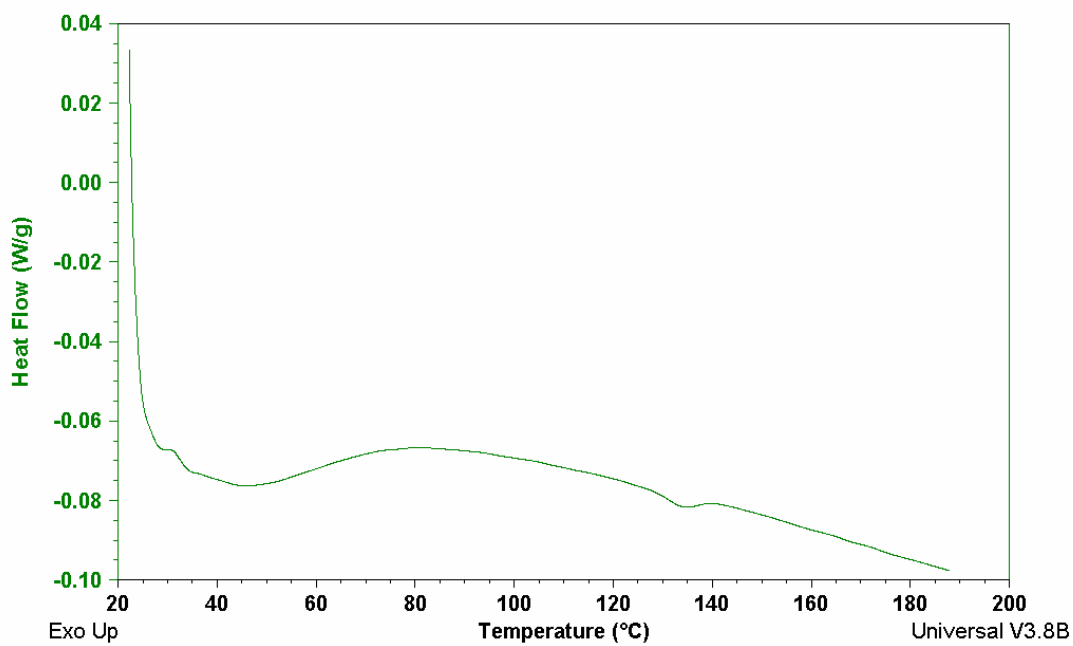
Various reliability qualification tests suggest that PTF materials in TV1 might not have been fully cured. During the first two hundred cycles of thermal cycling, resistance showed a decreasing trend before the resistance started to gradually increase. To investigate the degree of cure (DOC) of PTF resistors, Differential Scanning Calorimetry (DSC) was performed with the help of PRC research engineers.

DSC is a commonly used thermal analysis to measure the amount of energy absorbed or released with respect to temperature. The amount of energy is based on the heat flow of test sample while the temperature is heated, cooled, or maintained constant. To test if PTF resistors in TV1 are fully cured, a small amount of PTF resist paste was cured based on the recommendations from the manufacturer at 170°C for 1 hour. Then, DSC measurement was taken while the temperature was increased from 25°C to 190°C. Figure 7.19 shows the DSC test results.

As shown in Figure 7.19, a small amount of exothermic reaction occurs at around 70°C. Even after when the sample was cured for two hours, there is still a small amount of exothermic reaction occurring at around 70°C. These dynamic scans suggest that although the material is almost cured, it is not fully cured.



(a) DSC of cured specimen at 170°C for 1 hour



(b) DSC of cured specimen at 168°C for 2 hour

Figure 7.19. DSC measurements of partially cured PTF material



# **CHAPTER VIII**

## **FINITE ELEMENT MODELING**

### **8.1 Material Modeling**

Electronic packages usually consist of multiple layers of dissimilar materials. When subjected to thermal excursions, the dissimilar material properties cause stresses and strains within layers that could result in cracking, delamination, and others that could lead to failure. Therefore, it is important to represent the material behavior, geometry, and process conditions as accurately as possible to be able to predict the various failure modes. Some materials can be represented using simple linear elastic model, while other materials require more complex material models that are temperature and time dependent. This section discusses the four materials that were used in the numerical models: the base substrate, the capacitor dielectric, the copper electrodes and via metallization, and the substrate dielectrics.

#### ***8.1.1 Copper Electrodes and Microvia Metallization***

The copper electrodes and copper microvias were “mechanically” modeled in the same way regardless of the fact that the electrodes were thin-film laminated, while the via was electroplated. The elastic behavior of copper was modeled as linear isotropic and temperature independent. The plastic behavior of copper was modeled with a multi-linear kinematic hardening relationship. Instead of isotropic hardening where the expansion of the yield surface after initial yielding is uniform with no shape change, kinematic hardening which represents a translation of the yield surface is used. Table 8.1

lists the mechanical properties of copper, and Figure 8.1 shows the multi-linear stress strain curve at room temperature.

Table 8.1. Material properties of copper at room temperature [Iannuzzelli 1991]

Property	Value
Young's Modulus (GPa)	121.0
Poisson's Ratio	0.34
CTE (ppm/°C)	17

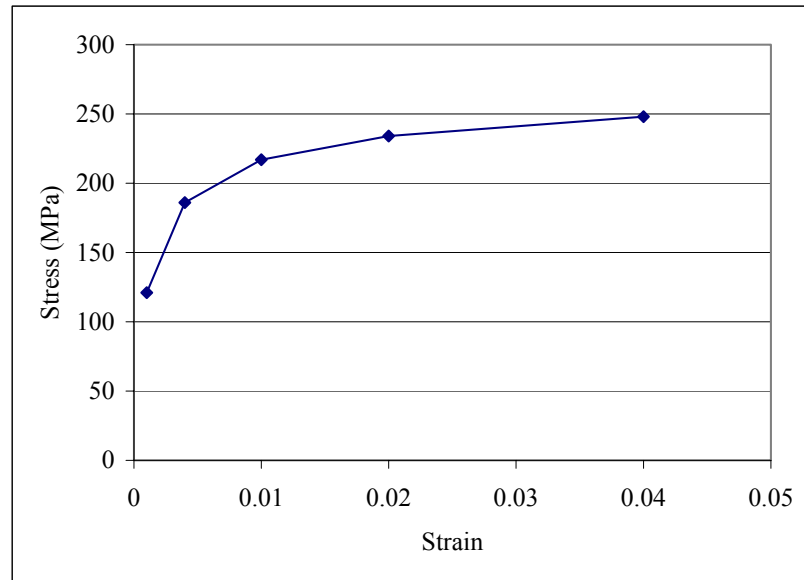


Figure 8.1. Stress strain relationship of copper at room temperature

### 8.1.2 Base Substrate

The base substrate is Driclad<sup>®</sup> from EI Technologies, Inc. It is a high  $T_g$  FR4 with dielectric constant of  $\sim 3.9$  and dielectric loss of 0.014 [EI website]. Since the  $T_g$  of 180°C is above the processing temperature, Driclad<sup>®</sup> was modeled as orthotropic temperature independent. Table 8.2 lists the material properties for Driclad<sup>®</sup>.

Table 8.2. Material properties of Driclad® [EI website]

Property	Value
Young's Modulus (GPa)	17.305
Poisson's ratio	0.14
CTE $\alpha_x$ and $\alpha_y$ below $T_g$ (ppm/°C)	14.7
CTE $\alpha_z$ below $T_g$ (ppm/°C)	55
CTE $\alpha_x$ and $\alpha_y$ above $T_g$ (ppm/°C)	8.7
CTE $\alpha_z$ above $T_g$ (ppm/°C)	360

### 8.1.3 Substrate Dielectric

The substrate dielectric that covers both sides of the board is Dynavia 2000™. This photo-imageable epoxy based dielectric exhibits linear viscoelastic behavior. Its mechanical behavior is dependent on temperature and time. Below its  $T_g$  of approximately 115°C, the CTE is 72 ppm/°C, while above its  $T_g$  the CTE is 200 ppm/°C.

A simple way to model the linear viscoelastic behavior is by using various combinations of spring and dashpot elements. The elastic behavior is modeled using springs, and the viscous behavior is modeled using dashpots. The Kelvin-Voigt and Maxwell models can represent a simplified viscoelastic behavior by using mechanical springs and dashpots in parallel and in series respectively as shown in Figure 8.2 [EN222 Course Note, Brown University]. These simple models, however, do not accurately model the viscoelastic behavior. The Kelvin-Voigt model does not show time-dependent stress relaxation or deform instantly under a suddenly applied stress. Also, Maxwell model does not display a decreasing strain rate under a constant stress or time-dependent recovery after being unloaded. In order to accurately model the linear viscoelastic

behavior, a generalized Maxwell model was used. Essentially, it is a combination of Kelvin-Voigt and Maxwell models. The Kelvin-Voigt models in parallel were used for simulating creep, and the Maxwell models in series were used for simulating stress relaxation [Findley et al., 1989]. This model is also known as Prony Series and is represented in Equation 8.1.

$$G(\xi) = G_o + \sum_{i=1}^N G_i \exp(-\xi / \tau_i)$$

where,  $G_o$  is the initial glassy modulus,  $N$  is the number of Maxwell elements,  $\xi$  is the reduced time, and  $\tau$  is the relaxation time. The Prony Series parameters are based from Dynamic Mechanical Analysis (DMA) measurement as listed in Table 8.3.

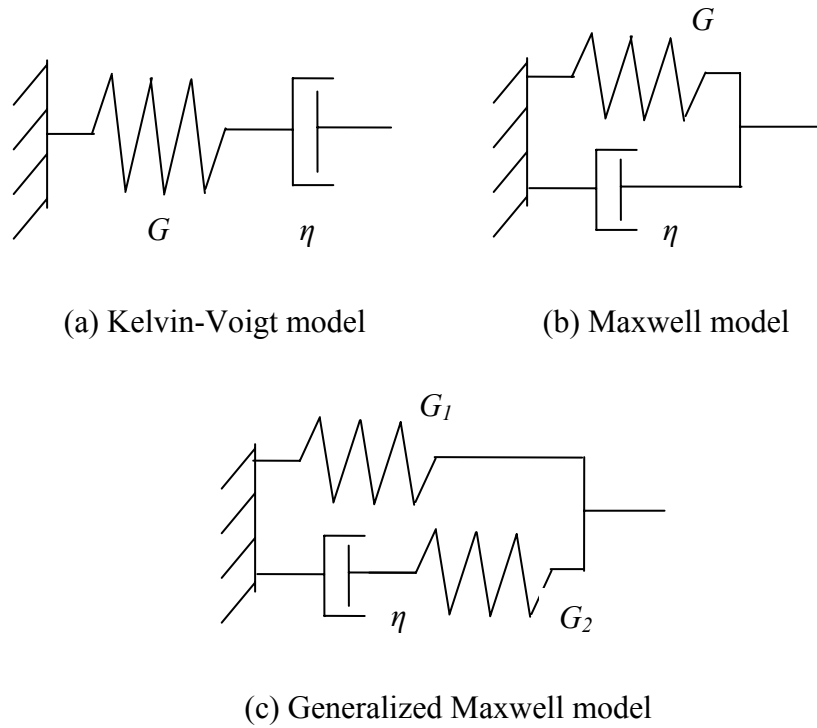


Figure 8.2. Various viscoelastic representations

Table 8.3. Dynamic Mechanical Analysis measurement of Dynavia 2000™  
[Ramakrishna, 2003]

Relaxation time $\tau_i$ (sec)	Extensional relaxation modulus weight factors (MPa)
7.19E-03	16.6368
9.05E-02	9.48133
1.14E+00	167.537
1.43E+01	136.641
1.81E+02	312.464
2.27E+03	330.227
2.86E+04	267.117
3.60E+05	251.494
4.54E+06	9.75963
5.71E+07	38.8723
7.19E+08	21.4291
	$E(\infty)$ (rubbery) = 7.55

#### 8.1.4 Capacitor Dielectric

The dielectric material used in the capacitors was developed by EI Technologies, Inc. The exact material chemical composition is proprietary, but it is a mixture of polymer and ceramic based nano-particles to achieve relatively high dielectric constant and stable material properties. This material was modeled as linear isotropic and temperature dependent. Table 8.4 lists the mechanical and electrical material properties.

Table 8.4. Material properties of capacitor dielectric

Property	Value
Young's Modulus (GPa)	2.8
Poisson's Ratio	0.34
CTE below 125°C (ppm/°C)	33.5
CTE above 125°C (ppm/°C)	60.7
Dielectric Constant at 1 MHz	22
Loss Factor at 1 MHz	0.016

## 8.2 Geometry Models and Assumptions

Physics-based numerical models were developed to qualitatively assess the failure mechanisms of embedded capacitor. Both 2-D and 3-D finite element models were developed to analyze the sequential buildup (SBU) process and the thermo-mechanical electrostatic performance of embedded capacitors. Some of the assumptions made for the finite element analysis and material models were:

- Due to the complex substrate structure, some of the minor geometric features were ignored.
- The geometric dimensions were obtained from the cross-sectioning of the structure. Any minor dimensional variations due to processing were ignored.
- Although effort was made to accurately model the materials, limited access to proprietary materials resulted in simplified material models.
- The electrostatic analysis assumes that the variation in the capacitance is solely from thermo-mechanical deformation of capacitors. Material

degradations such as change in dielectric constant due to thermal excursions were neglected.

All the material properties and important dimensional parameters are parametric, and thus, they can be easily changed to analyze other materials or different geometric dimensions. Four different cases were compared based on the copper probing pad location and planar dimension to investigate their effects on the thermo-mechanical reliability. As discussed in earlier chapter, probing pads are either located in the center or the edge of the capacitor as shown in Figure 8.3. The main difference between them is center probe has a hole in the center of top electrode while the edge probe has extended bottom electrode. In terms of electrical performance, center probes are preferred due to less parasitic inductance than edge probes; however, it is unknown which performs better in terms of thermo-mechanical reliability. For this comparison, actual dimensions were slightly modified to keep all the relative dimensions equal except the location of vias. In addition, identical mesh density for both models was used.

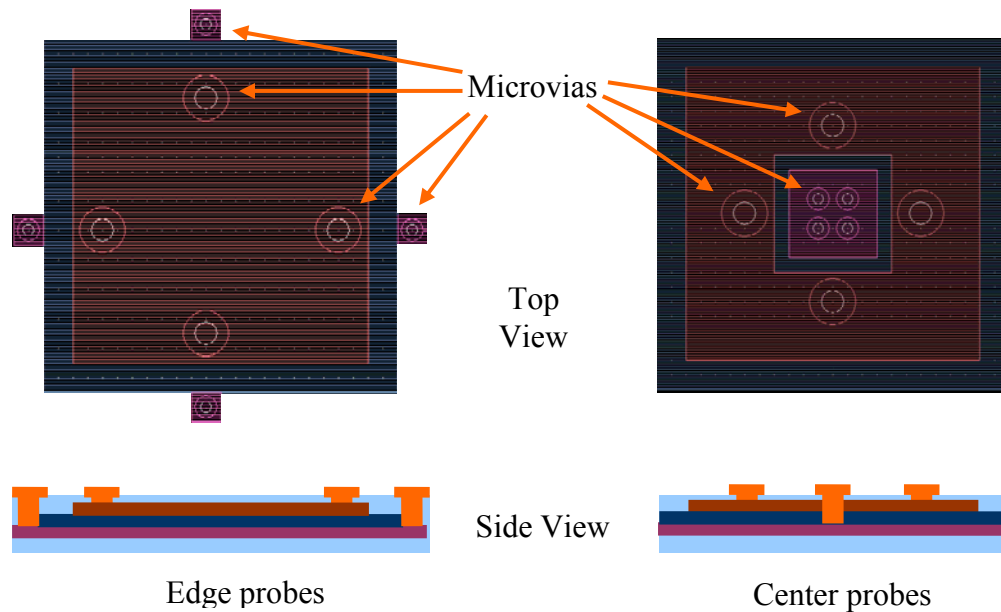


Figure 8.3. Comparison between edge probe and center probe

Other comparison was based on the capacitor size. Numerical models of both 2 mm and 4 mm capacitors were developed to examine if the change in capacitance is due to thermo-mechanical deformations rather than other reasons such as fabrication problems. Table 8.5 summarizes the test cases.

Table 8.5. Summary of capacitor geometry comparison test

Test cases
2 mm edge probe
2 mm center probe
4 mm edge probe
4 mm center probe

### **8.2.1 Modeling Approach**

There are several approaches to accurately model the embedded capacitors. The most simplified approach is using 2-D plane elements. By approximating the out-of-plane thickness, this approach can give good approximation of results in the shortest time. For complex analysis, this approach could give misleading results, and they should be interpreted with caution. More accurate approach is using 3-D solid elements. 3-D model does not have any geometry and material simplification, and is most time-consuming and computationally expensive. Both 2-D and 3-D approaches were taken to model the embedded passives, and following sections describe each approach in detail.

#### **2-D Plane Elements**

The out-of-plane thickness can be assumed as plane strain, plane stress, or plane stress with thickness. Plane strain assumes that the out-of-plane strain can be neglected. This assumption is valid if the thickness of the out-of-plane is one to two orders of



magnitude larger than the planar dimensions. Similarly, plane stress assumes that the out-of-plane stress can be neglected. This assumption is valid if the thickness of the out-of-plane is much smaller than the planar dimensions. Lastly, plane stress with thickness defines a finite out-of-plane thickness.

For all 2-D analyses, PLANE183 (ANSYS<sup>TM</sup>) quadratic element with plane stress with thickness assumption was used. Only half of the capacitor was actually modeled with the assumption that the left side and right side is symmetric along the center line. To apply this symmetry boundary condition, the nodes on the left edge were constrained in the  $x$ -direction. In addition, the bottom left corner node was constrained in the  $y$ -direction to prevent any rigid body motion. Figures 8.4 and 8.5 show the geometry of the 2-D edge probe and center probe capacitors respectively, and Table 8.6 lists the dimensions.

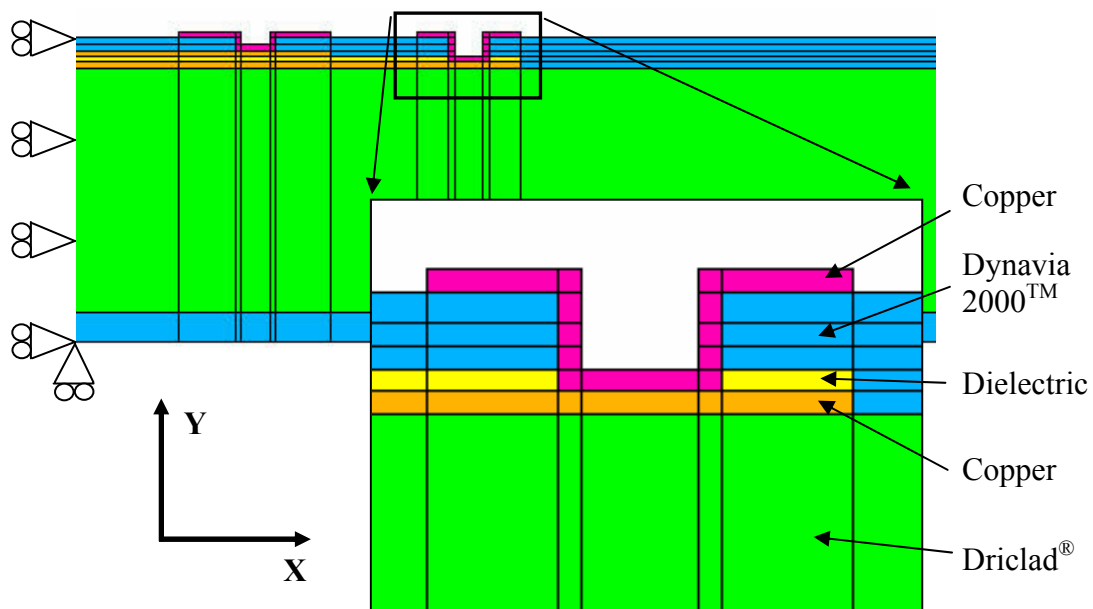


Figure 8.4. 2-D edge probe capacitor with material identifications

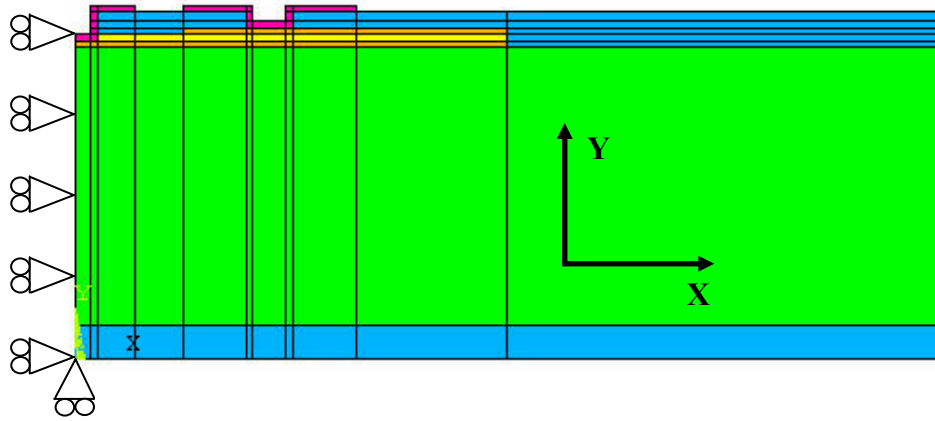


Figure 8.5. 2-D center probe capacitor with boundary conditions

Table 8.6. Embedded capacitor dimensions

Feature	Thickness ( $\mu\text{m}$ )
Driclad <sup>®</sup> substrate	640
Top and bottom Dynavia 2000 <sup>™</sup>	80
Copper electrodes	15
Capacitor dielectric	20
Microvia	15

### 3-Dimensional Solid Elements

For all 3-D analyses, SOLID186 (ANSYS<sup>™</sup>) quadratic element with full integration assumption was used. Only 1/8<sup>th</sup> of capacitor was actually modeled due to symmetry. To apply this boundary condition, the nodes on the left most edge in  $x$ - $y$  plane were constrained in the  $x$ -direction, and the bottom left corner node in  $x$ - $y$  plane was constrained in the  $y$ -direction. In addition, nodes attached to diagonal areas in  $x$ - $z$  plane were constrained to have equal displacement in positive  $x$ -direction and negative  $z$  direction. Figure 8.6 shows the geometry of 3-D capacitor with the boundary conditions.



of the “dead” elements is multiplied by a reduction factor (1.0 E-6) so that the “dead” elements do not contribute any stiffness to the model. Also, any element loads or mass associated with the dead elements are zeroed out and removed from other calculations. When the elements are reactivated, their stiffness, mass, and element loads return to their original values. This element birth-and-death feature is different from merely changing the material property of certain elements, because the strain history of reactivated elements is not maintained. Just changing the material property will retain the initial strain experienced by the elements as they are born into the displaced node configuration.

The process model assumes the structure to be stress-free at the curing stage of capacitor dielectric at 150°C. After curing, the substrate was brought down to room temperature for the lamination of substrate dielectric. The dielectric was then cured at 135°C for 1 hour, and the entire board was brought down to room temperature. Electroless copper plating of seed layers and electroplating of probing pads were completed at room temperature. Figure 8.7 shows the thermal load profile.

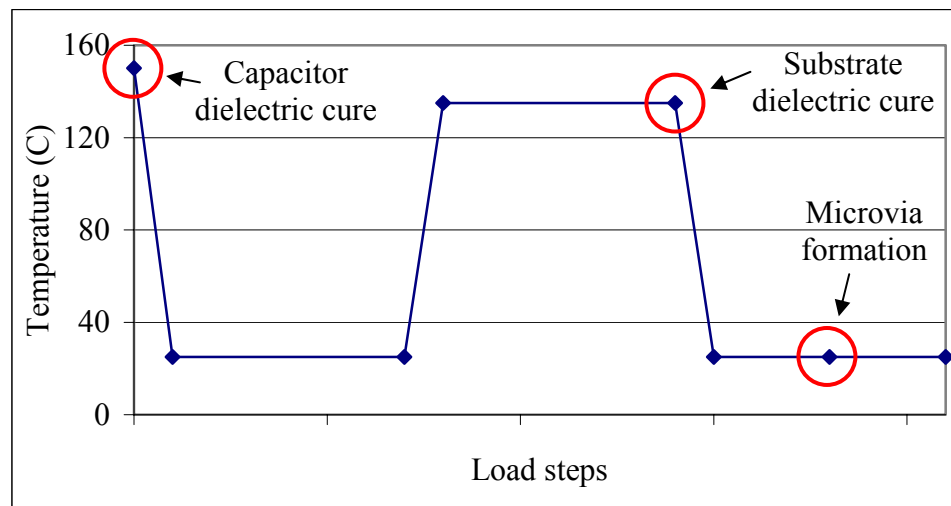


Figure 8.7. Thermal load profile for process model

### 8.3.1 Process Modeling Results

Finite element analysis of process modeling focused on several thermo-mechanical concerns including: warpage, dielectric cracking, and interfacial delamination. Axial stresses and von Mises stresses were used as damage metric for dielectric crack growth, and peel stresses were used as damage metric for interfacial delamination. Figures 8.8 to 8.10 show typical warpage and stress distributions based on 2 mm edge probe capacitor, and Figures 8.11 to 8.13 compares the results from four cases. All the results were based on 2-D plane stress with thickness models.

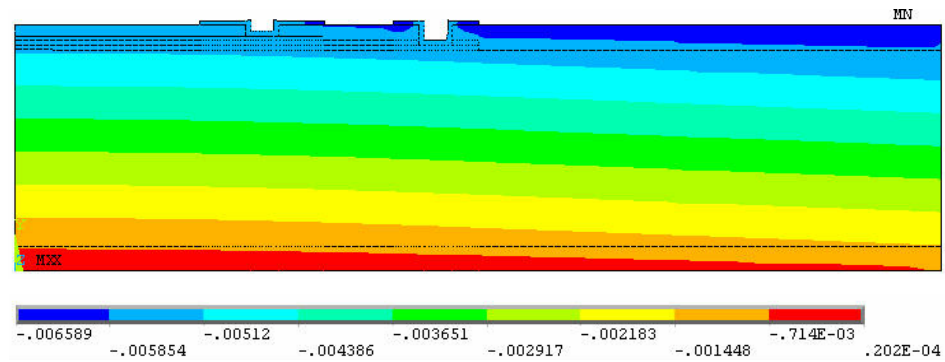


Figure 8.8. Board warpage after assembly process

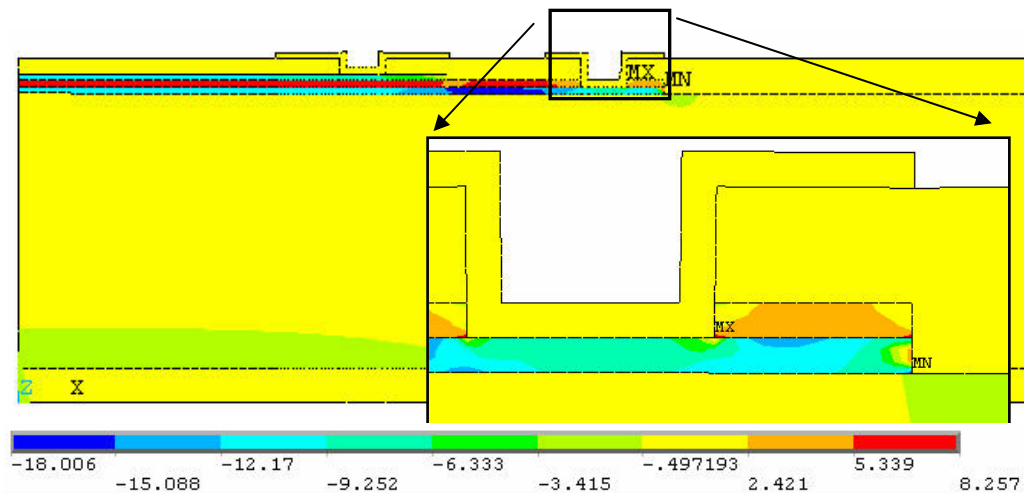


Figure 8.9. Axial stress distribution

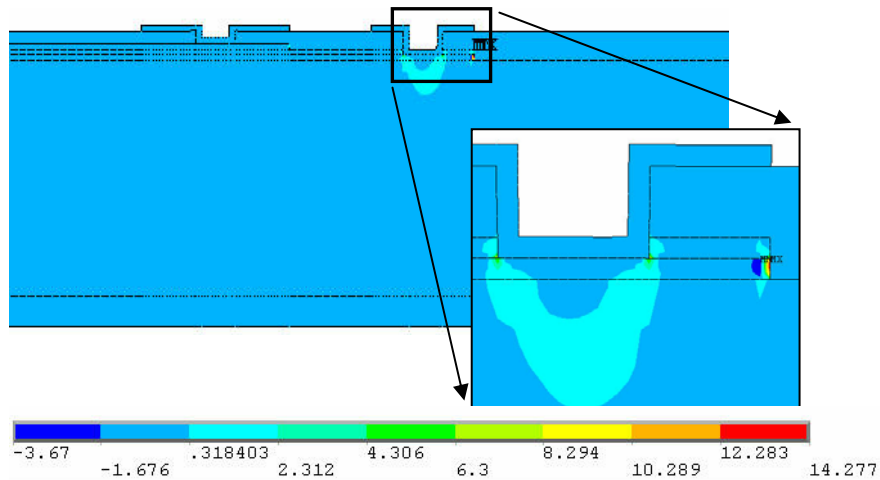


Figure 8.10. Peel stress distribution

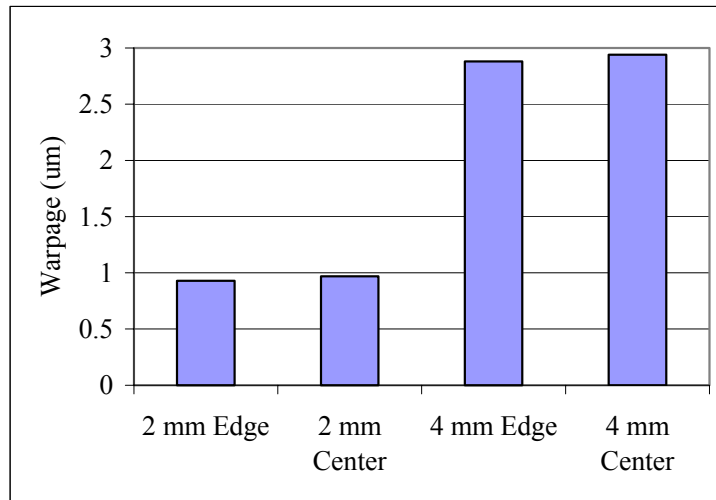


Figure 8.11. Warpage comparison

The warpage results were based on the y-component relative displacement between the bottom left most node and bottom right most node. Since warpage is dependent on the length of the board, 2 mm and 4 mm capacitors should not be compared directly. Since Dynavia 2000<sup>TM</sup> has higher CTE than the other materials, higher volume of Dynavia 2000<sup>TM</sup> at the bottom of the board shrinks and bends the entire board

downwards. For both 2 mm and 4 mm capacitors, probe location has very little effect on the warpage of entire board.

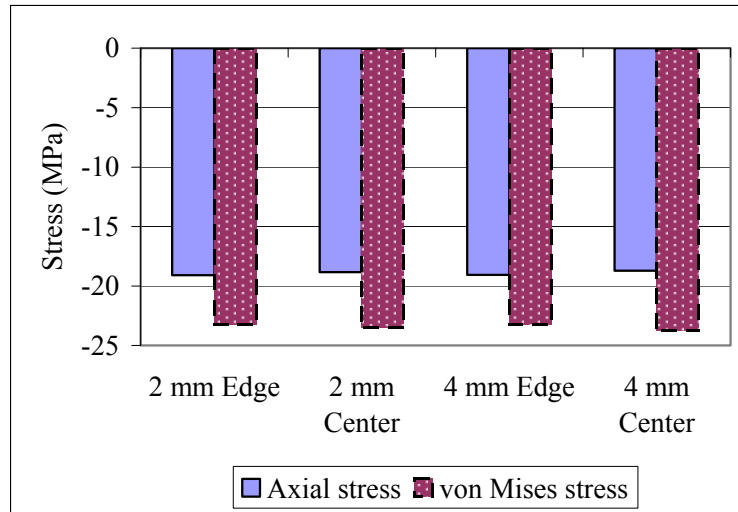


Figure 8.12. Axial and von Mises stresses

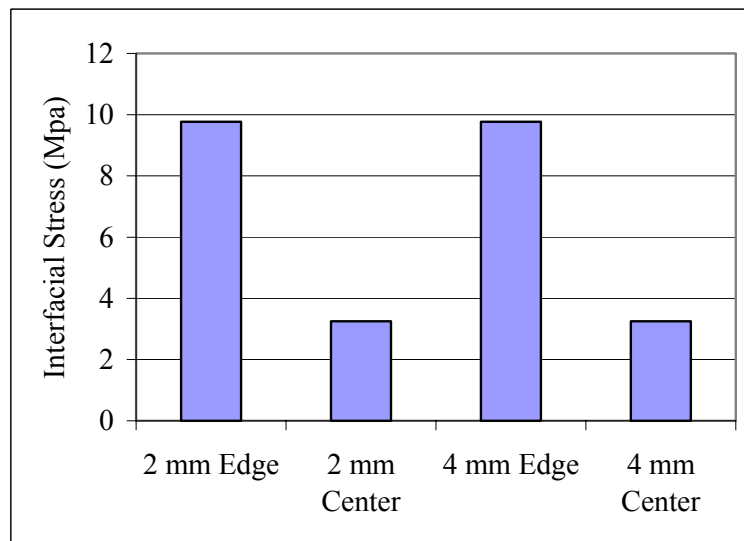


Figure 8.13. Peel stress comparison

Stress results were based on the maximum stress observed. As shown in Figure 8.12, the capacitor planar dimensions or the probe location does not seem to affect the

axial stress or von Mises stress. All four cases showed similar axial stresses of -19 MPa and von Mises stresses of -23.5 MPa. This is expected since the axial stresses are dependent on thickness of the build-up layers and the material moduli. In terms of interfacial delamination, the maximum interfacial peel stresses were observed near the edge of the capacitor between the copper and capacitor dielectric layers. As shown in Figure 8.13, the planar dimensions of capacitor does not seem to affect the results; however, edge probes show almost three times higher interfacial peel stresses than the center probes. Although this model is more qualitative and adhesion is dependent on numerous factors, literature review suggests that these stress levels could cause delamination. Kupfer [2000] reported interfacial strength between Cu and various polymers to be between 10 to 25 MPa depending on the surface treatments.

#### **8.4 Thermo-Mechanical Electrostatic Model**

Thermo-mechanical electrostatic analyses were performed to understand the thermo-mechanical behaviors and their effects on the performance of embedded capacitors. It is essentially a two-step process. First, thermo-mechanical analysis was performed to investigate the deformation of the capacitor, and then its displacement boundary condition was transferred to electrostatic analysis to investigate its effect on the capacitance. The temperature range of thermal cycling simulation was -40 to 125°C as shown in Figure 8.14.



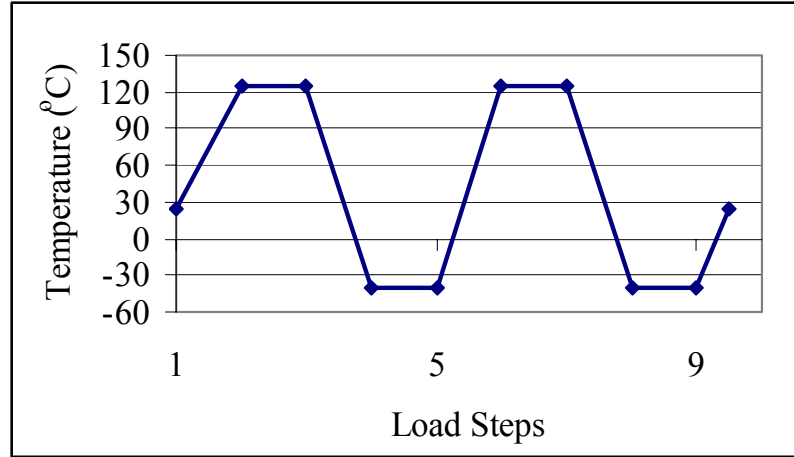


Figure 8.14. Thermal cycling load profile

#### 8.4.1 Electrostatic analysis

Electrostatic analysis was based on the electrical potential energy stored in the dielectric material. The magnitude of the electrical potential energy and its relationship between the capacitance are represented in Equations 8.1 and 8.2.

$$U = \frac{1}{2} \int_V E \cdot D dv \quad (\text{Eq. 8.1})$$

$$C = \frac{2U}{(V_1 - V_2)^2} \quad (\text{Eq. 8.2})$$

$U$  is the magnitude of electrical potential energy,  $E$  is electric field,  $D$  is electric distance,  $V$  is electrical potential,  $C$  is the capacitance, and  $V_1$  and  $V_2$  are the applied voltage on top and bottom electrodes respectably. When the voltage is applied on the electrodes, positive and negative charges within the dielectric material shift towards the electrodes in opposite direction. This creates the polarization within the dielectric and stores electrical

energy. Numerical model follows a similar approach. When different voltage values are applied on the top and bottom electrodes, the dielectric material stores electrical energy based on its dielectric constant. The magnitude of electrical potential energy at each element associated with the dielectric material can be added to obtain the total energy stored. Then, the capacitance can be calculated by Equation 8.2

#### 8.4.2 Thermo-Mechanical Electrostatic Analysis Results

3-D models were used to complete all thermo-mechanical electrostatic analyses. Thickness of all capacitors is assumed as 15  $\mu\text{m}$  based on test case 1. Table 8.7 compares the capacitance before the deformation with the theoretical calculation using Equation 8.3.

$$C = \frac{\epsilon_r A}{t} \quad (\text{Eq. 8.3})$$

$C$  is capacitance,  $\epsilon_r$  is the relative permeability of dielectric,  $A$  is the area of effective capacitor electrodes, and  $t$  is the thickness of dielectric.

Table 8.7. Comparison between the theoretical and simulated capacitance

Test cases	Theoretical capacitance (pF)	Simulated capacitance before deformation (pF)	Comparison (%)
2 mm edge	51.94	52.32	- 0.73
2 mm center	48.70	49.25	- 1.13
4 mm edge	207.77	208.34	- 0.27
4 mm center	204.53	204.86	- 0.16

Although theoretical capacitances are very similar to the simulated results, all four cases show slightly higher simulation results as listed in Table 8.7. This is expected due to the extra area of capacitor electrodes that is not considered in the theoretical calculations. The small tab of extension on the edge probe capacitors and the via areas of center probes do store electrical charge and contribute to the capacitance calculation. Table 8.8 lists the change in capacitance before and after the thermal cycling simulation.

Table 8.8. Comparison of change in capacitance

Test cases	Simulated capacitance before cycling (pF)	Simulated capacitance after cycling (pF)	Comparison (%)
2 mm edge	52.32	52.44	0.23
2 mm center	49.25	49.36	0.22
4 mm edge	208.34	208.83	0.24
4 mm center	204.86	205.35	0.24

Overall, there is less than 1% change in capacitance after thermal cycling simulation. These results are much smaller than the experimental results, where 110 mil (2.79 mm) square capacitor showed approximately 3% change in capacitance after identical thermal cycling. This is most likely due to inadequate material models. The simulation results are only based on the thermo-mechanical deformation, and any material degradation is not considered since they were not available. Inclusion of change in dielectric constant due to thermal cycling should show closer results.

## CHAPTER IX

### CONCLUSION AND FUTURE WORK

#### 9.1 Conclusion

This thesis made contributions to overall development of embedded passives by focusing on the design and fabrication as well as the experimental and theoretical reliability assessments. Experimental study was based on the fabrication of test vehicles and various reliability qualification tests. Theoretical modeling study was based on the development of numerical models that simulate the fabrication process conditions and thermal cycling. The summary and contributions of this thesis are:

- Embedded capacitors and resistors with different geometric shapes, planar dimensions, and thus different electrical characteristics were fabricated in a multilayered organic substrate.
- Capacitors are made with polymer/ceramic nanocomposite materials and have a capacitance in the range of 50 pF to 1.5 nF with specific capacitance of approximate 1.4 nF/cm<sup>2</sup>.
- Resistors are carbon ink based PTF and NiCrAlSi and have a resistance in the range of 25  $\Omega$  to 400 k $\Omega$ .
- High frequency measurements of capacitors showed stable capacitance from 200 MHz to 1.8 GHz and resonant frequency at 900 MHz.
- Various accelerated reliability qualification tests including thermal cycling (-40 to 125°C and -55 to 125°C), constant temperature and humidity tests

(85°C/ 85%RH), and HAST (121°C/ 100%RH) based on JEDEC and MIL standards were performed.

- Accelerated tests showed PTF resistors with less than 5% change in resistance and NiCrAlSi resistors with less than 1% change in resistance.
- Accelerated tests showed some capacitor test vehicles with more than 20% change in capacitance, while others only showed less than 5% change. Such dramatic change is most likely due to fabrication problems.
- Various geometric shapes and planar dimensions of resistors and capacitors were compared after accelerated tests. No clear dependence of geometric shapes and planar dimensions were shown.
- TCR and TCC of TV1 were measured to characterize the materials.
- Numerical models of capacitor were developed to analyze the fabrication process conditions and thermal cycling. All the material properties and important dimensional parameters are parametric, and thus, they can be easily changed to analyze other materials or different geometric dimensions.
- Two different probing pad locations and two sizes of capacitors were numerically compared. Center probes showed higher warpage and interfacial stresses than edge probes.
- Thermo-mechanical electrostatic analyses were performed and investigated the change in capacitance due to thermo-mechanical deformation. Less than 1% change in capacitance was shown due to thermo-mechanical deformation.

## 9.2 Future Work

Over the last several years, tremendous progresses have been made in embedded passive technology. Some of recommendations for future work are:

- Perform other experimental characterization such as break down voltage to help understand the embedded passive behaviors.
- Develop numerical models to characterize high frequency performance of capacitors
- Perform more accurate material characterizations to qualitatively study the failure mechanisms.
- Analyze different dielectric material systems to compare their thermo-mechanical reliability

## APPENDIX A: Detailed Fabrication Steps

### Appendix A.1. Detailed embedded capacitor fabrication processes and conditions

Surface preparation	Acetone bath and microetch for 2 minutes to thoroughly clean the surface and improve adhesion.
Bond film to improve adhesion	<p>Bond film is a 3 step process:</p> <p style="padding-left: 40px;">Cleaner at 40 – 55°C for 4 minutes</p> <p style="padding-left: 80px;">Rinse with DI water for 2 minutes</p> <p style="padding-left: 40px;">Activator at 25 – 45°C for 2 minutes</p> <p style="padding-left: 80px;">No Rinse</p> <p style="padding-left: 40px;">Bond solution at 35 – 45°C for 2 minutes</p> <p style="padding-left: 80px;">Rinse with DI water for 2 minutes</p> <p>Board was baked at 90°C for 30 minutes to remove moisture.</p>
Nanocomposite preparation	Mix 44 g of barium titanate based polymeric resin with 4.24 g of hardener and 5 g of thinner for 1 hour.
Spin coat nanocomposite	<p>Spin coat at 2000 rpm for 30 seconds with 500 rpm ramp rate.</p> <p>Board was baked at 65°C for 45 minutes to remove moisture.</p>
Copper lamination	Drawer Vacuum Laminator
Heat press to strengthen copper lamination	2 tons press applied at 70°C for 20 minutes.
Surface preparation	<p>Acetone bath and microetch for 2 minutes to thoroughly clean the surface and improve adhesion.</p> <p>Board was baked at 70°C for 30 minutes to remove moisture</p>
Spin coat photoresist	<p>Shipley SP20-29 positive liquid photoresist was spin coated at 1000 rpm for 30 seconds.</p> <p>Board was baked at 70°C for 30 minutes to remove moisture.</p>
UV exposure to pattern top electrode	UV exposure of 200 – 300 mJ/cm <sup>2</sup> performed on Tamarack 152R contact printer under vacuum hard contact with a Mylar photo tool.

Develop exposed photoresist	<p>12% Photoposit 303A developer at 26 – 32°C for 1 – 3 minutes with mild agitation</p> <p>Board was baked at 70°C for 30 minutes to remove moisture.</p>
Etch copper	<p>Exposed copper area removed with 30% Ferric Chloride for 15 minutes</p>
Strip nanocomposite and photoresist	<p>Nanocomposite and remaining photoresist were flat UV exposed for 2 minutes.</p> <p>Gamma Butyrolactone (GBL) solvent was sprayed for 10 minutes to strip the nanocomposite and photoresist.</p> <p>Board was fully cured at 150°C for 1 hour to complete the process.</p>



## Appendix A.2. Detailed embedded resistor fabrication processes and conditions

Surface preparation	Acetone bath and microetch for 2 minutes to thoroughly clean the surface and improve adhesion.
Laminate dry photoresist	Dupont Riston 4615 dry film (30 $\mu\text{m}$ thick) was vacuum laminated on the board.
UV exposure	UV exposure of $\sim 300 \text{ mJ/cm}^2$ performed on Tamarack 152R contact printer under vacuum hard contact with a Mylar photo tool.
Develop photoresist to get pattern	1% Sodium Carbonate at $45^\circ\text{C}$ was used for 2 minutes to develop the photoresist. Board was baked at $70^\circ\text{C}$ for 30 minutes to remove moisture.
Apply Carbon Ink resist material	The Carbon Ink was squeezed into the developed negative pattern of the resist trace. Board was baked at $120^\circ\text{C}$ for 1 hour to harden the resist material.
Strip photoresist	3% Sodium Hydroxide at $55^\circ\text{C}$ was used to strip the photoresist. Finally, the board was cured at $150^\circ\text{C}$ for 1 hour to complete the process.

### Appendix A.3. Detailed microvia fabrication processes and conditions

Surface preparation	Acetone bath and microetch for 2 minutes to thoroughly clean the surface and improve adhesion.
Spin coat photoresist	<p>Photoepoxy dielectric (Vantico Probimer 7081) was spin coated at 1000 rpm for 40 seconds to achieve a nominal thickness of 30 <math>\mu\text{m}</math>.</p> <p>Board was baked at 90°C for 30 minutes to remove moisture.</p>
UV exposure	<p>UV exposure of <math>\sim 4,000 \text{ mJ/cm}^2</math> performed on Tamarack 152R contact printer under vacuum hard contact with a Mylar photo tool.</p> <p>Board was baked at 110°C for 1 hour to fully crosslink the exposed area.</p>
Develop photoresist to open up microvias	<p>Gamma Butyrolactone (GBL) solvent at room temperature was used for <math>\sim 3</math> minutes to develop the photoresist.</p> <p>Remaining photoresist was flat exposed with <math>\sim 4,000 \text{ mJ/cm}^2</math>.</p> <p>Board was fully cured at 160°C for 1 hour.</p>
Electroless copper plating to build a seed layer	<p>Electroless copper plating is a 8 step process:</p> <ul style="list-style-type: none"> <li>Swell at 70°C for 8 minutes</li> <li>Rinse with DI water for 2 minutes</li> <li>Etch at 77°C for 7 minutes</li> <li>Rinse with DI water for 2 minutes</li> <li>Neutralizer at 40°C for 2 minutes</li> <li>Rinse with DI water for 2 minutes</li> <li>Conditioner at 65°C for 6 minutes</li> <li>Rinse with DI water for 2 minutes</li> <li>Predip at room temperature for 1 minute</li> <li>Rinse with DI water for 2 minutes</li> <li>Activator at 40°C for 6 minutes</li> <li>Dip in DI water for 20 seconds</li> <li>Reducer at 27°C for 5 minutes</li> <li>Dip in DI water for 20 seconds</li> </ul>

	Electroless copper bath at 34°C for < 2 minutes Board was baked at 120°C for 1 hour.
Laminate dry photoresist to build microvias and copper pads	Dupont Riston FX515 dry film (15 µm thick) was vacuum laminated on the board.
UV exposure	UV exposure of 105 mJ/cm <sup>2</sup> performed on Tamarack 152R contact printer under vacuum hard contact with a Mylar photo tool. Board was baked at 90°C for 10 minutes to harden the photoresist.
Develop photoresist to get pattern	1% Sodium Carbonate at 45°C was used for 2 minutes to develop the photoresist.
Electroplating copper to build microvias	Direct current of 1.25 A was applied for 8 minutes for each of 4 rotations to achieve the target thickness of 8 -10 µm.
Strip photoresist	3% Sodium Hydroxide at 55°C was used to strip the photoresist.
Microetch copper	The seed electroless copper layer was microetched to complete the process.

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